

Bruker Nano

Nanos ScanPanel

User Guide

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This manual is supposed to introduce the usage of the Scanning probe microscope system *Nanos*. It was reedited from former versions and extended. The structure of the chapters is s follows.

The "safety regulations" are summarized in the first chapter.

The chapter "<u>Introduction</u>" contains basic information about the method of Scanning Probe Microscopy (SPM) and your *Nanos* in detail. The reader, who is not familiar with SPM gets substantial information about the method and the special features of the *Nanos*. Some technical terms, are defined in this chapter; they are marked in bold type. Names of settings, which can be entered to the ScanPanel software, are marked with SMALL CAPITALS.

The chapter "<u>Installation</u>" guides the user through hardware and software installation. The installation after the first delivery is usually done by our technical support. In case of e.g. reinstallation of the system or software updates it may be necessary to follow this chapter.

For getting started with your new system the chapter "basic operating" gives step by step information to perform a measurement. From parameter settings to the storage of a measurement, the chapter conduct the operator through the image recording procedure by screenshots and photos. For each operating step standard settings are shown, usually followed by a technical description of its effect. On getting started with your new instrument you may skip these technical descriptions, which follows usually in each paragraph and go ahead with the next operating step.

Settings, which are not substantial for the initial operation are described in the next chapter. This is titled "<u>The functions with ScanPanel</u>". The conception of the software is explained here. The single functions of the ScanPanel user interface are described here or you will find a reference to another chapter.

The "<u>Tip exchange</u>" is described as a basic rigging operation in its own chapter.

Qualification to start the device is an optimal installed and calibrated instrument, like after the first delivery. For recalibration and new calibration and all other alignments and adjustments, which can be performed by the customer, refer to the chapter "adjustment and calibration".

In general this manual is intended to supply operating instructions. It does not provide application support. If you have special questions, please contact us.

We wish you good luck and many useful results with your new *Nanos* instrument. Please let us know about your experience. In case of questions, please contact our support.

Bruker Nano GmbH



History of ScanPanel versions

<u>1.1xw:</u>

Rados: Titanos functions now available in Rados system. several bug fixes for X-Theta systems: Target position is reference position in non optics position, turning clockwise if theta > theta min, positioning until target position reached, deletion of single row in user/macro list.

<u>1.1xu/xv:</u>

Titanos: click in camera image for movement to crosshair; Automatic focus adjustmet between differnet lenses, Error handling for measurements in macro, several more new functions for Titanos.

<u>1.1 xs/xt:</u>

Optional approach via software: An external approach unit with external software can be driven via a common memory interface (Bruker Nano AFM Motor interface).

Display of user interface: Manual setting of 3 different screen resolutions possible.

XY curves: new designed dialog field, new functions (delay time), support of SPIP curve module, several improvements.

<u>1.1 wi:</u>

Start Scan: clicking the button START SCAN during scanning and when it is already selected causes starting a new scanning image.

System parameter: New dialog field to choose weather the system parameter should be user depending or machine depending

Display of user interface: depends on screen area. Support of three different resolutions: 1024x768, 1280x960 one and two monitor style.

Rados-X0-**Stages**: Stage alignment respect now Dy offset by 1²-point calibration, Coordinate positioning improved, coordinate alignment by 1 and 2-point calibration.

Field Contrast2: New and faster software procedure (Multi plurality mode)

Lithography: several improvements

<u>1.1.v:</u>

Rados (NanoStation HD): coordinate import of several file formats with fileServer



Tiatanos (NanoStation300): implementation of functions to drive Nanofocus device

<u>1.1.t:</u>

Calibration: Calibration dialog field contains step correction button

rectangular pixel shape: The number of scanned rows and columns is free to be unequal. This can help to improve the speed af imaging. <u>Please Note:</u> When using this feature, the pixel number in x direction must be an integer multiple of the number in y direction, otherwise image distortion might be observed.

Tiatnos (NANOStation300): improved functions, see Titanos manual.

<u>1.1.q:</u>

HD-Stages: improved positioning; severel functions implemented for PS90 controller.

<u>1.1.p:</u>

Y-Offset in XY-Control field: the sign has been changed. A positive value is now equal to a upwards movement of the scan range.

Parameter Z-Gain in main window: the physical Z-range of the scanner can be electronically diminished by a user defined percentage. A value smaller 100% decreases the maximum Z-Range, while the digital resolution is increased. The setting can be changed in the main window with and without tip in feedback. The setting is controlled now by the *SCAN*Control *C* through a change in the firmware.

Extended status bar: indication of invisible scanner movements (e.g. from image center starting point on top right side, dummy lines, etc.), display of autosave on/off and current autosave file.

Pause Button: stops the forward motion in slow scanning direction. This can be used together with the trace/retrace function for optimizing P/I-values while continuous scanning a single line.

Check box "Square": in main window for convenient input of square scan ranges.

Rewriting system parameters: not only at program exit but also inbetween, e.g. after closing calibration dialog field, closing tip approach window and closing Modul -> Info. System parameters will be loaded at program start.

Autosave window: criterion can be set to save only the images with more than a selectable number of lines scanned.

<u>1.1.n:</u>



Adaptive control of XY-Feedback loop: the P/I values for linearization are no longer necessary to adjust. The new linearization works with an advanced XY-Feedback and adjust by itself. Furthermore the linearization can be used now for scanning fields with less than 1 µm edge length. There is a system parameter available to switch between new and old linearization. The checkbox "linear" in the linearXY-adjust window has no meaning with new linearization.

Improved coarse approach in non-contact mode: the approach was improved especially for small free amplitudes, approach in liquid and other difficult situations. The effect of stopping before reaching the sample was removed. The improvement affects also the firmware.

New dialog field "Advanced Settings": through this dialog field "Set Point" and "Free Amplitude" can be changed during scanning.

More functions for XY-stages, Xq**-stages:** Functions for automatic movement, read in of coordinates and also read in of camera images were implemented. These are intended for convenient and automatic measurement with our automatic platforms. We recommend the upgrade of your system with one of our motorized platforms.

Dialog field "Z-Gain": In this dialog field the maximum Z-Range of the scanner can be diminished electronically via a percentage value. This increases the digital resolution on flat samples.

Log files: the log files contain the cronological transfered commands to the *SCAN*Control *C*. The log files may be used for improved documentation and diagnostics.





TABLE OF CONTENTS

1	Saf	ety regulations	1-1
	1.1	Warnings on the rear of the device	1-1
	1.2	Hazard warnings	1-2
	1.3	Operating voltages	1-3
	1.4	Warnings	1-4
2	Intr	roduction	2-1
	2.1	Scanning Probe Microscopy in general	2-1
	2.2	Cantilever based Scanning Probe Microscopy	2-1
	2.3	The tips	2-2
	2.4	Tip positioning by piezo actuators	2-3
	2.5	The concept of the <i>Nanos</i>	2-4
		2.5.1 Interferometric detection	2-5
		2.5.2 The role of the cantilever piezo	2-8
		2.5.3 Replacing the tips without adjustment	2-9
		2.5.4 The compact tip holders	2-10
		2.5.5 Static and dynamic operating modes	2-11
		2.5.6 The digital Z-feedback	2-12
		2.5.7 The Scanners	2-13
		2.5.8 The scan pattern	2-14
		2.5.9 The linearization	2-16
		2.5.10 The stand	2-18
		2.5.11 The controller	2-18
		2.5.12 The software	2-19
	2.6	Resolution and magnification in SPM	2-20
	2.7	Preparation of the samples	2-21
3	Inst	tallation	3-1
	3.1	System components at a glance	3-1



3.2	Choosing the place of installation	3-2
3.3	Connecting the system components	3-3
	3.3.1 Wiring diagram for tube scanner systems	3-4
	3.3.2 Wiring diagram for upgraded systems	3-5
	3.3.3 Wiring diagram for scanning stage systems	3-6
3.4	Installation of the measuring head	3-7
	3.4.1 Adaptation to an optical microscope	3-7
	3.4.2 Installation to another stand	3-8
3.5	Installing the software	3-8
	3.5.1 Installation program	3-8

4 Basic Operating Instructions 4-1

4.1	Prerequisites	4-1
4.2	Getting started	4-1
4.3	Turning On the Measurement Electronics and Computer	4-4
4.4	Swiveling in the <i>Nanos</i> (turret mount)	4-6
4.5	Turning On and Activating the Isolation System	4-7
4.6	Setting the Signal Adjust	4-8
4.7	Settings in the "Mode / Channel" Window	4-11
	4.7.1 The several acquisition Modes	4-11
	4.7.2 Available Channels for synchronous recording .	4-12
	4.7.3 The switch for Linearization on/off	4-14
	4.7.4 The switch for High or Low Voltage Range	4-15
4.8	Settings in the ScanPanel User Interface	4-16
	4.8.1 The Scan Range	4-16
	4.8.2 The "Z-Feedback" loop control presetting	4-18
	4.8.3 The Image Resolution	4-19
	4.8.4 The Scan Speed presetting	4-20
	4.8.5 The display of multiple recording channels	4-21
4.9	Settings in the Tip Approach (Contact) Window	4-22
	4.9.1 Presetting the Load Force	4-22
4.10	Settings in the "Tip Approach (Non Contact)" Window	4-26
	4.10.1 Setting the Operating Point Adjust	4-27



	4.10.2 Settings in the "FREQUENCY SELECTION" Window
	4.10.3 Setting the Resonance Frequency
	4.10.4 "Coarse" calibration of the Excitation Amplitude4-31
	4.10.5 Calibrating the excitation amplitude
	4.10.6 Setting the Set Point and Free Amplitude
	4.10.7 Checking the Non Contact mode settings
4.11	Settings for additional Measurement Modes4-37
4.12	Approaching the tip (Approach)4-37
4.13	Starting the Scan / Image Acquisition4-40
4.14	Setting the "Display Sensitivity" Contrast Indicator4-42
4.15	Optimizing the Z-Feedback Slider Settings4-44
4.16	Optimizing the scan speed setting4-47
4.17	Monitoring the "Range" Display during the Scan
	4.17.1 Correcting the approach with the "Step" function4-50
4.18	Saving your Measurement Data4-51
4.19	Choosing a New Scan Range4-52
4.20	Retracting the tip4-53
4.21	Turning off the System4-54

5.1	Screen sectioning of the user interface5-1
5.2	Available submenus5-2
5.3	Available buttons5-3
	5.3.1 Button appearance5-4
5.4	The recording image window5-5
5.5	The field "Z Control"5-5
5.6	The field "XY Control"5-8
	5.6.1 Opening the selection frame5-9
	5.6.2. Scaling up or down the selection frame5-10
	5.6.3. Changing the selection frame from one corner5-12
	5.6.4. Changing the selection frame from one edge5-13
	5.6.5. Shifting the position of the selection frame5-14
	5.6.6. Turning the selection frame



6

	5.6.7. The meaning of X- and Y-Offset5-16
5.7	The status bar5-17
5.8	Slider parameter setting; Slider Properties5-18
5.9	Advanced settings5-19
5.10	Plane Correction5-20
5.11	Configuration settings for Extern Channels5-22
	5.11.1 Read in of an extern voltage5-24
	5.11.2 configuring additional read in channels5-25
5.12	Acquisition Delay Time5-25
5.13	The Auto Save Function5-27
5.14	AUTORETRACT- automatic tip retraction5-28
Tip	Changes 6-1
6.1	Causes for tip wear6-1
6.2	Indications for tip changes6-1
6.3	Summary of the procedure6-2
6.4	Remove <i>Nanos</i> from its stand6-3
	6.4.1 Quick-snap adaptor design (microscope)6-3
	6.4.2 Changeable microscope turret design6-4
	6.4.3 Z-Adapter design (PICOStation)6-4
6.5	Remove cantilever connector from the <i>Nanos</i>
	6.5.1 Standard design for measurements in air
	6.5.2 Design for measurements in fluids6-6
6.6	Replacing the tip on the cantilever connector6-7
6.7	Mount cantilever connector on the <i>Nanos</i>
	6.7.1 Standard design (for operation in air)6-9
	6.7.2 shielded design, (for operation in fluid)6-10
6.8	Mounting the <i>Nanos</i> on its stand6-11
	6.8.1 Inserting into the microscope quick-snap adaptor6-12
6.9	Centering one optical lens with respect to the tip position6-13

7 Adjustment and Calibration7-1



7.1	Adjustment of X/Y Linearization	7-1
	7.1.1 Preparations	7-2
	7.1.2 Open the menu X/Y-Linearization	7-2
	7.1.3 Linearization range (Linearization Table)	7-4
	7.1.4 P/I value adjustment of the X/Y-Feedback	7-7
7.2	Offset trim of the Metrology Sensor signal (Z-Sensor)	7-12
7.3	Adjustment of the Phase Channel	7-14
7.4	Calibration	7-17
	7.4.1 The menu Calibration Data	7-17
	7.4.2 Semiautomatic Calibration	7-19
	7.4.3 Additional functions in the dialog Calibration	7-25
	7.4.4 Adjusting the spring constant	7-29
	7.4.5 The menu point Align	7-29
7.5	Cleaning	7-31
	7.5.1 Cleaning the sample stage	7-31
	7.5.2 Cleaning the ferrule	7-32
	7.5.3 Cleaning the SCANControl C	7-33
App	pendix	8-1
8.1	Centering- and calibration-sample data sheet	8-1
8.2	Technical specifications:	8-2
8.3	Mains power supply / fuses	8-3
	8.3.1 Setting power supply voltage	8-4
	8.3.2 Fuse changes	8-4
8.4	Pin assignments of the SCANControlC connectors	8-5
	8.4.1 Signal input connectors	8-6
	8.4.2 Signal output connectors	8-8
	8.4.3 Nanos/scanner connector	8-10
	8.4.4 Motor connector	8-12
	8.4.5 USB-connector	8-14
	8.4.6 Extension port	8-15

9	Index		9-	1
---	-------	--	----	---

8



LIST OF ILLUSTRATIONS

Fig. 1-1	Warnings on the rear of the device1-1
Fig. 2-1	Sketch of the measurement principle in static mode2-2
Fig. 2-2	The "tip": cantilever chip with cantilever and tip
Fig. 2-3	Illustration of the tip radius definition2-3
Fig. 2-4	Example on the deformation of a piezo by positive and negative voltage
Fig. 2-5	Design of a standard tube scanner2-4
Fig. 2-6	Illustration of the Nanos2-5
Fig. 2-7	Illustrated principle of fiber-interferometric detection
Fig. 2-8	The fiber interferometer: intensity I(d) for three different cantilever distances d. \dots 2-7
Fig. 2-9	Interferometer signal plotted over the deflection2-8
Fig. 2-10	The role of the cantilever piezo
Fig. 2-11	Alignment-chip and tip: Drawing, sectional view (sketch), and photography2-9
Fig. 2-12	The cantilever-plug; left side: sectional view, right side: three dimensional view . 2-10
Fig. 2-13	Static cantilever deflection: contact mode
Fig. 2-14	Dynamic cantilever deflection: non-contact mode
Fig. 2-15	Z-feedback: the components of the closed loop feedback
Fig. 2-16	Tube-scanner (I.); Z-only-scanner with scanning stage (r.)
Fig. 2-17	Scan pattern of a 16x16 pixels scan range
Fig. 2-18	Tube scanners with deflection sensors in full bridge connection (schematic) 2-17
Fig. 2-19	Module architecture of the SCANControlC
Fig. 3-1	Illustration of the measuring set-up
Fig. 3-2	Wiring diagram for tube scanner systems
Fig. 3-3	Wiring diagram for systems upraged to SCANControl C
Fig. 3-4	Wiring diagram for stage scanner systems
Fig. 3-5	Example of components to adapt the <i>Nanos</i> to a microscope
Fig. 3-6	Standard adaptor for measuring head
Fig. 3-7	installation program
Fig. 3-8	USB-driver files on CD
Fig. 3-9	USB driver correctly installed
Fig. 4-1	Dialog box "Scanner Key / Setup"
Fig. 4-2	Main Control Panel of the ScanPanel user interface
Fig. 4-3	Example of a Microscope lamp switch
Fig. 4-4	Nanos in a microscope turret
Fig. 4-5	Setting the SIGNAL ADJUST
Fig. 4-6	Diagram in the "Signal Adjust" Window



Fig. 4-7	The "Mode / Channel" dialog window	4-11
Fig. 4-8	Choosing the "Contact" / "Non Contact" measuring mode	4-11
Fig. 4-9	"Mode / Channel" dialog window, "Channel Selection" field	4-12
Fig. 4-10	"Linearization" field in the "Mode / Channel" dialog field	4-14
Fig. 4-11	"HIGH VOLTAGE" field in the "Mode / Channel" dialog box	4-15
Fig. 4-12	XY-Control: Setting the scan range	4-16
Fig. 4-13	P/I values for "Z-Feedback" preset with nominal values	4-18
Fig. 4-14	Setting the resolution of the acquisition scan image	4-19
Fig. 4-15	Setting the Scan Speed	4-20
Fig. 4-16	Illustration of activating a measurement channel	4-21
Fig. 4-17	"TIPAPPROACH(CONTACT)" dialog window - setting the load force	4-22
Fig. 4-18	Explanation of Adjustment of the "Load Force" Bearing Strength	4-23
Fig. 4-19	Load force adjustment in the Signal Adjust Window	4-24
Fig. 4-20	"TIPAPPROACH(NONCONTACT)" DIALOG FIELD WITH A RETRACTED TIP	
Fig. 4-21	Illustration of the "Operating Point Adjust" meter versus slider function	4-28
Fig. 4-22	The "Frequency selection" Dialog Window	4-29
Fig. 4-23	Setting the Free Resonance Frequency	4-30
Fig. 4-24	Setting the "Excitation" Factor	4-31
Fig. 4-25	Cantilever Oscillation Amplitude at the Interferometer Signal	4-34
Fig. 4-26	Setting the "SET POINT" and "FREE AMPLITUDE"	
Fig. 4-27	Theoretical Amplitude Run of the Resonance Curve	4-36
Fig. 4-28	Function of the "Z-Range" Indicator	4-40
Fig. 4-29	Image acquisition in the ScanPanel	4-41
Fig. 4-30	Setting the "Display Sensitivity" Slider	4-42
Fig. 4-31	Setting the Z-Feedback loop control	4-44
Fig. 4-32	Input field for the scan speed, "Scan Speed"	4-47
Fig. 4-33	Status bar of the Main Window, Displaying the Tip Speed in $\mu\text{m/s}$	4-47
Fig. 4-34	Monitoring the "Range" Display	4-48
Fig. 4-35	Dialog Box (S AVE)	4-51
Fig. 4-36	Choosing the next scan area within the last image or in the "X/Y Control" t	field 4-52
Fig. 5-1	Screen sectioning of the ScanPanel main window (see text for details)	5-1
Fig. 5-2	Tool Bar of the main window	5-3
Fig. 5-3	The diagram to display a profile; "Oscilloscope window"	5-5
Fig. 5-4	Rangemeter	5-6
Fig. 5-5	Slider P and I for Z-Feedback adjustment	5-6
Fig. 5-6	Slider "Display Sensitivity"	5-7
Fig. 5-7	Input field "Scan Speed" - number of recording lines per second	5-7
Fig. 5-8	Input field "Z-Gain" - percentage of maximum Z-Range	5-7
Fig. 5-9	Scaling up/down the selection frame proportionally	5-10

List of Illustrations



Fig. 5-10	Context Menu for the selection frame	. 5-11
Fig. 5-11	Scaling up/down the selection frame from one corner	. 5-12
Fig. 5-12	Scaling height or width of the selection frame separately	. 5-13
Fig. 5-13	Shifting the selection frame	. 5-14
Fig. 5-14	Turning the selection frame	. 5-15
Fig. 5-15	Coordinate system of the set scan range and maximum scan range (vers. 1.1p)	. 5-16
Fig. 5-16	ScanPanel Status bar (left side) with three different indications	. 5-17
Fig. 5-17	ScanPanel Status bar (right side), one example	. 5-17
Fig. 5-18	The dialog field "Slider Properties"	. 5-18
Fig. 5-19	Step profile using Auto Slope	. 5-19
Fig. 5-20	Step profile using Auto Slope	. 5-20
Fig. 5-21	Step profile using Auto Mean	. 5-21
Fig. 5-22	PLANE CORRECTION (AUTO) DIALOG WINDOW	. 5-21
Fig. 5-23	PLANE CORRECTION (MANUAL) WINDOW.	. 5-22
Fig. 5-24	Settings for the metrology sensor (also called Z-Sensor).	. 5-23
Fig. 5-25	Settings for additional hardware, supplying an external voltage.	. 5-24
Fig. 5-26	Acquisition Delay Time window	. 5-26
Fig. 5-27	Acquisition Delay Time countdown	. 5-26
Fig. 5-28	"Auto Save Options" dialog window	. 5-27
Fig. 5-29	Options dialog for automatic tip retraction	. 5-29
Fig. 6-1	Hand wheel for Z-Approach	6-3
Fig. 6-2	Plugging out the scanning head (3 photos)	6-3
Fig. 6-4	Photo from the PICOStation	6-4
Fig. 6-3	Example for base plate (Ring)	6-4
Fig. 6-5	Cantilever plug (4 photos)	6-5
Fig. 6-6	Liquid Plug change (4 photos)	6-6
Fig. 6-7	Tools to change tips	6-7
Fig. 6-8	Cantilever connector	6-7
Fig. 6-9	Adjustment structure (alignment chip) (1), Tip (2), Tip inserted correctly (3)	6-7
Fig. 6-10	Cantilever Chip taking out from storage box	6-8
Fig. 6-11	Cantilever-Chip inserting, frontwards (left) or sidewards (right).	6-8
Fig. 6-12	Aligning the cantilever chip (right); position check by touching from top (left)	6-8
Fig. 6-14	Connector storage box	6-9
Fig. 6-13	Closing the spring clip for the cantilever chip	6-9
Fig. 6-15	Connector insertion to scanning head	. 6-10
Fig. 6-16	Screwing cantilever connector	. 6-10
Fig. 6-17	Liquid plug storage	. 6-11
Fig. 6-18	Connector plug insertion	. 6-11
Fig. 6-19	Liquid plug electrical connector	. 6-11



Fig. 6-20	Screwing liquid connector	6-11
Fig. 6-21	Head insertion to quick snap	6-12
Fig. 6-22	safety screw at quick snap	6-12
Fig. 6-23	Centering and calibration sample	6-13
Fig. 6-24	AFM image of the centering sample	6-13
Fig. 6-25	Optical lens with centering adaptor	6-13
Fig. 6-26	Situation before centering	6-14
Fig. 6-27	Centering the optical lens	6-14
Fig. 6-28	Situation with correct centering	6-14
Fig. 7-1	Menu "LINEARIZATION"	7-3
Fig. 7-2	Example for diagram before and after correctly adjusted "LINEARIZATION TAB	LE"7-5
Fig. 7-3	Scanner movement with "X/Y-Feedback" loop switched off	
Fig. 7-4	Diagram dialog window Z-Sensor	7-12
Fig. 7-5	Potentiometer for amplifier offset of the Z SENSOR	7-13
Fig. 7-6	Dialog window PHASEDIFFERENCE	7-14
Fig. 7-7	Phase image example (from the centering sample).	7-16
Fig. 7-8	Display window for Calibration values	7-18
Fig. 7-9	Dialog window "Calibration"; register "XY-Calibration".	7-20
Fig. 7-10	Calibration image with inserted frame ("Tracker") for XY Calibration.	7-22
Fig. 7-11	Dialog field "Pitch"	7-23
Fig. 7-12	Dialog field "Calibration", register "Z-Calibration"	7-23
Fig. 7-13	Dialog field "Calibration", register "Z-Calibration" with cross section.	7-24
Fig. 7-14	Cross section for calibration of the Z-Range with markers	7-24
Fig. 7-15	Dialog menu for input of calibration values	7-26
Fig. 7-16	Dialog field "Pitch"	7-27
Fig. 7-17	Dialog field "Contrast"	7-28
Fig. 7-18	Dialog field "CALIBRATION - Spring Constant"	
Fig. 7-19	Dialog window "ALIGN"	7-30
Fig. 7-20	Cleaning the ferrule under magnifier or microscope	7-32
Fig. 8-1	Bruker Nano centering and calibration sample (from 2006 on)	8-1
Fig. 8-2	Power supply connector at SCANControlC	
Fig. 8-3	SCANControlC - rear panel (scheme)	8-5
Fig. 8-4	Lemo Input connectors SCANControlC	
Fig. 8-5	Connectors for optional read in channels	8-7
Fig. 8-6	Signal output connectors SCANControlC	
Fig. 8-7	Output connectors SCANControlC (continued)	8-9
Fig. 8-8	Main connectors for Nanos measuring head	8-10
Fig. 8-9	Connector for coarse approach step motor	8-12
Fig. 8-10	USB-connector	8-14



Fig. 8-11 connector for optional devices	8	3-1	15
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Please follow the safety regulations, summarized in this chapter. Please read here, which advises of danger, warnings and caution must be considered to use this device.

1.1 Warnings on the rear of the device



Fig. 1-1 Warnings on the rear of the device

- 1 Warning: laser radiation. The emitted radiation at the light conductor outlet classifies the device as Laser class 1.
- 2 Risk of blinding from lasers. Always keep the shutter of the optical fiber connector closed. Do not look into the laser beam, not even with optical instruments!
- 3 Dangerous electrical energy at the scanner connector
- 4 Dangerous electrical energy at the mains connector
- 5 Unplug mains before open



1.2 Hazard warnings



	Danger: electrical hazard
©=⊅-	Always disconnect the system from the mains before starting maintenance work.
	Unplug mains before open.
	Danger: electrical hazard
	Only replace blown fuses by fuses of the same type.
/7	Do not connect a damaged system to the mains.
	Do not switch a damaged system on.
	Do not repair a damaged system on yourself.
	Incorrect service
	Incorrectly performed service can lead to serious inju-
	ries. Service work may only be carried out by Bruker Nano. approved service personnel.
	Dangerous development of heat
	Always keep ventilation slits free. Clean filter pad in the fan inlet housing regularly.
	An excessive development of heat can lead to over- heating and fires.





A DANGER

Mains voltage in Europe

The device may only be operated with an operating voltage of 220 V - 240 V / 50 Hz. Any other operating voltage will destroy the device.

Make sure that the operating voltage set in the factory corresponds to the local power connection.



A DANGER

Mains voltage in the USA

The device may only be operated with an operating voltage of 110 V - 120V / 60Hz. Any other operating voltage will destroy the device.

Make sure that the operating voltage set in the factory corresponds to the local power connection.



A DANGER

Mains voltage in other countries

The device may only be operated with an operating voltage of 110 V - 120V / 60 Hz or 220 V - 240 V / 50 Hz. Any other operating voltage will destroy the device.

Make sure that the operating voltage set in the factory corresponds to the local power connection.



1.4 Warnings



Switch the device off immediately and unplug from the mains if you detect an excessive development of heat or the smell of burning.
Measurements in liquids and on wet samples may only be performed with the liquid type of the Nanos. Otherwise the Instrument may be damaged and the operator takes a risk of electric shock.



	Risk of blinding from lasers
	Always keep the shutter of the optical fiber plug clo- sed.
	Do not look into the laser beam, not even with optical instruments!
	The whole instrument comes to Laser Class 1, the in- built Laser alone comes to Class 3a
	Risk of crushing
	There is a risk of crushing when the coarse approach motor works. This is likewise for additional motorized stages. If so, follow their additional safety advises.



In this chapter, the functionality of a Scanning Probe Microscope in general and the special characteristics of the Bruker Nano stage "*Nanos*" are explained.

Terms, which are defined in the text, are printed in **bold** letters.

Designations which appear as adjustable parameters in the user interface Scan-Panel are set in SMALL CAPITAL LETTERS.

2.1 Scanning Probe Microscopy in general

The *Nanos* measuring system is a Scanning Probe Microscope. With such microscopes no direct optical images are produced (in contrast to optical microscopes). Images are generated artificially by a computer.

The term, **Scanning Probe Microscope (SPM)**, characterizes microscopes which record image information from a sample surface using a rastering motion point-to-point across a small range. A probe measures, at each point, one or more measured variables in its near field of interaction as image information. The recorded data can be displayed using image processing software as brightness values or color values for each pixel.

The term "**probe**" is used as a general term for all possible kinds of point-wise measuring sensors. A further generalized name for Scanning Probe Microscopy is the term "**SXM**", whereby the X stresses the possibility of scanning several types of characteristics. This term must not be confused with "Scanning X-Ray Microscopy".

With adequate probes and measuring modes it is possible to record locally a multiplicity of sample characteristics. Depending on the kind of recorded characteristic, special terms are used for each kind of SPM or its measuring modes respectively.

2.2 Cantilever based Scanning Probe Microscopy

Cantilever based SPMs use a very fine **tip**, seated on a bar like spring, as a probe. From its shape, this bar like spring is called **cantilever**. Such cantilevers can support a large variety of probes.

One example can be found in one of the static measuring modes of the *Nanos*. Here the tip presses with the spring force of the cantilever towards the sample surface. The spring force or **load force** results from the deflection of the cantilever described by Hook's law. The deflection is measured by an appropriate detector.

With this force detection principle, the measuring system can be called a Scanning Force Microscope (SFM). The *Nanos* has evolved from this.

The scale of structures, measured with this microscope, is nearby the size of atoms. The force interaction between sample and tip is based on inter atomic



forces. The primary name for these types of measuring systems is **AFM** (for **Atomic Force Microscope**).



Fig. 2-1 Sketch of the measurement principle in static mode

There are numerous spin-offs of the AFM technique with numerous cantilever based probes available. Most of these techniques are supported by default, or as options, by the *Nanos* measuring system.

For example magnetization (MFM; Magnetic Force Microscopy) or electrical fields (EFM; Electrostatic Force Microscopy) of a sample can be investigated with the optionally available Field Contrast mode. Certain *Nanos* systems also support non-cantilever based modes too; e.g. "**STM**"; **Scanning Tunneling Microscopy**. Separate manuals are available for systems sold with these capabilities.

2.3 The tips

Instead of "probe", the more descriptive term "**tip**" is often used in this manual when discussing probes used in the *Nanos*.

Tips for the *Nanos* have three substantial characteristics, i.e. three inseparable parts:

- The **tip** itself is the fine point, with which the surface is scanned.
- The **cantilever** fulfills the function of a leaf spring. The tip is situated at this leaf spring or cantilever.
- The **cantilever chip** is the substrate. The cantilever and tip are micro manufactured, e.g. as part of the creation of the substrate.

The cantilever chip, cantilever and tip are made of one part. These are the most sensitive parts of the *Nanos* unit.





Fig. 2-2 The "tip": cantilever chip with cantilever and tip

The individual characteristics of the unit can not be dismantled. Thus, this unit is called the "tip" or "cantilever" or "cantilever chip" or "probe"; depending on which characteristic one would like to stress. In this manual, the term "tip" is used for the unit unless another characteristic needs to be stressed.

One important factor for the characterization of a tip is the **tip radius** (see Fig. 2-3).



Fig. 2-3 Illustration of the tip radius definition

A typical value for the tip radius of a standard tip for the Nanos is 10 nm.

2.4 Tip positioning by piezo actuators

The point-wise and line by line positioning of the tip across a sample surface is called **raster scanning** or **scanning**. The scanner is the actuation unit, which implements this movement. The scanner normally consists of **piezo actuators** (piezos), which are the motive elements. Piezos make ultra fine scanner movements possible with highest resolutions (< 0.1 Å).

A piezo, as it is used here, consists of electrically polarized ceramics. Applying a voltage to the electrodes of the piezo leads to an elastic stress in the ceramic material. The ceramic material is flexible. It deforms, until the absolute force values of the mechanical stress and elasticity are equal. Positive or negative voltage applied to a piezo actuator generates extension or contraction. In that way it can be used as an actuator. The next illustration shows the piezoelectric effect, by which these actuators work.





Fig. 2-4 Example on the deformation of a piezo by positive and negative voltage

A **scanner** can be constructed from separate piezos or from a single piezo with multipart electrodes. It moves the probe in three dimensions: in-plane with the surface (the **X-Range** and **Y-Range**) and perpendicularly to the surface, in height (the **Z-Range**) vertically. An example of a single-piece three-dimensional scanner is the standard tube scanner of the *Nanos*. This is represented in the next illustration.



Fig. 2-5 Design of a standard tube scanner

2.5 The concept of the Nanos

The essential parts of a Scanning Probe Microscope were integrated in a chassis, which looks similar to an optical microscope objective. This measuring head alone is also-called the **Nanos**.

The *Nanos* measuring head comprises a major part of the *Nanos* measuring system, together with the **SCAN**Control**C** controller, and a computer, loaded with the software ScanPanel. The measuring head is mounted on a high rigid, usually customized stand, operated on a fully isolated platform.





Fig. 2-6 Illustration of the Nanos

- 1 Sample surface
- 2 Probe or tip
- 3 Scanner end protruding from the Nanos body
- 4 Nanos body

The *Nanos* can be adapted, like an optical objective, to most optical microscopes. Because of its compact design, the *Nanos* can be combined with numerous other methods for the investigation of surfaces.

This compact design is possible through the use of fiber-interferometric detection and a specially constructed tip holder. With this design, the tip can be moved across a static mounted sample surface. In conventional designs the sample is moved across a statically mounted tip, which strongly limits the specimen size.

2.5.1 Interferometric detection

A characteristic of the *Nanos*, compared to conventional systems, is the method by which the deflection of the cantilever is detected. The detector used for this is a **fiber-optic interferometer**.

This detection method is a key to the compact design of the measuring head without any compromise for its resolution. This detection method also offers you freedom from adjusting vibration sensitive mirrors in contrast to a laser



beam deflection detector.

Essentially the end of a fiber-optic cable is positioned at the measuring head for detection. This fiber end is positioned approximately d \approx 50 µm above the up side of the cantilever. The fiber-optic cable is connected to the controller, where all remaining components of the detector are located (see next illustration).



Fig. 2-7 Illustrated principle of fiber-interferometric detection

Function of the detector

The **SCAN**Control**C** controller contains a laser, which produces monochromatic light with a wavelength of $\lambda \cong 790$ nm. This is linked into the fiber-optic cable. The light is transmitted via the fiber to the *Nanos* measuring head.

The light is reflected from two planes: the first plane of reflection is from the planar end of the fiber. The wave reflected here can be referred to as **reference wave**. The second reflection plane is the up side of the cantilever. The wave reflected here can be referred to as the **detected wave**.

Both reflected light waves interfere with each other. They are transmitted back to the electronics via the fiber-optic cable. The total intensity is detected in the controller by a photo diode and processed as an interferometric signal (**Interferometer Signal**). This interferometer signal depends on the phase difference caused by the optical retardation (i.e. the optical path length difference) between the reference wave and the detected wave.

If we let A and B be the amplitudes of the two reflected waves **A** and **B** and let $\Delta \phi$ be their phase difference, then they add up vectorial to the total intensity (I)



in equation (1) below:

$$I = |\mathbf{A} + \mathbf{B}| = (A^2 + B^2 + 2 \cdot A \cdot B \cdot \cos \Delta \phi)^{\frac{1}{2}} \text{ law of cosine}$$
(1)

The superposition of the reflected waves can be described schematically, as in the following illustration.



Fig. 2-8 The fiber interferometer: intensity I(d) for three different cantilever distances d.

Let the overall distance between the two reflection levels be **d**. It divides into an offset $\mathbf{d_0}$ and a cantilever deflection by the offset $\mathbf{d_i}$, i.e. $d = d_0 + d_i$.

The phase shift between the two reflected waves amounts to $\Delta \varphi = 2 \cdot d_{i_i}$ since the light covers the distance twice; forwards and backwards. If, for example, the distance between the two reflection levels shifts to half a wavelength ($\lambda/2$ = 395 nm), the optical retardation between the interfering light waves shifts to twice this amount; one full wavelength.

Drawn from equation 1, above, the interferometer signal is a sinusoidal periodical function of the distance d with the period $\lambda/2$.

Plotted as a function over the distance $d_{\rm i},$ the interferometer signal appears as shown in the next figure:





Fig. 2-9 Interferometer signal plotted over the deflection

The sensitivity of the detection varies over d_i with the same periodicity as the intensity. This is also shown in the illustration: during the largest change of intensity the largest sensitivity of the detector is reached. In order to adjust the sensitivity of the detector optimally, the distance d needs to be optimized. This is done by a small piezo, which is called the **cantilever piezo**. Its function is described below.

2.5.2 The role of the cantilever piezo

The **cantilever piezo** is another actuator, which can move the tip vertically; it works independently from the scanner motion and it has different functions:

- The interferometer signal can be adjusted by the cantilever piezo to its optimal sensitivity.
- The load force for the static (CONTACT) mode gets adjusted by the deflection of the cantilever piezo.
- In the dynamic (NON-CONTACT) mode the tip works as a mechanical oscillator. The tip excitation is produced by the cantilever piezo.

The next diagram demonstrates the function of the cantilever piezo.





Fig. 2-10 The role of the cantilever piezo.

By applying a voltage (V) the cantilever is moved relative to the end of the optical waveguide; the distance d(V) is adjusted.

The tip is mounted in its tip holder, which is called the **cantilever-plug** or **cantilever connector**. The cantilever-plug contains the cantilever piezo.

2.5.3 Replacing the tips without adjustment

The tip needs to be replaced regularly as a function of wear. When mounting the tip, no mechanical adjustment needs to be made. On the cantilever chip are etched grooves (see next illustration). The cantilever chip is placed upon another chip, which has positive platforms matching the negative grooves of the cantilever chip. This other chip is called **alignment-chip**.

The cantilever chip sits with micrometer-precision on the alignment-chip. This is provided by the slant edges on the alignment-chip. For tip changes, the tip is simply removed from the alignment-chip and another tip is inserted. No further adjustment is necessary



Fig. 2-11 Alignment-chip and tip: Drawing, sectional view (sketch), and photography



Performing the tip change, is described in the chapter "Tip Changes".

2.5.4 The compact tip holders

The tip holders for the *Nanos* are called **cantilever-plugs**. The adjustment-free cantilever-plugs are constructed very compactly. They are another key to the compact, high-resolution, design of the *Nanos*.

The cantilever-plugs are plugged in at the end of the scanner. Their design is described in the following.

The end of the optical fiber lies protected in a specially manufactured ceramic ferrule. The cantilever-plug is put on the end of the very hard and resistant ferrule at the scanner end. It is attached with an allen key screw to the scanner. The cantilever-plug supports the cantilever piezo. On the piezo the alignment-chip is factory mounted within micrometer precision.



Fig. 2-12 The cantilever-plug; left side: sectional view, right side: three dimensional view

The tip is fixed on the alignment-chip by a clip, i.e a **retaining spring**. For comfortable tip changes, the retaining spring can be uplifted by loosening a small screw (see Fig. 2-12). The new tip only needs to be inserted correctly into the alignment-chip. The tip is affixed by tightening the retaining spring. The lateral and vertical distance to the optical fiber end are correctly positioned without further adjustment.

For the investigation of samples fixed in an aqueous solution, a special design of the cantilever-plug and of the *Nanos* measuring head is available. In this liquid measuring head, all contacts are isolated and waterproofed. The special cantilever-plugs are called **liquid-plugs**. They are equipped with a cable to exclude pins from the liquid area. The associated *Nanos* measuring head is called a liquid-scanner.



2.5.5 Static and dynamic operating modes

The available measuring modes for the *Nanos* are divided into two main principles. One differentiates between static measuring modes (setting "CONTACT MODE") and dynamic measuring modes (software setting "NON-CONTACT MODE").

The NON-CONTACT MODE is already an extension of the system by another module. The basic CONTACT MODE and NON-CONTACT MODE are described in this manual. Further special modifications and other modes are described as an extension in other manuals, which belong to their respective modules.

<u>CONTACT MODE</u>: The tip presses on the sample surface while scanning. The deflection of the cantilever is static. On active Z-feedback, the cantilever is moved with constant cantilever deflection across the sample, and thus with constant load force. This is called "constant force mode". In contrast, scanning with deactivated or very slow Z-Feedback in the CONTACT MODE is called "constant height mode".

The following illustration shows CONTACT MODE, i.e. the static deflection of the cantilever by its contact to the sample.



Fig. 2-13 Static cantilever deflection: CONTACT MODE

<u>NON-CONTACT MODE</u>: The method allows for less wear on the tips, since no load force or friction force appears. The tip is oscillated via excitation of the cantile-ver-piezo (see following illustration). The distance between tip and sample can be controlled by the amplitude of the cantilever.



Fig. 2-14 Dynamic cantilever deflection: NON-CONTACT MODE

The tip should trace the topography of the sample during raster scanning as pre-



cisely and as free of wear as possible. To protect the tip against unnecessary wear, it is moved actively across obstacles and through pits. The main difference between the operating modes is how the feedback loop works. This is described in the following chapter.

2.5.6 The digital Z-feedback

The interferometer signal determines the position of the tip. The feedback of the cantilever deflection upon the height deflection of the scanner, is done by a closed loop feedback control.

Here the feedback loop control is called the **Z-feedback**. Like other loop controllers with the *Nanos* it also works digitally. That means the loop control operates as software in the digital signal processor (DSP).

Cantilever deflection may be divided into static and dynamic deflection. **Dynamic deflection** means that the cantilever is oscillated for dynamic measuring modes near its resonance frequency. **Static deflection** designates, however, that the deflection of the tip is achieved by a force without vibration excitation.

<u>Static operating modes (setting "CONTACT"):</u> the cantilever deflection is controlled at a preset constant value, the setting "LOAD FORCE". Cantilever deflection is determined by the interferometer signal. The interferometer signal is a value for the static cantilever deflection and thus for the active load force.

Deviation from a target value is transmitted as a so-called "ERROR SIGNAL" to the automatic closed loop Z-feedback. It controls the vertical deflection of the scanner towards its input signal. In other words, the Z-feedback works inversely to the deviation of the target value.

<u>Dynamic operating modes (setting "NON-CONTACT"):</u> the feedback loop reacts to amplitude changes of the interferometer signal.

First, the interferometric detector forms the RMS value of the interferometer signal. This amplitude is a measure of the distance between tip and sample. Second, the deviation of the amplitude to a target value (the SET POINT) is formed. This so-called "error signal" is transmitted to the automatic closed loop Z-feedback. The Z-feedback works, in any case, inversely to its input signal, the so-called "error signal".

Another dynamic mode that should be mentioned is the optional frequency mode (FM Control). Using this mode, tip excitation is stimulated with its momentary resonance frequency. The target value of the Z-feedback is therefore a constant frequency. The optional module, the "FM-Control", produces the input signal for the Z-feedback, fed into the ScanControlC unit. The Z-feedback is controlled via an external signal.

The following sketch of the scanner, mounted over the sample, shows the operation method of the Z-feedback for both settings; CONTACT and NON-CONTACT.




Fig. 2-15 Z-FEEDBACK: the components of the closed loop feedback.

Ideally, the deflection of the scanner compensates for the variation of the detector signal; that means the "Error Signal" is ideally zero during scanning. Naturally, the sensitivity of the feedback can not be boosted to an infinite level, but only up to a certain limit.

The feedback sensitivity can be adjusted by two parameters. These are the proportional gain, \mathbf{P} , and the Integral part, \mathbf{I} , (i.e. inertia) of the closed loop control.

The Z-feedback output data are called the height data, topographic data or the z-position data. They are recorded as raw data. These data can be imaged as a frame in the computer.

All recordable measurements can be selected in the software as respective measuring channels. The topography is always preselected as the first measuring channel for recording.

Depending on the kind of tip, and the selected operating mode the *Nanos* is able to record additional information of the sample surface synchronized with the topography (e.g. electrical resistance, magnetic strength, frictional force, elastic strength, etc.). For recording these additional values, appropriate measuring channels are available. Similarly to the topography the additional information can be displayed as an image on the computer screen.

2.5.7 The Scanners

To move the tip in three dimensions, single-piece and multipart scanners are used. Two different designs are used in the *Nanos*:





Fig. 2-16 Tube-scanner (I.); Z-only-scanner with scanning stage (r.)

The *Nanos* **tube scanner** is a single piece ceramic tube with separate electrodes. The scanner is fitted into a body, similar to a microscope objective lens. With the sample fixed into place, the tip moves in all three dimensions. This scanner version has universal applications compared to the scanning stage system described in the next paragraph. The single piece scanner is suitable for smaller scan ranges. Because of that it can achieve higher resolutions than the large range systems with integrated scanning stages.

The *Nanos* Z-only-scanner, used in combination with an XY-scanning stage, is a multipart scanner system. The so-called **Z-Scanner** in the *ULTRA*-Objective measuring head moves only vertically. The sample is fixed on a **scanning stage**. The scanning stage provides the lateral positioning of the sample under the tip. These scanner systems achieve larger maximum scan ranges. The Z-Scanners have better dynamics than the tube scanners. They reach their deflection faster and with a higher Z range. In these systems the Z-positioning is de coupled more effectively from the lateral positioning.

Note: Piezo scanners consist of very sensitive ceramic components. Respect the possible danger of breakage, in particular with impact -, shear -, and percussive powers.

2.5.8 The scan pattern

The following figure shows the scan pattern of lateral raster scanning tip movement. On the basis of this figure, some terms about the scanning process will be explained. The scan range in this example is 16 x 16 pixels.





Fig. 2-17 Scan pattern of a 16x16 pixels scan range. The arrows are shown as curves only for descriptiveness.

With the *Nanos*, the positions where Data are to be recorded, are actuated one by one. They are called **scanning spots (or pixel)**. In the illustration above, the points in the grey supported area show these scanning spots. Each of these points corresponds to a **pixel** of the computer generated image.

The **maximum scan range** is limited by the design of the piezo scanner. It is limited due to the maximum possible deflection of the piezo actuators. At the *Nanos* system the desired scan range is selectable within the maximum scan range.

The set **scan range** is the range for scanning, set in the ScanPanel user interface. It is the range, where image data are recorded. It is marked by the grey supported area in the figure above. It is usually selected quadratically, although, with the *Nanos*, the edges of the scan range are independently selectable, as the parameters **X-RANGE** and **Y-RANGE**. That means the scan range can be a rectangular area. The position of the frame within the maximum scan range can be selected by the parameters **X-OFFSET** and **Y-OFFSET**. The rotation angle of the frame with respect to the maximum scan range can be selected by the parameter **ANGLE**.

The ScanPanel user interface also makes it possible to select these parameters also graphically, i.e. by opening up a frame (a so-called **tracker**) and positioning it comfortably with the mouse. The tracker can be positioned either across the last recorded image or across the maximum scan range.

The **image resolution** or the **pixel resolution** is the number of recorded pixels for one frame. In the figure above the image resolution is 16x16 lines by points. Realistic frames are recorded with 400x400 pixels. The software currently limits the maximum image resolution with the *Nanos* system to 1024x4096 pixels.



The **MARGIN PIXELS** are the pixels to the left and to the right of the grey supported area in the figure. Even though the tip moves across this range, no data are recorded. The number of MARGIN PIXELS or the margin range (**MARGIN WIDTH**) can be adjusted in the software. The MARGIN PIXEL adjustment is used to avoid tip effects from directional changes.

The "**Slow-to-start"** motion describes the initial movement of the tip to one corner of the set scan. In the illustration above this is shown by the arrow pointing from the center to the upper right corner of the frame. The scanning process usually starts at the upper right corner.

After completion of the recording, or when the stop button is pressed, the tip moves back into the center of the set scan range. The speed of the tip at the Slow-to-start movement, with the setting "LINEAR OFF", corresponds to the SCAN SPEED setting. With the setting "LINEAR ON", the situation is slightly different. The speed of the tip also corresponds to the adjusted scan speed, which is not based on the set scan range but on the maximum scan range.

The SCAN SPEED is the speed of the tip in lines per second. One **line** consists of one forward motion plus one backward motion. The speed of the tip, scaled in µm per second is also indicated as "SPEED" in the main window of the ScanPanel. The time needed to record one full image can be calculated by the number of lines in image resolution divided by the adjusted scan speed. The recording time for one full image typically amounts several minutes.

2.5.9 The linearization

The term **linearization** designates the linearly controlled scanner movement in the *Nanos* system. This closed-loop feedback can also be termed **XY-Feed-back**. For switching the feedback control on or off, one setting in the ScanPanel is used: "LINEAR ON" or "LINEAR OFF".

Piezo scanners change their deflection only approximately but not exactly linearly with an applied voltage. In fact the correlation between applied voltage and deflection is a hysteresis.

With the setting "LINEAR OFF", the voltage applied to the scanner during scanning varies linearly; i.e. with a digital system in steps with a constant width. The scanner moves approximately linearly, but only in the linear section of the hysteresis. However there is no control, in this case, of where the scanner really moves. The scanning voltages are changed "blindly".

With the setting "LINEAR OFF" the position, at which an image is recorded, depends on the position of the respective previous image. The nonlinear fractions of the scanner movement may cause typical image distortions, which do not happen with the linearization switched on.

For "Linear On" movement additional sensors, which are affixed to the scanner are used. They indicate the position of the tip within the maximum scan range and allow the system to control the position of the tip at each individual scanning spot.



The additional sensors on the tube scanner are strain gages (brit. engl.: strain gauges). Those sensors change their electrical resistance with their expansion or contraction. This function is described in the following illustration:



Fig. 2-18 Tube scanners with deflection sensors in full bridge connection (schematic)

Four sensors for each deflection direction (X or Y) are used with this tube scanner type (in the figure above only one direction is shown). The very sensitive strain gauge sensors are connected in a Wheatstone Bridge circuit. This provides optimal sensitivity. The output signal from this circuit indicates the position of the tip within the maximum scan range. This is called **DMS-Signal**.

The first amplification of the DMS-Signal takes place inside the measuring head and the second amplification occurs in the so-called **linearization box** near the measuring head. The signal-to-noise ratio becomes optimal through this arrangement of amplifiers. The DMS-Signal is A/D converted to a **DMS-Value** inside the **SCAN**Control**C** controller.

With the setting "LINEAR ON" the deviation of the DMS-Value from its target value is sent to the XY-feedback loop, which controls the lateral scanner movement. This feedback loop works like the Z-feedback.

The XY-Feedback works independently in the X and Y directions.

The maximum scan range is defined by the largest accessible scanner deflection difference, however on a different base.

With the setting "LINEAR OFF", the **non-linearized maximum scan range** is calibrated for the maximum difference of scanner output values or voltages. The scan range lies within a "voltage range".

With the setting "Linear On" the **linearized maximum scan range** is calibrated for the maximum difference of DMS input values. The scan range lies within a "DMS range".

In both cases, the maximum scan range is still reduced through consideration



of coupling factors and "MARGIN PIXELS", which are determined during the calibration.

The linearization sensors provide sufficiently high resolution, so that image distortion does not arise for large, medium, or even small scan ranges. For very small scan ranges linearization is usually not used and not necessary. The smaller the scan range, the better the approximation of a linear voltage versus deflection correlation. Therefore, for very small scan ranges the linearization is usually switched off.

Usually one wishes to first record an image with a large scan range, zooming the scan range in on an interesting feature, and eventually switching off the linearization for very small features.

When switching off the linearization, the software (starting with ScanPanel 1.1b) adapts the X-OFFSET and Y-OFFSET parameters to keep the image position constant. The offset adaptation is necessary because the maximum scan range is based on different values: in the first case on DMS-Values and in the latter case on controllable voltages.

The optional function of the **Z-sensor** operates with the same sensors, as the linearization. However this works without the feedback loop. The scanner deflection in the Z-direction can be measured point-wise by the Z-sensor. It can be recorded in an additional measuring channel. The Z-sensor measuring channel contains the height data on a linear scale. After calibration of the scale by an accurate standard, the Z-sensor option makes exact metrology investigations possible.

2.5.10 The stand

The *Nanos* measuring head can only be operated on a suitable **stand**. For the *Nanos* measuring system, stands like the *Neos (NanostationII)* and the Argos (*PICO*Station) are available.

The resolution of the system depends heavily on the mechanical stability of the stand and its mechanical and acoustical absorption. Particularly, highly rigid granite stands, developed by Bruker Nano GmbH, are most suitable. The *PI-CO*Station has a compact design for highest resolution. The stands of the Neos, Argos, Rados and Titanos (*NANO*Station series models I, II, 150, 150s, 150HD, 300) are used in combination with optical microscopy and for automatic sample positioning.

In order to automate the **approach** between the tip and the sample surface, the stand is equipped with a motorized vertical drive as a basic equipment. During approach, the distance between the *Nanos* tip and the sample surface is reduced by software control, until the tip is in its measuring position. The automatic approach is more reliable and finer than manual adjustment.

2.5.11 The controller

The control unit is designed for very high resolution signal processing. It is de-



veloped on a modular base. Digital and analog circuitry components were carefully galvanically de coupled. Power main adaptors and voltage supplies are additionally shielded.

Signal processing in the controller is digital (50 MHz, 32 bits DSP). The analog components are limited to several filters and amplifiers.

Input voltages are digitized in each case by a single 16 bit A/D converters. The deflection voltages for the lateral scanner movement are each produced by three 16 bit D/A transducers. They make it possible to independently set the size of the scan range (gain), the position of the set scan range (offset) and to perform the scanning. So, the scan range is always 16 bits long. The output voltage for the vertical scanner movement (Z-movement) is converted by means of two 16 bit D/A converters (z-output and gain).

All closed-loop feedback controllers are realized in software. The sampling rate for the Z-feedback and the linearization is usually set to 30 kHz. One exception is, for example the optional friction force mode (longitudinal force modulation). The Sampling rate is set to 20 kHz for this mode, due to technical reasons.



Fig. 2-19 Module architecture of the **SCAN**ControlC

2.5.12 The software

The user interface is part of the control and acquisition software ScanPanel for the *Nanos* measuring system. The user interface is based on Windows.

The ScanPanel drives the image recording and the communication with the Controller **SCAN**Control**C**. The ScanPanel also contains the software for the digital signal processor (**DSP**). It is transferred into the controller whenever the



ScanPanel program is opened. The controller is connected to the PC by USB.

2.6 Resolution and magnification in SPM

The **resolution** of a microscope is usually defined by the smallest distance between two features on a sample, that can be just kept apart in a magnified image. The resolution is limited in optical microscopes to the order of magnitude between [0.1... 1 μ m]. This is because of the aperture of optical lenses which is given also by the size of visible light wavelength,

Aperture does not affect image resolution in Scanning Probe Microscopy. This enables, in principle, lateral resolutions down to the atomic scale (< 1 nm). Resolution in the Z-range is always much more precise.

The resolution of a Scanning Probe Microscope depends mainly on the following factors:

- the tip quality,
- the positioning accuracy of the scanner,
- the rigidity and stability of the stand
- the environmental conditions (e.g. floor vibrations),
- the kind of used sample itself.

The components of the *Nanos* are optimized to enable the highest technically feasible resolution in air and at room temperature.

One differentiates with Scanning Probe Microscopes between lateral and vertical resolution. The vertical resolution is principally higher than the lateral resolution. The lateral resolution depends in particular on the surface structure of the samples that are to be investigated.

Lets assume a sample is smooth, except for some obstacles. If the tip fits between the obstacles, it is still possible to resolve structures smaller than the tip radius. In contrast, if the structures on the sample are laterally so close together that the tip does not fit in between them, it is no longer possible to resolve this structure.

The **magnification** of a microscope can be defined as the ratio between the output image size (e.g. at the screen), and the set SCAN RANGE. The smaller the set scan range, the higher the magnification.

The scan range can be set so small, that the distance between two pixels becomes smaller than the available resolution. In this case the recorded images do not show real structures any longer.

At the limits of image resolution, interpretation of SPM images can be more complicated. What an image truly shows, can only be determined by an experienced observer.



2.7 Preparation of the samples

It is not necessary to prepare the samples particularly beyond making sure that the surface to be analyzed is easily attained by the tip, as follows.

Suitable samples for the *Nanos* may not be covered, as is common in light microscopy. Also, thin additional layers (e.g. oxidation) on the surface can hinder measurement or need to be considered.

The surface of a sample must be firm, very clean, and free of grease and dust, in order to enable imaging via Scanning Probe Microscopy.

The surface parts, which are to be scanned, must be affixed in as stable as possible on the sample holder; they must not move. The scanning direction of the scanner lies preferably in plan with the sample surface. That means, samples must be affixed as even as possible on the sample holder.

The smoother the surface, the better the resolution.

Chapter 2



Introduction



3.1 System components at a glance

The measuring set-up for the *Nanos* system consists of the following components:

- The *Nanos* is the measuring head for the scanning probe microscopy of a sample
- A stand for the *Nanos*, e.g.: *Bruker Nano*, *PICO*Station or a stand with motorized height adjustment recommended by the Bruker Nano GmbH
- The measuring electronics *SCAN*Control *C* to control the *Nanos*
- The Linearization Electronics to amplify signals near by the measuring head
- A computer to control the scanning and to output and edit the scanning images.
- An arrangement to isolate floor vibrations, e.g. an active dampening base.
- An enclosure for acoustic dampening if required (not shown in the image)



Fig. 3-1 Illustration of the measuring set-up

- 1 Computer (PC)
- 2 Measuring electronics SCANControl C
- 3 Linearization electronics (Linear2000)
- 4 optical Microscope as an example for a stand
- 5 Nanos measuring head
- 6 Motorized coarse approach
- 7 Vibration isolation



3.2 Choosing the place of installation

The selection of the installation place does have a significant effect on the system's resolution and image quality.

With scanning force microscopy the tip-sample interaction is in the range of Nanonewton. Disturbing forces must be kept as small as possible to enable a high resolution. Pay attention to the following points:

- **Place of installation**: it must be as quiet and as free from vibrations as possible. Installation in the basement or ground floor should be given preference compared to an installation in higher floors because of the smaller building vibrations. If available a separate foundation would be most suitable, de coupled from the floor pavement at a place far away from roads and large machinery. Such an ideal place is rarely available. So the vibration isolation equipment must be arranged up to the needs of your application.
- **Stability of the set-up**: the *Nanos* can only be operated on suitable stands, e.g. the *Neos*, the *Argos*, recommended microscopes, or other recommended stands.
- **Insulation against floor vibrations**: a vibration-reducing base is necessary. A suitable active system is available from the Bruker Nano GmbH. Alternatively, we recommend operation on a passively damped table. Vibrations must not be transferred via connecting cables. The cables must be fixed flat on the base but without hindering the dampening. There should be no other devices on the vibration-reducing base wherever possible.
- **Soundproofing**: a quiet, separate room is recommended. Sound absorbing carpets are recommended, although you must ensure a safe stand for the device. A soundproof chamber may improve the system. With the optional soundproofing system the adjustable device feet must be set to ensure a firm stand.
- **Few air movements**: avoid air-conditioning systems, fans, open windows, convection through heated air. Place the system away from radiators.
- **Prevention of vibration conduction**: the stand with the *Nanos* must stand apart from the computer and control electronics on a separate table. The setup should be placed away from other machines and devices. There should be no other objects on the table for the *Nanos*.
- **Constant temperature**: the chosen room should display minimal temperature fluctuations whenever possible. Protect the system against direct sunlight. No sources of heat (e.g. lamps) should be operated alongside the *Nanos*. The system should be set up at a suitable distance from radiators, windows, doors and outside walls.
- **Constant atmospheric humidity**: a fine film of condensation arises on every surface through permanent exchange processes with the ambient air. The condensation film on the sample surface can interfere with the measurements. The thickness of the film depends among other things on the atmospheric humidity (normal atmospheric humidity 30% 70%).



3.3 Connecting the system components

The electrical connections between the individual system components are described in the following on the basis of the wiring diagrams.



	Correct mains voltage
	Make sure that the operating voltage set in the fac- tory is the same as the mains voltage of your local power supplier before connecting the device.
	An incorrect mains voltage will destroy the device.



Risk of blinding from lasers

Do not look into the laser beam, not even with optical instruments!

Always keep the shutter of the optical fiber plug closed.

The device is a LASER CLASS 1 product

Note: Only use the enclosed connecting cables!

Note:	The plugs of the sensitive measuring cables work with a ring to lock and re-
	lease them. Insert and release these delicate "Lemo"-cables only by handling
	at this ring. Insert them as straight as possible.

Note: The optical fiber plug (green) has a small flap to protect the end of the fiber. This flap must always be closed before insertion to prevent damaged plugs.





3.3.1 Wiring diagram for tube scanner systems

Fig. 3-2 Wiring diagram for tube scanner systems

Α	Computer (PC)	4	Optical waveguide for interferometric detection
В	Rear of measuring electronics SCAN Control C	5	Fixed connecting cable <i>Nanos</i> - Linearization Electronics
С	Linearization Electronics (<i>Linear</i> 2000)	6	Electrostatic field electrode (optional)
D	Nanos	7	Manual sliding table
E	System components on the microscope or stand	8	Socket for "ground"
F	Motorized height adjustment	9	Sample table ground (electrostatic field electrode)
1	USB cable for PC	10	Connecting cable for motorized height adjustment
2	Connections for Linearization Sensors <u>XS</u> : sensor for deflection in X direction <u>YS</u> : sensor for deflection in Y direction <u>ZS</u> : Optional if sensor fitted for deflection in Z direction <u>GNDS</u> : connection to ground for the sen- sor <u>CPV</u> : contact for actuator below the canti- lever; " <u>cantilever piezo-V</u> oltage"	11	Mains connection for SCAN Control C measuring electronics
3	Connection for Nanos (X, Y, Z actuators)		



3.3.2 Wiring diagram for upgraded systems



Fig. 3-3 Wiring diagram for systems upraged to $\mathbf{S}CANC$ ontrol C

Α	Computer (PC)	4	Optical waveguide for interferometric detection
В	Rear of measuring electronics SCAN Control C	5	Fixed connecting cable <i>Nanos</i> - Linearization Electronics
С	Linearization electronics	6	Electrostatic field electrode (optional)
D	Nanos	7	Manual sliding table
E	System components on the microscope or stand	8	Socket for "ground"
F	Motorized height adjustment	9	Sample table ground (electrostatic field electrode)
1	USB cable for PC	10	Lead for motorized height adjustment
2	Connections for Linearization Sensors <u>XS</u> : sensor for deflection in X direction <u>YS</u> : sensor for deflection in Y direction <u>ZS</u> : Optional if sensor fitted for deflection in Z direction <u>GNDS</u> : connection to ground for the sen- sor <u>CPV</u> : contact for actuator below the canti- lever; "cantilever piezo-Voltage"	11	Mains connection for SCAN Control C measuring electronics
3	Connection for Nanos (X, Y, Z actuators)		





3.3.3 Wiring diagram for scanning stage systems

Fig. 3-4 Wiring diagram for stage scanner systems

Α	Scanning stage electronics	D	Components at the stand (e.g. microscope)
A1	Z-Scanner amplifier	D1	Nanos measuring head
A2	Linearization control	D2	Sample stage
A3	Scanning stage amplifier	D3	Scanning stage
В	Rear of electronics SCAN Control C	D4	Translation stage (e.g. hand operated)
С	Scanner connecting box	D5	Coarse approach stage (design varies)
		Е	Computer (PC)



3.4 Installation of the measuring head

3.4.1 Adaptation to an optical microscope

The *Nanos* can be operated with a suitable adaptation on almost all stable microscopes. The adaptation at the microscope nose piece includes different adapter rings. Some frequently used adapter rings are shown in the illustration below.

A **centering adapter** is included for microscopes without center able optical lenses. A **quick-snap adapter** for taking out the measuring head at tip change is used for microscopes without a removable lens turret.

Distance adapters are used to adjust the different lengths of the objectives. The thread of the *Nanos* can be adapted to all common lens thread sizes using the **thread adapter**.



Fig. 3-5 Example of components to adapt the *Nanos* to a microscope

- 1 Distance adapter
- 2 Centering adapter
- 3 Thread adapter
- 4 Quick-snap adapter (female part)
- 5 Quick-snap adapter (male part; brass ring)

Further more the adaptation comprises the equipment of the microscope focus drive with a motor for the coarse approach. This must be done at the factory.



3.4.2 Installation to another stand

Another often used adaptor can be seen in see Fig. 3-6. It is used in the PICO-Station and for many user specific stands.



Fig. 3-6 Standard adaptor for measuring head

The adaptor can be mounted with one screw. This is convenient for the tip excange.

3.5 Installing the software

3.5.1 Installation program

The control software *ScanPanel* Version 1.1 can be installed on all personal computers with a USB-interface and operation system from Windows 98 (second edition) on (e.g. Windows ME, Windows 2000, Windows XP)

Please follow the following procedure starting on the windows user interface:

1) In case of update, save system parameters

run Windows-Registry-Editor (START -> RUN -> REGEDIT). Mark the arm HKEY_CURRENT_USER/SOFTWARE/SISREGISTRY. Export this arm of the registry into a file (FILE -> EXPORT). You may recover the parameters later by importing this file.

2) uninstall any former version of the ScanPanel completely.

Start the Windows uninstalling (START->SETTINGS->SOFTWARE. Choose *ScanPanel*

Uninstall ScanPanel by using the remove button. If an old version is not displayed here it must be unregistered manually. To do so, execute the file "ScanPanel_unreg.bat. If not available you may create it from "ScanPanel_setup.bat" by inserting "/u" for each component. In this case also the USB-driver must be removed manually. (see next chapter)

Alternatively to uninstalling, the old program version can be <u>unregistered</u> only. This can be done by running the batch file "ScanPanel_unreg.bat". The old program version may be recovered later with "ScanPanel_setup.bat". Please make sure: do never have two versions simultaneously registered. For starting the



program, make sure you run only the new "ScanPanel.exe"

3) Install the new version ScanPanel 1.2.

Start the setup program BNSETUP.EXE. The setup program can be found in the main folder on the CD or it starts automatically. The setup program guides through the installation.



The installation is complete within a few mouse clicks.

Updating System	
The features you selected are currently being installed.	

Fig. 3-7 installation program



4) Load system parameters into the registry:

The specific parameters for the system need to be added to the registry for the current user. Run the adequate *.reg file. (e.g. double click). For first installation and factory updated parameters, the adequate *.reg file can be found in the folder "ScanPanel1.1/registry" on CD or separately. Otherwise use the previously saved *.reg file.

5) installing new USB driver for ScanControl C

The driver files were already copied to hard disk during installation and the driver can be installed now.

Switch on the properly connected *ScanControl C* unit.

The wizard "found new hardware" appears. Choose "search for a suitable driver" and "specify location". Choose on the Harddisk the path "ScanPanel 1.1/driver". The driver file "SISUSB.inf" is the one, which is necessary to announce as the driver file (see Fig. 3-7).



Fig. 3-8 USB-driver files on CD

After the driver is properly installed and switched on, the device manager shows the USB device *ScanControl* C (see START -> SETTINGS ->SYSTEM ->HARD-WARE -> DEVICE MANAGER).



Fig. 3-9 USB driver correctly installed

If necessary the driver can be updated or removed in the device manager. Double click on the USB ScanControlC and select the new path to the files sisusb.inf and sisusb.sys.

Now the ScanPanel user interface can be started.

4 BASIC OPERATING INSTRUCTIONS

This chapter contains a "getting started" section for beginners and illustrates the basic settings for "CONTACT" and "NON CONTACT" measurement modes. This chapter is intended to accompany one full measurement with the *Nanos* from start to finish.

The measurement should begin after an interesting area has been located on the sample. You can find interesting areas via an optical microscope (i.e. *Neos*) or other detection techniques. If your sample is relatively uniform, you may simply choose to perform a scan without an optical observation, such as may be performed with the *PICO*Station.

Note: Sample positioning with an automatic sample positioning stage is covered in a separate set of instructions included with the special stage. Instructions on additional optional measurement modes can be found in their respective manuals.

4.1 Prerequisites

The following prerequisites will help assure that the system has been properly set up:

- Assure the system's location meets the requirements outlined in Chapter 3.2,
- Assure the system is properly calibrated and adjusted (See Chapter 7),
- Assure the Nanos is mounted on a stable base (i.e. Neos),
- Assure the cantilever plug is mounted on the Nanos with an intact cantilever,
- On systems with complementary optical device assure that the centering procedure was followed already. Centering procedure for *Neos* and other microscope turret mounting see Chapter 6.
- Assure the sample is **affixed** to the sample stage so that it cannot move during the scan. Avoid soft adhesives because of potential sample drift.

4.2 Getting started

A first standard step by step measurement from switching on until switching off the system will be shown within the next sections. Each step is described in a separate section. A section shows standard parameter settings at the beginning followed by more detailes and a short explanation of the functionality of this setting. For convenience getting started, the user can skip the more theoretical explanations at the section end and simply ensure that the settings are correct before moving onto the next section. However, at some point, we recommend more complete familiarization with each setting so that the user's comfort level and expertise with the *Nanos* can be optimized.

The following **Checklist** summarizes the steps for one full measurement. More information regarding each step is provided in the corresponding sections.



Checklist of points to observe during the standard scan:

- Turn on the Computer, the vibration isolation system and the SCANControl C.
- Start the ScanPanel software.
- In conjunction with complementary system, e.g. an optical microscope:
 - Turn off what is not needed (e.g. <u>light source</u> for the optical microscope; this may be turned off automatically via the optional "*DRIVE*Control").
 - Swivel in the *Nanos* scanning head With manual systems.
 - With motorized systems move the sample under the *Nanos* scanning head; e.g. with *Rados or Titanos* systems use the Button "AFM" in the microscope window (see supplementary *stage* manual)
- Open the "SIGNAL ADJUST" window and set the "GAIN" amplification to the optimal position. Checking this window ensures that the cantilever detection works and is properly adjusted. Close the "SIGNAL ADJUST" window with "OK".
- Allow the system to warm up for at least 30 minutes
- Enable the active vibration isolation system and close the enclosure door, if applicable.
- After warm up check that the "GAIN" in the "SIGNAL ADJUST" window is still in the optimal position. Close the "SIGNAL ADJUST" dialog field with "OK".
- In the "MODE/CHANNEL" dialog window:
 - Choose: "CONTACT" or "NON CONTACT".
 - Choose: On/off "LINEAR" (for scan ranges < 1 μ m, turn off linearization; this option is only available on tube scanning systems).
 - Turn HV "High Voltage" on/off, according to your requirements.
- Choose the desired measurement channels.
- Preset the scan image resolution (i.e. 256 x 256 pixels).
- Preset the desired: "SCAN SPEED".
- Preset the approximate Proportional and Integral (PI-values) of the "Z-FEED-BACK" loop control.
- Open the "TIP APPROACH" window
- When starting in "CONTACT" mode:
 - Move the load force slider to vary the signal detection bar beyond its 50% marker and check if the z-range bar turns down. This ensures working feedback.
 - Preset the "LOAD FORCE" bearing strength. Wait up to another 30 minutes until the drift of the detected load force value is minimized.
- When starting in "NONCONTACT" mode:
 - Set the slider "OPERATING POINT ADJUST" to the correct working point.
 - Set the "FREQUENCY SELECT" free resonance.
 - Either Calibrate the amplitude value through the "CALIBRATION" menu or set "COARSE CALIBRATION".
 - Set the "FREE AMPLITUDE" excitation value.
 - Set the "SET POINT" value as a percentage of the "FREE AMPLITUDE".
 - Move the "OPERATING POINT ADJUST" until the amplitude bar undercuts the "SET POINT" marker and make sure the z-range bar turns down. This ensures the feedback working. Readjust the "OPERATING POINT ADJUST" and turn on the "AUTOMATIC".
- Check if the scanning head is in its place and mounted correctly above the sample.
- Start the automatic approach and wait until the, "Z-RANGE" indicator reaches approximately 50%. Click "OK" to exit the "TIP APPROACH" window.
- Start the measurement with a single or a continuous scan.



- Check and optimize the preset values in the *ScanPanel* (P, I, Scan Speed, etc.) during the scan to improve the scan quality.
- Rescan with proper settings until image distortion is minimized
- Save final scan and retract the tip
- Close the program and, if necessary, turn off the system or investigate other areas of the sample.



4.3 Turning On the Measurement Electronics and Computer

Note After turning on the system, a warm-up time of 30 minutes should be allowed. If the warm-up time is not allotted, there is a strong possibility of drift within the scan image. 1. Turn on the computer and wait until the operating system starts. 2. Turn on the main power switch on the front of the SCANControl C electronics. 3. Start the ScanPanel program, (e.g. by double clicking on the **desktop icon**): Note: If starting ScanPanel under a user account which has not been used with this program before, make sure the system parameters are properly loaded (see point 4 on page 3-10; loading the registry).

4. If the system is used with multiple scan heads, then the following choices will be available:

Scanner Key / Setup		
Scanner	Scanner#2	•
Setup	Nanostation	•
		Continue

Fig. 4-1 Dialog box "SCANNER KEY / SETUP"

In the "SCANNER" field, choose the actual attached scanning head. In the "SETUP" field, choose the type of system you are using.

Operating Mode:

In the "SCANNER" field, a registry (including a complete data folder with User, System, and Program parameters) can be chosen for the system. In the image above, these registries are named "Scanner #1". The system can be equipped with several of these registries for different system configurations, different users, and different applications.

In the "SETUP" field, a subfolder is selected, which contains the approach setting parameters. In the image above, this file folder is named "*NANO*-Station".system parameters are installed for the current user.

Every user with a separate logon on the PC has different hardware parameters saved in the registry. In order to make these registries available to other users, please see point 4 on page 3-10 (loading the registry).

5. The ScanPanel user interface opens (See following page).







- 1 Menu bar
- 2 Tool bar: list with icon buttons
- 3 Measurement window for selected scan range
- 4 Status bar
- 5 Z CONTROL: Settings for Z-Feedback, Oscilloscope for the measurement signal
- 6 XY CONTROL: scan range settings, scan image representing maximum scan range

Note: If the background of the line profile is displayed in green colour, please check if the system parameters (registry) are installed properly for the current user (see chapter 3).

For a detailed list of the functions for the User interface, see chapter 5.1 on page 5-1.



4.4 Swiveling in the *Nanos* (turret mount)

If your *Nanos* is mounted in a microscope turret, it is vital observe the following:

Turn off the Microscope light!

- the image can easily show thermal drift from the heat of the micros-cope light!
- to further improve the image and oscillation de coupling, you can also remove the light cable from the power supply / light source.
- Fig. 4-3 Example of a Microscope lamp switch

Pivot in the Nanos:

- Turn the turret to swing the *Nanos* into place.
- Check that the Nanos cables are correctly situated, taking particular care that they won't disturb other objectives.
- Fig. 4-4 Nanos in a microscope turret





Note: It is important that you <u>only use the turret to turn the objectives</u>. *Although it is often easier to turn the turret by holding the objectives, this habit will cause the centering calibration to be lost. Always use the turret!*

The safety margin between the tip of the *Nanos* and the sample averages about. 0.3 mm. (This is true, assuming that the correct mounting and focusing procedure was followed prior to pivoting in the *Nanos*. Other objectives must be focused on the sample and not on a slipcover or other area.)



4.5 Turning On and Activating the Isolation System

- 7 Eliminating interference sources: Remove all unnecessary objects from the microscope base and the isolation system. Check that the measurement system moves freely on the isolation base. Cables must be tightly attached to the table and support base for the isolation system. In the transition area between the base and the isolated area, the cables should <u>not be tight</u>, so that the mechanical coupling is as light as possible. If necessary, remove unnecessary cables (such as cable for the light source).
- 8 <u>Activating the isolation system</u>: more precise information can be found for different isolation systems through their respective manufacturers. The following are general notes:
- Activating the MOD1 isolation system:
 - Turn on the power (switch on the back of the isolation system).
 - Check the weight balance / mass centering. Springs for the levelling system are set through four hex screws on the sides of the isolation system. It is important to make certain that the springs are as equally stressed as possible and that they are not unequal or unbalanced.
 - Activate the active isolation (switch on the front of the isolation system).
- Activating the Micro 40 / Mod 1 plus isolation system:
 - Turn on the power (switch on the back of the isolation system).
 - Activate the switch for the automatic levelling (switch on the front of the isolation system).
 - Allow the system to drive itself from its transport locking position (indicated with a red LED) to its levelled position (indicated with a green LED).
 - Turn off the automatic levelling (indicated with a yellow LED).
- Activating the TS140/TS150 isolation systems:
 - Turn on the power switch (on the front of the isolation system).
 - Use the arrow keys () Use the "Push is to unlock" menu
 - Use the is key to start the automatic levelling. If the levelling must be corrected a second time, first put the system into "lock" position and then again into the "unlock" position.
 - Activate the isolation with the E key (indicated with a red LED)
 - Use the arrow keys (1) Use to call up the load indicator. If you make additional adjustments before approaching with the *Nanos*, repeat the levelling procedure to avoid automatic readjustment during the scan.
- For passive isolation systems:

Turn on according to the manufacturers instructions. With all air isolation systems, check that the weight balance on the base / feet is well distributed.



4.6 Setting the Signal Adjust

Note: This setting ensures that the cantilever is properly detected. Cantilever approach under wrong "SIGNAL ADJUST" settings can produce serious damage. To avoid drift effects, the preset values should be only checked upon every system startup, every change of cantilever, and upon immersion (with a liquid head) in liquids.

Under the "ADJUST" menu, choose the "SIGNAL ADJUST" option.



The "SIGNAL ADJUST" dialog window appears. In this window, the interferometer signal must be adjusted after the system startup. The "GAIN" slider is adjusted according to the following Figure:





Fig. 4-5 Setting the SIGNAL ADJUST

Fine adjustment of the "GAIN" slider can be made with the "cursor up" and "cursor down" keys.

At the correct "GAIN" setting, the interferometer signal will be in the area of +/-20000 (indicated by boundary lines).

The "OFFSET" slider is set automatically.

Note: Make sure that the "AUTOMATIC OFFSET ADJUST" is turned on. It can be turned off for special applications only

Confirm the settings in the "SIGNAL ADJUST" dialog window by clicking "OK".





Note After closing the 'SIGNAL ADJUST" dialog window, the <u>30 minute warm-up</u> <u>waiting period</u> should be observed prior to approaching the scanning head. This is to reduce drift effects on the load force settings and, respectively, on the "Operating Point" settings (when "AUTOMATIC" is not selected).

Operating Mode:

The amplifier between the fiber optic interferometric detector (see figure 2-7 on page 2-6) and the A/D converter is aligned by this function.

The photo signal must be strengthened, and the offset must be corrected, so that every possible intensity at the detector can be red into the digital system. The resulting digital value is a number between -32767 and +32767 due to the range of the 16-bit AD-converter. The value must be adjusted so that it is a linear function of the input signal.

For this reason, you will find an adjustable amplifier in the electronics. The parameters for this amplifier are set in the menu under the "gain" and "offset" sliders.

When the "SIGNAL ADJUST" window is open, the cantilever piezo is swept between two preset minimum and maximum values (registry parameters "Siganl-AdjustSweepMin" and "SignalAdjustSweepMax"). The figure below offers a diagram that shows the interferometer signal with its digital axes.



Fig. 4-6 Diagram in the "SIGNAL ADJUST" Window

The "gain" slider is effect on the amplification factor. This must be set such that the converter range of the A/D converter is as fully utilized as possible and such that the amplification remains as linear as possible without going into saturation. Therefore, a setting of a signal range of +/- 20000 digits is recommended.

The "Offset" slider is for the constant value, which is read from the detector signal, so that the signal constantly remains near a zero value. The automatic offset setting can be turned off if the user wishes to set the Offset slider by hand. This is only relevant for special applications.



4.7 Settings in the "Mode / Channel" Window

Under the **Tools** menu, click on the "MODE / CHANNEL" button.



The "MODE/CHANNEL" dialog window opens:

Mode / Channel			×
Channel Selection Error Topography back Error back	1: Topography >> <<	Acquisition Mode Contact Non Contact Self Excitation STM Extern Linearization	PM Device On Mode Spectroscopy On
	Clear	High Voltage	Pixel Range

Fig. 4-7 The "MODE / CHANNEL" dialog window.

In this window you can select the measurement mode and any of the available measurement channels. Furthermore, for tube scanning systems, you can turn on the linearization and the high voltage. These points will be discussed below.

4.7.1 The several acquisition Modes

In the "ACQUISITION MODE" field of the dialog window, activate the "CONTACT" measurement mode or, if available, the "NON CONTACT" measurement mode:

	Contact
No	on Contac
5e	Exoitatio
	STM
	Extern:

"Contact" **mode** "Non Contact" **mode**

Fig. 4-8 Choosing the "CONTACT" / "NON CONTACT" measuring mode

Note: With any given measurement mode, a suitable cantilever must be mounted. The basic configuration of the system only includes the "CONTACT" measurement mode. Other modes are optional, and for those functions additional hardware and software may be required.



4.7.2 Available Channels for synchronous recording

Selection of available measurement channels takes place in the "CHANNEL SEL-ECTION" field of the "MODE / CHANNEL" dialog window:

Error Topography back Error back (1)	>> <<	: Topography (2)
	- 4	Clear

Fig. 4-9 "MODE / CHANNEL" dialog window, "CHANNEL SELECTION" field

- 1 measurement channels available to you
- 2 measurement channels chosen for the next measurement

The range of available measurement channels depends on which measurement mode you have selected. Choose from the available measurement channels in the "CHANNEL SELECTION" field.

To **select** a channel for the measurement:

Click on the "ADD" button.

To **remove** a channel from the measurement:

Click on the "REMOVE" button.





In the following, the most commonly used/available "Contact" and "Non Contact" modes will be discussed.

With "<u>averaged</u>" marked channels, a mean value is accumulated for every pixel. Instantaneous values are recorded with the sampling rate of the system. These are arithmetically averaged over the acquisition time for each pixel. With the non-averaged channels, the last recorded instantaneous value before approaching the next pixel is used.

With channels marked "<u>Back</u>" the pixel values are recorded in the return scan direction. With standard tube scanners, with "HIGH VOLTAGE" turned on, the backward movement is from left to right (see figure 2-17 on page 2-15). Forward scanning works from right to left.

The "Back" channels are not itemized separately here. From ScanPanel Version 1.1 onward, there are no differences between the averaging of Forward and Back channels nor between averaging for "LINEAR on" or "LINEAR off" settings.



Tabelle 4-1: Table of Available Measurement Channels	

Channel	Description
TOPOGRAPHY	In this channel, the height profile of the sample is measured. This is the output signal of the Z-Feed- back loop control. This signal is averaged and then scaled with the Z-calibration nm. This measure- ment channel is always automatically selected.
ERROR SIGNAL (CONTACT)	The "Error Signal" is the input signal of the Z-FEED- BACK loop control ("setpoint value" minus "actual value"). The setpoint value is "0" (see figure 4-6 on page 4-10), and the actual value is the Interferome- ter signal.
ERROR SIGNAL (NON CONTACT)	Calculated value from the input signal of the Z- FEEDBACK loop control (it is called "Error Signal", because it is setpoint value - actual value). Actual value here is the scaled Amplitude, in nm, of the cantilever oscillation (respectively, the interferome- ter signal). The setpoint value is the nm scaled "SET- POINT"
Z-SENSOR	Optional channel for <i>Nanos</i> s with a Z-Sensor (metrology sensor) for linear topography values (averaged).
Extern 1 Extern 2	Input channels for <i>SCAN</i> Control <i>C</i> electronic measuring equipment equipped with additional optional signal processing equipment.
Extern 3	For these channels in the <i>SCAN</i> Control <i>C</i> electronic measuring equipment, three BNC inputs are available. They are labeled "IN1", 2, and 3. These channels are recorded with averaging. For special measurement modes of the optional <i>PM Control</i> a special low-pass filter averaging is utilized (for PM channels, see PM instructions)
Extern 4	The "Z-Sensor" input connector can also be configu- red as an "Extern 4" input, in cases where it is not already needed for the metrology sensor. An extern signal, connected to the "ZS" plug at the scan con- trol can be synchronously recorded with the scan
Phase (Non Contact)	The phase relationship between the excitation osci- llation of the cantilever and the oscillation of the cantilever; averaged for forward scanning.)
Amplitude (Non Contact)	Amplitude of the cantilever oscillation. This signal can be scaled in nm with "amplitude calibration".
FURTHER CHANNELS (FIELDCONTRAST, LOC, ETC.)	Other channels are available for additional measure- ment modes. These are described in the included instructions.



4.7.3 The switch for Linearization on/off

In this section, we will select if the scanner movement is linearized (the so-called "closed loop scan") or if the linearization is turned off. The standard setting keeps linearization on.

Linearization	
	On

Fig. 4-10 "LINEARIZATION" field in the "MODE / CHANNEL" dialog field

For systems with NANOS tube scanners:

With tube scanners, the linearization is controlled via resistance strain gauges, which have a lateral resolution of <10 nm. The linearization is controlled by the SCANC ontrol**C** (see figure 2-18 on page 2-17).

For systems with scanning stage (e.g. 100 μm or 200 μm):

With scanning tables, the linearization is controlled with capacitance sensors. These are controlled by the controller for the scanning table and are turned on/ off through that controller. As such two switches on the "PZT-Servo Controller" for the linearization must be turned "on" for the X and Y Directions (See CH 1 and CH 2). The switch for CH 3 should also be turned "on" (see chapter 3.3.3 on page 3-6). You will notice that the "LINEAR" switch in the "MODE / CHANNEL" dialog field is greyed out and cannot be turned on with scanning table systems.

Operating Mode:

Due to the piezo material properties, it is normal to see some image distortion with scanning probe microscopes when the excitation between the voltage and the scanner head movement is not linearized.

With linearization turned on, the scanner movement is controlled by sensors. In this case, the typical image distortion should not be apparent.

At very small scan ranges the "Linearization" should be turned off. As a rule, the linearization should only be turned on at scan ranges > 1 μ m. Non-linearized artifacts are not generally apparent at very small scan ranges. Also, when you turn the linearization off at smaller scan ranges, you can achieve higher lateral resolution.

At the moment the Linearization is turned off, the x-offset and y-offset can be automatically adjusted so that the image position keeps constant (see chapter "The linearization" on page 2-16). At turning on the linearization an offset correction won't be conducted, although this is possible without danger for the tip in the approached position (the tip moves slowly into the controlled position).



4.7.4 The switch for High or Low Voltage Range

When the "HIGH VOLTAGE" switch is turned off, the maximum scan range is reduced and, at the same time, lateral resolution is increased.

With the switch a relay inside the scan control is switched. If the switch is turned off, it means that the high voltage amplifier for the lateral deflection of the scanner is not active, or bypassed. If the HV field is marked with a ✓ symbol, the "HIGH VOLTAGE" is turned on. The default setting for "HIGH VOLTAGE" is turned on.



Fig. 4-11 "HIGH VOLTAGE" field in the "MODE / CHANNEL" dialog box

The vertical range of the Scanner (in the Z direction) does not change when "HIGH VOLTAGE" is selected or deselected.

For systems with NANOS tube scanners:

At very small scan ranges, the resolution of the *NANOS* can be increased by turning off the "HIGH VOLTAGE". The already very small noise from the high voltage amplifier doesn't play any role after switching off. When "HIGH VOLTAGE" is selected, a separate calibration of X- and Y-Range is valid. (See Chapter 7: Calibration). The Linearization is always turned off with low voltage setting.

At "HIGH VOLTAGE ON" the amplifiers supply a voltage of up to 200 Volts, with which the scanner is deflected to its maximum scan range. At "HIGH VOLTAGE OFF" the scanner can only reach a range of approximately 1/16 of its maximum nominal range (e.g. +-10V instead of a usually factory set +-165 V).

Note: The "HIGH VOLTAGE" switch may not be used when tip is in approach position.

For systems with scanning tables (e.g. 100 μ m or 200 μ m scan ranges):

With scanning tables the "HV" switch has no effect on the scan range. The voltage to drive the scan stage is generated in the scan stage's controller by the module "LVPZT-Amplifier".

With "HV" on and off, scanned images are scaled with two different XY calibrations. These can be used in order to supply different sets of X- and Y-Range calibrations, e.g for the linearization settings "on" and "off" available from the scanning table controller.

Confirm the settings in the "MODE / CHANNEL" dialog field by clicking "OK".

ОK



4.8 Settings in the ScanPanel User Interface

The following preferences are used in the main window of the ScanPanel user interface.

4.8.1 The Scan Range

The scan range can be freely chosen within the maximum scan range. There are three possible ways to choose the size setting:

Scan range setting method 1: numeric; The values for "X-RANGE", "Y-RAN-GE", "X-OFFSETS-OFFSET" and "ANGLE" can be entered directly into the XY-Control area of the ScanPanel user interface:



Fig. 4-12 XY-Control: Setting the scan range

field	meaning
X-Range / µм	Edge length of the set scan range in the fast scan direction (X in the coordinate system of <u>set</u> scan ranges, marked along the edge of the sizeable frame as a white line).
Y-Range /μm	Edge length of the set scan range which is perpendicular to the fast scan direction (Y in the coordinate system of <u>set</u> scan ranges).
ANGLE	Angle of the set scan range in relation to the maximum scan range in degrees (angle of the white edge to horizontal).
X-Off- Set	Offset of the middle point of the scan range from the midpoint of the maximum scan range (X-components in the coordinate system of the maximum scan ranges).
Y-OFF- SET	Offset of the middle point of the scan range from the midpoint of the maximum scan range (Y-components in the coordinate system of the maximum scan ranges).
SQUARE	check for convenient input of square edge length in field XRange.


Scan range setting method 2: with the mouse, by dragging and sizing the scan range with the interactive cursor ("Tracker"). The "Tracker" can used to size the scan range in the large scan window as well as in the in the small scan window (which is used to define the location within the maximum scan range).

To size the scan range with the mouse, place the mouse over the scan window, left click the mouse while dragging it over an area of the window. The following table explains the different renderings of the available cursor functions:

Cursor Function Meaning	Cursor Rendering
Decreases / Increases the box size while keeping the same edge length proportions	<mark>帰</mark> 割 ピピ
Changes the scan area by dragging an edge or a side. Allows increasing / decreasing and creation of rectan- gular shapes	↔ ↓
Shifts the selected scan range within the maximum scan range (Alters the offset)	~} >
Turns the scan area (changing the angle) The white edge of the box (weakly visible in non-black backgrounds) marks the first line of the scan range	\bigcirc

Tabelle 4-3: Cursor functions for choosing a new scan range

Scan range setting method 3: Maximizing or squaring the scan; move the mouse in the XY-Control to the small window (the permanent display of the maximum scan range). Right-click with your mouse.

The following context menu will appear:



Maximize Square (X) Square (Y)

With these choices, it is simple to maximize the scan area or square the scan area along an edge. For further information see chapter "Opening the selection frame" on page 5-9.



4.8.2 The "Z-FEEDBACK" loop control presetting

In this step, the P and I parameters for the Z-Feedback loop control will be preset (see Figure).



Fig. 4-13 P/I values for "Z-FEEDBACK" preset with nominal values

I stands for the **Integral** portion of the loop control, **P** stands for the proportional amplification. Optimization of these preset values should be carried out during the scan by the user (see chapter "Optimizing the scan speed setting" on page 4-47).

Although counterintuitive for many users, the sliders have a higher Z-feedback control characteristic toward the bottom of their range. The faster the modulation, the better the tip follows the sample topography after the approach and the start of the measurement. As the modulation is increased, the susceptibility to sensitivity problems also increases - up to the point of scanner resonance (see note below). Moving the sliders upwards slows down the modulation, which decreases the sensitivity to topography, but also reduces the sensitivity problems.

The correct values for the P/I settings depend on a number of factors, including the installed system components, the selected scan range, the scan speed, the sample properties, the selected cantilever and the measurement mode. The P and I parameters can vary over several orders of magnitude. P-values are generally between 10^{-5} and 10^{-1} . If scans have already been taken with the system on a sample, starting values should be known by the user. The P/I values are stored as a system parameter on program exit. The last entered values are recovered on program opening.

The maximum and minimum values of the "DISPLAY SENSITIVITY" slider can be chosen by the user (as with most of the sliders in the ScanPanel). To access these values right click on the slider. A context menu will appear, entitled "SLIDER PROPERTIES" (see chapter "Slider parameter setting; Slider Properties" on page 5-18).

Note:

WARNING: If overly fast values for P and I are preset, e.g. I very small and P very large, the scanner can begin to audibly resonate. ("singing" or "whist-ling of the scanner). In this case the sliders should immediately be monitored (Move the sliders upwards!). Slightly fast values may result in noisy images.



4.8.3 The Image Resolution

The image resolution is the pixel count of the acquired image. (see chapter "The scan pattern" on page 2-14). Choose the desired resolution from the drop-down menu in the tool bar (see figure 4-14).



Fig. 4-14 Setting the resolution of the acquisition scan image

In figure 4-14, an image resolution of 256 x 256 Pixels is displayed.

The resolution can be set free within the maximum resolution. The maximum image resolution through ScanPanel 1.2 is 1024×4096 pixels (for rectangular scans, 1024×1024 for square scans). Optional exists also 4096×4096 pixel. These settings can not be altered while scanning.

The ScanPanel 1.2 supports also rectangular pixels. This means in a square image one can also select e.g. 256x64 pixel. See note!

Note: When imaging with rectangular pixels, the pixel number in x direction must be an integer multiple of the number in y direction, otherwise image distortion might be observed.



4.8.4 The Scan Speed presetting

The scan speed "SCAN SPEED" is set in lines per second.

1	
4 C	120
	-

Fig. 4-15 Setting the Scan Speed

Values may be entered as numeric values or by using the arrow buttons to increase or decrease the scan speed.

<u>Direct Numeric Entry</u>: Desired values can be entered directly within 4 decimal places within in the scan speed field. The smallest selectable value (Standard = 0.01 I/s) and the largest selectable value (Standard = 12 I/s) are preset in the registry.

<u>Using the Arrow Keys:</u> With every mouse click on either the "up" or "down" arrows, the scan speed will increase/decrease by a single step. The step length is preset in the registry as (Standard = 0.25 l/s).

In practice, most users aim to scan images at the highest possible speed, and so they choose a correspondingly high scan speed. However, the scan speed can only be high as long as the Z-Feedback of the tip can safely navigate over the sample topography. Otherwise, the tip wear will be unneccesarily high.

It is best to start with a low scan speed (e.g. see figure 4-15). The speed can always be optimized during the scan (see chapter "Optimizing the scan speed setting" on page 4-47). If the optimal settings have already been determined during a prior (or test) scan, it is best to begin with those values.

Note: Overly large scan speed settings will result in rapid tip wear and tip breakage, particularly with rough samples.



4.8.5 The display of multiple recording channels

By clicking this button, you can choose whether one or four measurement channels should be displayed at a time



Specify the measurement channels to be displayed by activating them (by clicking on their individual names) with the mouse:



Fig. 4-16 Illustration of activating a measurement channel

When switching the active measurement channel display between channels, the respective Z-Control range profile will be displayed in the *ScanPanel*. Use the "Display Sensitivity" slider to alter the image contrast.

Note: Using the "Display Sensitivity" slider does not alter raw image data.

Chapter 4



4.9 Settings in the TIP APPROACH (CONTACT) Window

Click on the "TIP APPROACH" button.

If "CONTACT" was chosen in the "MODE/CHANNEL' dialog window, the "TIPAPPROACH(CONTACT)" dialog window will appear.





Fig. 4-17 "TIPAPPROACH(CONTACT)" dialog window - setting the load force

This window has three fields:

- In the "Z RANGE" field, you will see an indicator for the vertical position of the scanner. In figure 4-17 you will find the light colored marker all the way at the bottom of the range. This means that the scanner is fully expanded.
- In the "APPROACH CONTROL" field, you will see buttons that control the "approach" and "retract" function of the *Nanos* scanning head via the step motor. The movement status indicator shows as "INACTIVE" above.
- In the "LOAD FORCE" field, the preset values for the load force need to be entered. This field has a slider for setting the load force, a bar like meter to give a graphic representation of the load force, and a numeric value to show a numeric display of the load force.

4.9.1 Presetting the Load Force

Before approaching the sample, the load force for the "CONTACT" mode must be preset. This is performed in the "LOAD FORCE" field of the "TIPAPPROACH(CONTACT)" dialog window (see figure 4-17).

The cantilever piezo is moved with the "LOAD FORCE" slider. The metering bar shows the interferometer signal graphically as a bar. In the window under the slider, the preset load force as a function of the interferometer signal is shown.

How to perform the adjustments: When moving the sliders, the metering bar



can move in the same or opposite direction as the slider being moved (e.g. both toward the bottom). Set the slider control "LOAD FORCE" so, that the bar is near the 50% marker and the measuring bar and the slider move in opposite directions. If bar and slider move in the same direction, find the correct position by moving the slider until the bar exceed its next extremal value and then move further until the bar is again at the 50% marker.

After the adjustment, wait a little while and observe if the adjusted value changes. Reset it as necessary. The load force is largely determined by the type of cantilevers chosen. Using the "LOAD FORCE" adjustment allows you to alter the bearing strength within a small range.

The selected values for the load force depend entirely on the type of sample being examined. Soft materials should be examined with lower load forces; higher load forces are likely to alter the surface of soft materials. On hard materials, higher load forces allow for more stable contact and, therefore, "better" images. Bear in mind that the higher load forces on harder materials will wear the tip more quickly.

<u>Operating Mode</u>: The relationship between the adjustment of the sliders and the display of the measurement bar is explained further in figure 4-18. Here, you can see the slider and metering bar displayed differently:



Fig. 4-18 Explanation of Adjustment of the "Load Force" Bearing Strength

In principle, the sliders allow a single point on the "Signal Adjust" curve to be set. In the example, the measuring bar is shown at less than 50%. In this case, the preset load force is positive.

Note: Before approach please check the feedback: check if the load force bar (standard color yellow) can be varied by the slider beyond the 50% marker. The Z-Range bar will jump with this check between 0% and 100%. If not, the feedback does not work; please do not approach! Please check Signal Adjust and P/I settings. Approaching without properly adjusted feedback can seriously damage your scanning head!



With an approached tip, the cantilever is bent upwards. Put another way, the tip is pushed out of the preset positive range, until the Interferometer signal reaches the 50% set point.

If the measuring bar is over the 50% mark, then the displayed load force will be negative. The approach can only happen when the load force is in the positive range.

The displayed value for the preset bearing strength is calculated via Hooks Law, which means that the bearing strength is the product of the deflection of the tip and the set spring constant. The deflection of the tip is calculated from the interferometer signal. Therefore, we consider that the interferometer signal is sinusoidal between the top and bottom peak and that the difference between the peaks represents one fourth of a wavelength of the laser light, which is roughly 200 nm (see chapter "Interferometric detection" on page 2-5).

Please bear in mind that, for the displayed value, the standard cantilever plug is aligned for cantilever lengths of 225 μ m. For standard "CONTACT" tips with a 450 μ m length, the displayed load force is too small by a factor of \cong 3,2 (see the adjustments for spring constant).

From the displayed measurement bar, it is not possible to calculate a precise load force. This is shown in figure 4-19.



Fig. 4-19 Load force adjustment in the Signal Adjust Window

The set value (dashed black line in figure 4-19) intersect the interferometer signal by the rising and falling edge. The loop control works with the rising edge only, i.e the setpoint of the Z-Feedback is at 50% of the Load force metering bar with the rising edge (see figure 4-19 -(1)). The displayed value for the load force is only true, if the adjustment is on the rising edge, e.g. at (2). With the adjustment on the opposite side (3), the load force is larger than displayed.

As a rule of thumb, it is noted here that the sliders and the indicator should move in the opposite directions for the correct display of the measurement values.

As a "rule of thumb": The signal adjust window shows values along the x-axis from 0-65535. This corresponds to voltages on the cantilever piezo in the range of -60V to approximately 4.5V. The deflection of the cantilever piezo moves from maximum elongation to no elongation. The slider for the load force displays its maximum at the bottom. Bearing all of this in mind, we find that the set point edge in the "Signal Adjust" window is actually the rising edge (plotted over -d). It is possible to check this rule on your individual system by very carefully approaching by hand. By very slowly approaching Position (2), the metering bar moves direct to the set point. From Position (3), the measurement bar goes first through its minimum and then to 50%.



Setting high load forces: The values for the load force are reasonably calculated through one deflection of the cantilever at $\lambda/8 \cong 100$ nm. At a force constant of e.g. 0.1 N/m, this is an equivalent load force of 10 nN. If the slider is pulled further, the load force will again be shown as lower, but it will rise again to approximately 20 nN until the "next" 50% indication of the measurement bar. At measurement bars greater than 50%, approaching is no longer possible.

In order to set even higher load forces, the cantilever can be pushed through from one to several interferences.

As such, the automatic approach is carried out first with a preset load force. Then, while carefully watching the "TIPAPPROACH" window, you may use either the hand wheel or the "STEP" buttons to *cautiously* approach further. The "Z-Range" indicator will move upward during this approach procedure. After it has reached its maximum, the interferometer signal will move out of its set point position. If the tip is approached further, then the load force metering bar will first increase and then again decrease. Upon passing the 50% marker again, the signal will jump to the next interference level. The load force increase by 40 nN, in cases where the force constant of the cantilever is 0.1 N/m.

Thereafter, the "Z-Range" marker is returned to approximately 50% by tracking back the hand wheel a very small portion. As long the setting is not changed, the high load force is present, although the displayed value is not correct.

<u>Setting weaker load forces:</u> particularly with soft (e.g. biological) samples, and to reduce wear on the tip, it is a good idea to reduce the load force setting as much as possible. To this end, it is important to use soft cantilevers.

When setting the load force in this case, it is important to note that the cantilever piezo can drift for some time after setting the load force. For this reason, it is important to leave some time during setting smaller load forces (approximately 30 minutes) before approaching. This should be observed after any resetting of the load force, until no further change in the indicated load force values are observed.



4.10 Settings in the "TIP APPROACH (NON CONTACT)" Window

Click on the "TIPAPPROACH" button.



If "NON CONTACT" was chosen in the "MODE/CHANNEL" dialog window, the "**TIPAPPROACH** (Non**CONTACT**)" dialog window will appear.

Note: The 'Non Contact"	measurement mode is on	ly available as an op	otion
-------------------------	------------------------	-----------------------	-------

-0	TipApproach (NonContar Z Range / % - 100 - 50	Ct) Approach Control Step Step	Amplitude Control - 200 nm est Point / % est = 100 Free Amplitude / nm 150	Freq. Selection
Beadu OK Cancel	0			

Fig. 4-20 "TIPAPPROACH(NONCONTACT)" dialog field with a retracted tip

This window has five main areas:

- In the "Z RANGE" field are markers indicating the vertical position of the scanner. In figure the bright indicators are completely at the bottom of the available range. This means that the scanner is fully extended.
- In the "APPROACH CONTROL" field are buttons for controlling the approach and retract functions of the *Nanos* scanning head via the step motor. The motion status indicator is also shown (shown in figure as "INACTIVE").
- In the "OPERATING POINT ADJUST" field, the optimal sensitivity of the interferometer signal should be set (see chapter "Interferometric detection" on page 2-5).
- In the "FREQUENCY SELECTION" field is a button for opening the dialog field which allows the excitation frequency to be set/selected.
- In the "AMPLITUDE CONTROL" or "AMPLITUDE CONTROL (*COARSE)" field (contingent upon the appropriate current amplitude calibration), the free amplitude ("FREE AMPLITUDE") can be set in nm and the set point for the Z-Feedback loop control ("SET POINT") can be set by percentage.

The "NON CONTACT" parameters are set in the last three fields named above. These settings are explained further in the following section.



4.10.1 Setting the Operating Point Adjust

The slider must be set, such that the floating indicator remains between the hash marks. The slider can be used in three ways (dragging, large steps, small steps), but the "Automatic" check box must be deselected (by removing the check mark in the "Automatic" check box):Move the "OPERATING POINT ADJUST"

Dragging:

Drag the slider until the red floating indicator is between the hash marks. Once the indicator is between the marks, it changes to a yellow color. There are several correct positions along the slider's range. If possible, choose a middle position for the slider.

Large Steps:

For rough positioning of the slider, using large steps, click to the left or right of the slider with the mouse. For each mouse click, the slider will take a large step in the direction of the mouse.



Small steps:

For fine positioning of the slider, use the cursor (arrow) keys on your keypad.

If the settings do not appear stable after a waiting time, and drift erratically (or outside) of the hash marks, check that the tip is correctly mounted.

Automatic:

After manually setting the "OPERATING POINT ADJUST" by any of the methods above, select the "Automatic" function by clicking in the "AUTOMATIC" check box. This automatic adjustment will be also switched on during the scan.

If the operating point leaves the desired range, an Error message will appear. In this case, the tip must be retracted from the surface, the "Automatic" adjustment turned off, and a new "OPERATING POINT ADJUST" set.



until the

<u>Operating Mode</u>: The relationship between the setting of the sliders and the graphic image is illustrated by figure 4-21. Here, you can see elements of the user interface (slider and graphic image) arranged differently as an example:



Fig. 4-21 Illustration of the "OPERATING POINT ADJUST" meter versus slider function

In principle, the slider allows a single point on the "SIGNAL ADJUST" curve to be set. For further explanation see chapter "Interferometric detection" on page 2-5.



4.10.2 Settings in the "FREQUENCY SELECTION" Window

In the "TIPAPPROACH" dialog window, click on the "FRE-QUENCY SELECTION" button.



Before opening the dialog window, a warning may appear:

This "Warning" message appears, as a software safety check that the tip is not in the approach position. It is possible that the warning may appear even if the tip is not in the approach position, e.g. after the tip change.



Note: When the "Warning" message appears, check if the tip is in the approach position or not. <u>You may click "CONTINUE"</u> only if the tip is NOT in the approach position.

After clicking "CONTINUE", the "FREQUENCY SELECTION" dialog window appears:



Fig. 4-22 The "FREQUENCY SELECTION" Dialog Window

When the "FREQUENCY SELECTION" dialog window opens, the "Z-FEEDBACK" loop control is turned off. To read in the frequency function of the tip, the excitation frequency is cycled through the selected range ("frequency sweep").

The "FREQUENCY SELECTION" dialog window includes:

- A diagram showing the frequency function (interferometer amplitude vs. excitation frequency)
- A "FREQUENCY CONTROL" field for setting the excitation frequency of the cantilever piezo
- An "AMPLITUDE CONTROL" field for setting and scaling the excitation amplitude of the cantilever piezo

In the following pages, frequency and amplitude settings are explained further.



4.10.3 Setting the Resonance Frequency



The setting procedure follows as is shown in the figures below:

Step 1: Click on RESET

After left-clicking with the mouse on the RESET button, the resonance curve will reset over the full frequency range within the display.



Step 2: Zooming

The button for ZOOM / SELECT must be activated, as shown to the left, in order to activate the "ZOOM" function. By left-clicking and dragging the mouse over the resonance curve, you can zoom in on the resonance peak.

If there is more than one peak at the resonance frequency, check the amplitude (see next page).



Step 3: Choose Frequency

<u>-Left click</u> the button for ZOOM / SELECT to switch to "SELECT", as shown to the left. <u>-Left click</u> on a chosen area of the resonance curve, to select the desired excitation frequency.





4.10.4 "Coarse" calibration of the Excitation Amplitude

In the "EXCITATION" input field, values between 0 and 65535 for the excitation amplitude can be entered. Set these parameters as shown below, in order to bring the tip toward the optimal resonance curve.



Fig. 4-24 Setting the "EXCITATION" Factor

Note:

The values shown in the figures can differ actual values for a given cantilever by some orders of magnitude.



With the preset amplitude maximum, the free amplitude can be coarsely scaled. To this end, the \bigcirc Coarse Calibration^{*} is turned on (checked). The values in the "Excitation" field are then scaled to approximately $\lambda/4 \cong 200$ nm.

However, it is *strongly* recommended to go through the amplitude calibration procedure so that the Coarse Calibration^{*} can be turned off (unchecked). This procedure is detailed in the following section.

4.10.5 Calibrating the excitation amplitude

The amplitude calibration allows the following possibilities:

- calibration of the nm scaled "AMPLITUDE" and "ERROR" channels
- calibration of the "SETPOINT" and "FREE AMPLITUDE" settings

The calibration is performed as follows:

Turn off the	COARSE C	ALIBRATION
--------------	----------	------------

Open the window for the amplitude calibration by clicking the "Calibration" button.

Calibration	

Coarse Calibration*

Step1: Check Frequency

Was the resonance frequency in the "FREQUENCY SELECT" window set correctly? If not, click "BACK" and set/select the resonance frequency.

Step 2: Operating Point Adjust

Optimize the OPERATING POINT ADJUST, if necessary.

Step 1: Check Frequency	x
Please make sure that you have selected a frequency close to the resonance!	
Continue Back	
Step 2: Operating Point Adjust	
Operating Point Adjust	
Continue Back Cancel	





Next, slide the "EXCITATION" slider at it's minimum (all the way to the top):

The minimum slider setting, as most of the other sliders in the ScanPanel, is all the way at the top of the slider range.



Pull the EXCITATION slider downward until the amplitude indicator barely crests its maximum level (within 5% of the maximum range, or less).

The excitation is increased with the "Excitation" slider until the measured amplitude reaches its first maximum. The excitation is increased just slightly further so that there is some certainty that the maximum will actually be reached during the calibration procedure.

The amplitude of the cantilever vibration at the curve maximum, due to the wavelength of the laser in the interferometer, is approximately 200



Click on the CALIBRA-TION button.

The Interferometer Amplitude versus the excitation amplitude is recorded and the fit is computed. The curve maximum is set to a 200 nm amplitude.

Confirm the current settings by clicking "OK".





Operating Mode:

The amplitude of the interferometer signal and the actual amplitude of the cantilever oscillation can be derived from the interferometer signal. This is shown in figure 4-25:



Fig. 4-25 Cantilever Oscillation Amplitude at the Interferometer Signal

The function interferometer signal amplitude versus true cantilever amplitude can be derived qualitatively from the "SIGNAL ADJUST" curve. The highest amplitude is the difference between the minimum and the maximum of the "SIGNAL ADJUST". This difference is equivalent to $\lambda/4 \cong 200$ nm (see chapter "Interferometric detection" on page 2-5). If the cantilever oscillation becomes larger than this maximum, the measured interferometric signal yields distorted. The spectrum analysis may show peaks at higher frequency rate while the amplitude at the selected frequency decreases. The result of this is the "dip" (as the indentation is called) in the frequency response at too high an excitation (see figure 4-22 on page 4-29; middle).

Through this, it is possible to scale the interferometer signal. This means that the amplitude of the cantilever oscillation can be measured in nanometers. There are two methods of calibrating this:

With the simple but not exact "COARSE CALIBRATION", the preset excitation amplitude and the maximum of the frequency response in the diagram are assigned a value of (see figure 4-22 on page 4-29) 200 nm. Other values are computed with the approximation of a linear relationship.

With the more precise Amplitude Calibration a *not* linear relationship between the interferometer signal and the cantilever amplitude is respected. The function is measured with the amplitude calibration. Here 50 different excitation amplitudes are recorded for the interferometer amplitude. An inverse function is calculated for the recorded curve. The settings of the free amplitude and the "SETPOINT", as well as the range of the "AMPLITUDE" and "ERROR SIGNAL", follow this calculated inverse function. The "COARSE CALIBRATION" must be turned off.

The recorded curve represents the cantilever amplitude versus interferometer amplitude function. The maximum of this curve is again equivalent to $\lambda/4 \cong 200$ nm. This is true respecting that the excitation amplitude behaves as a linear



function of the cantilever amplitude.

4.10.6 Setting the SET POINT and FREE AMPLITUDE

"FREE AMPLITUDE" is the free amplitude of the cantilever oscillation at the pre-set excitation frequency. In this case, free amplitude also means that the tip is far away from the surface.

The "SET POINT" is the desired percentage share of the free amplitude at the approached position. After the approach, the free amplitude reduces itself to the "SET POINT" level.



Fig. 4-26 Setting the "SET POINT" and "FREE AMPLITUDE"

<u>Example:</u> in figure 4-26, the free amplitude is set at 195 nm. In the approached position the distance between the sample and the tip will be regulated at 65% of the free amplitude (at approximately 127 nm). These values are standard settings in the software.

Note: Numbers entered via the keyboard are only accepted by the system as valid after pressing RETURN or ENTER.

<u>free Amplitude:</u> The "FREE AMPLITUDE" setting changes the excitation amplitude of the cantilever piezo. The free amplitude can be set at any value between 0 and 200 nm. So that the given value (in nm) is correct, the calibration of the free amplitude must be performed in the "FREQUENCY SELECTION" dialog field (with "COARSE CALIBRATION" turned off").

<u>"Set Point"</u>: The higher the pre-set value, the higher the distance between the tip and the sample during the scan. The "SET POINT" values should normally be between 50% and 80%. The smaller the value, the closer the tip will be to the sample surface. Tip wear can also increase at smaller values. At larger values, the interaction between the tip and the sample surface decreases until it is no longer possible to measure the interaction from the surface. In other words, the tip pulls away from the surface.



The connection between the "SET POINT" and the "FREE AMPLITUDE" is illustrated by means of the theoretical plot of the resonance curve:



Fig. 4-27 Theoretical Amplitude Run of the Resonance Curve

The figure 4-27 shows the theoretical amplitude characteristics of a resonance curve. Both the free, undamped cantilever oscillation (dark curve) and the dampened cantilever oscillation (light curve) are plotted.

The resonance curve during the tip approach (light) is wider and shifted more toward smaller frequencies when compared to the undamped resonance curve (dark).

The excitation frequency is also drawn in (right dashed line). The amplitude at this frequency is the reference value (100%) for the "SET POINT". When the tip is approaching, the amplitude of the excitation frequency is controlled to the selected "SET POINT". This is the intersection point of the during-approach-curve with the excitation frequency. This shows, that the approached cantilever vibrates no longer at his resonance frequency (left dashed line) but at the sensitive slope of the peak.

Note:	The 'SET POINT" and 'FREE AMPLITUDE" values can be changed after the ap-
	proach position is reached.



4.10.7 Checking the NON CONTACT mode settings

Check the previous settings and adjust them as necessary.

- Operating Point Adjust (see chapter "Setting the Operating Point Adjust" on page 4-27)
- Scaling of the free Amplitude (see chapter ""Coarse" calibration of the Excitation Amplitude" on page 4-31)

Note: The settings are saved when you quit the program by clicking "Exit". They reappear as default settings after a new start.

<u>Checking the feedback:</u> Before approach ensure that the feedback system works. If there is any doubt please do the following:

- Switch off the "AUTOMATIC" check box in the "OPERATING POINT ADJUST" field.
- Move the slider in this field until the amplitude bar undercuts the "SET POINT" marker and make sure the "Z-RANGE" bar moves up.
- If the "Z-Range" bar can not be moved with this procedure, do not approach! Please check all settings again like Proportional and Integral feedback settings, Signal adjust settings etc.
- If the "Z-Range" bar moves, the feedback works. Readjust the "OPERATING POINT ADJUST", turn on the "Automatic" and make sure that the "Z-Range" bar is at the bottom position.

4.11 Settings for additional Measurement Modes

Additional measurement modes and measurement channels are available as options for your controller. Supplementary settings are necessary for these additional modes in the "TIPAPPROACH" window. Descriptions of these additional settings and interface modifications can be found in the respective supplementary handbook provided with optional modes/channels.

4.12 Approaching the tip (APPROACH)

Note: Assure that the feedback works before approach. Approaching without properly adjusted feedback can seriously damage your scanning head (Contact Mode see chapter 4.9, Non-contact mode see chapter 4.10.7)

After you have checked the default parameters again, you may begin the approach process. Before pressing the "Approach" button, take a final look at the stage and check if the scanning head is in position (swiveled in and mounted properly).

The approach between the sample and the tip runs automatically. Depending on the type of base system you have, the approach may occur either by moving the *Nanos* measuring head or by moving the sample stage. **Starting the Approach:** Click on the "APPROACH" button. The sample will approach the scanner automatically.

<u>Note:</u> There is a danger of pinching your fingers between the Nanos and the sample/stage surface during the automatic approach. Stay clear!

The hand wheel associated with the stage or with the scanner (when installed) will turn visibly during the beginning of the approach. The last few steps of the approach are in the micron range, so it may be difficult to see the wheel turning during this latter stage. The motion status indicator of the step motor will display "APPROACH" until it completes the approach process, or until the user presses the "Stop" button.

When complete, the motion status indicator will display "INACTIVE".

If the sample/scanner approaches correctly, the yellow marker will be visible in the Z RANGE indicator window. Typically, it will be near the middle (or 50% mark) of the measurement bar.

This means that the scanner is compressed/stretched at half of its working range. This will allow you scan samples with a height variance of +/- 50% of the scanner's range.

If the approach does not work completely, or at all, please check the parameter settings noted above in this chapter (from chapter 4.9, page 4-22 on) and try again. In case this does not help, try discharging the sample (e.g., with an "lonized air blower")

Interrupting: If you click on "**STOP**" at any point during the approach procedure, the motor will stop immediately.

The system is stopped when the "INACTIVE" indicator appears.

Closing the Dialog Window:

After a correctly completed approach procedure, save the current settings and close the "TIP-APPROACH" dialog window by clicking "OK". You may now begin acquiring the scan/image.





















Note: Please do not confuse the Button "CANCEL". Use the Button "STOP" to stop the motor. Use the button "OK" to exit the window. The Button "CANCEL" closes the window and reconstructs all the parameter settings from before the window was opened. Do not try to click on "CANCEL" during or after approach: the potentially wrong

Do not try to click on "CANCEL" during or after approach; the potentially wrong parameter setting may harm the tip.

<u>Operating Mode:</u> After clicking the "APPROACH" button, the approach procedure will start, *unless* the scanner was not previously completely retracted *or* there is some indication that feedback parameters were not set correctly.

The motor then moves the scanner toward the sample. The speed of the approach is controlled by factory set parameters. During this approach, the system controls if the tip is getting near to the sample surface. This is indicated as the "free approach".

In this way, the input signal of the Z-Feedback loop control is monitored. In other words, depending on the measurement mode, either the interferometer signal or the amplitude signal is checked. If the input signal of the Z-Feedback loop control is changed, then the signal changes to the so-called "tapping mode". The "tapping mode" works as follows:

- At the beginning of a tapping step, the scanner is fully retracted.
- Then, the scanner approaches a specific distance. In other words, the step motor moves a set number of steps (with the distance and speed as determined by the factory set parameters).
- At the end, the scanner is slowly (under control of the Z-Feedback input signal) expanded. The scanner expands until the Z-Feedback input signal reaches its set point ("SETPOINT"). In cases where the set point is not reached, the scanner is fully elongated.
- The level of expansion of the scanner is generally equal to the amount of expansion that should be achieved (normally 50%).
- When the expansion process is close to the set point ("close" is understood to mean something around 25% compression of the scanner), the distance of every step of the step motor is reduced by half. This guarantees a very accurate positioning.
- The approach process ends when the approach is successful, when the "STOP" button is pressed, or when the default number of steps are unable to reach an optimal approach position. Otherwise, the next tapping step is performed.



The function of the ranger meter is explained in the following figure:



Fig. 4-28 Function of the "Z-RANGE" Indicator.

4.13 Starting the Scan / Image Acquisition.

After you have set all of the important/relevant parameters, and have completed the approach (see the previous section), you should again see the main window of the user interface. The scanning procedure can now be started.

You may choose between acquiring a single scan image ("SINGLE SCAN") and acquiring a continuous set of images ("START SCAN"):

SINGLE ACQUISITION ("Single Scan")

This function starts the acquisition of a single scan image. After the image is acquired, the scanning stops and you have the option of saving the measurement data.

CONTINUOUS ACQUISITION ("Start Scan")

This function starts the acquisition of the image in a continuous, or repeated, mode. After a full scan is completed, a new scan begins at the same starting location as the previous scan. The image acquisition continues until the user stops the scanning procedure. If you would like to save every image acquired, you must activate the "AUTOSAVE" function under the "AFM PARAMETER" menu. (See Chapter 5).

STOPPING THE SCANNING PROCEDURE

Click the "STOP" button in the tool bar will stop the image acquisition (after the data transfer for the forward or backward part of the scanned line is ended) and the tip will move to the middle of the set scan range. (see chapter "The scan pattern" on page 2-14).

During the scan, you can use the "SINGLE SCAN" and "START SCAN" button to switch between single and continuous scanning procedures. The active button will appear to be "pressed". After a single acquisition, you may save the completed image.

The image is acquired slowly (see figure 4-29):.

Fig. 4-29 Image acquisition in the ScanPanel









4.14 Setting the "DISPLAY SENSITIVITY" Contrast Indicator

It is possible to optimize the display of the measurement image during the acquisition of the measurement. The "DISPLAY SENSITIVITY" slider should be adjusted according to figure 4-30.

Changing the "DISPLAY SENSITIVITY" contrast indicator *does not* change the image data being acquired. It only changes the displayed contrast of the data.



Fig. 4-30 Setting the "DISPLAY SENSITIVITY" Slider

The maximum and minimum preferences of the "DISPLAY SENSITIVITY" slider can, as most of the sliders in the ScanPanel, be set by the user. Right-Click on the slider button to display the available variables for a given slider. The "SLIDER PROPERTIES" context menu will appear. (see chapter "Slider parameter setting; Slider Properties" on page 5-18).

In case of the "TOPOGRAPHY" measurement channel the factor set by the slider, is the factor by which the display is magnified from the height range, or "Z-RAN-



GE" of the scanner. The scaling of the displayed profile is calculated by multiplying this factor with the "Z-RANGE" calibration value.

For other measurement channels, the corresponding is also true. The calibrated maximum value of the respective measurement channels, divided through the aforementioned "Display Sensitivity" factor, is equal to the value range of the line profile.

The vertical positioning of the profile, i.e adding an offset value, is automatically performed. This works as long as the "PLANE CORRECTION" setting (under the AFM Parameter menu) is activated. However, the added offset is not included in the plotted scale, since the scale always begins at zero.

The horizontal axis of the diagram (the so-called "Oscilloscope") is scaled in pixels, depending on the number of pixels set for on scan line.

The current line height profile, of the selected measurement channel, is displayed. The "Display Sensitivity" settings are set differently for each selected measurement channel. Changing the slider in one active channel will not alter the display in another channel.

At the end of the scan, all measurement channels refresh their displays with their current (most recent) sensitivity settings. These settings can also be changed for the entire image after the end of the scan.



4.15 Optimizing the Z-FEEDBACK Slider Settings

The P (proportional amplification) and I (integral amplification) sliders of the "Z-FEEDBACK" loop control can be optimized during the scan, as shown in the figure below.

Every change in the P and I slider position in the "FEEDBACK CONTROL" area will result in changes in the scan data.



Fig. 4-31 Setting the Z-Feedback loop control



Note: Only move the P/I sliders in small steps. Wait for the results of the slider movement to manifest themselves during the next scan line. Incorrect settings will increase wear on the tip. Overly fast slider settings can even result in feedback resonance effects (Scanner "singing" or "whistling"). In this case, **immediately** move the sliders to their minimum (Sliders upwards!).

Optimization of the P and I settings should be made according to the current scan and by observing the currently displayed profile line in the "Oscilloscope".

If the display of the edges is too "weak", when compared to the estimated actual structure, the loop control must be set at a faster level. In other words, the P and I sliders should be alternately moved downward until an ideal structure is achieved. If, on the other hand, the displayed edges are too "strong" or if there is "noise" introduced into the image, then the feedback loop must be slowed down. In other words, the sliders should be moved alternately upward until the noise dissipates.

If a satisfactory setting cannot be found for the P and I sliders, we recommend slowing down your scan speed and trying the optimization again (see the next chapter).

The "AMPLITUDE" or "ERROR SIGNAL" measurement channels can also be included in the P and I settings. When the loop control settings are too slow, the edges of the displayed structures in these channels become clearer. Also, when the loop control settings are too fast, the signal shows more noise or over all range. At the correct setting, the deflection variance is minimal.

For further assistance in obtaining the correct settings, you can check one of the included "back" scan measurement channels (e.g. "TOPOGRAPHY BACK"). In order to decide if (for example) a rising edge is real, check in the "TOPOGRAPHY BACK" channel if a corresponding falling edge is visible at the same point. Noting the differences in the displayed edges in the different channels is highly recommended when learning the characteristics of the "Z-FEEDBACK" loop control.

Comparing corresponding backward and forward channels, one can discover also a lateral mismatch between the profiles. This lateral offset is also visible with "LINEAR ON". It is independent from the sample but it depends on scanning speed. The image quality is not affected by this offset.

Operating Mode:

In principle, the Z output signal of the Z-Feedback loop control is composed of the Δa input signal in the following way:

$$Z(t) = P \cdot \Delta a(t) + \frac{P}{I} \cdot \int_{-\infty}^{T} (\Delta a(t') \cdot dt') \qquad \Delta a(t) = a_{soll} - a_{ist}$$
Proportional Integral portion

The input signal, $\Delta a(t)$, is the current deviation of the detector signal from its setpoint. This is also called the "ERROR SIGNAL" (see chapter "The digital Z-feed-



back" on page 2-12). From this signal a proportional part and an integral part are produced separately. In the digital system the output signal from the last control cycle is modified by these two parts. In the infinitely variable formula the signal from the last control cycle is included with the Integral as well as all control cycles from the start of the feedback control [- ∞ , T].

Although the unit with I is μ s, the value is not the integration time. The accumulation works all the time from starting the loop control. I stands in the denominator of the integral portion, which means the higher I, the smaller is the integral portion, i.e. the accumulation part of the loop control.

The greater the proportional and integral amplification, the faster the reaction of the loop control.

In order to increase the Integral amplification, the I value must be decreased. In order to increase the proportional amplification, the P value must be increased.

The respective P and I sliders in the user interface are arranged such that their values increase and decrease conversely when the sliders are pushed in the same direction. This means that the sliding both downward will increase the reaction speed of the loop control. Sliding both upward slows down the control speed.

The current reaction speed van be maintained by moving one slider up and the other one down. The displayed values will be both smaller or larger then. It can be found many P and I settings by trial which provide an optimal reaction speed. This causes the question if there is a rule for setting a higher I or a higher P for a given reaction speed

On can estimate, that with a setting of I = 33 μ s the proportional part and the Integral part of the feedback have the same value. With this I setting, P will be at around P < 0.002 on a showcase setup. Is the I value higher than 33 μ s, with on remaining reaction speed adjusted P, the Integral part of the feedback becomes smaller and P will dominate the feedback. Vice versa the feedback control can be dominated by the Integral part with I smaller than 33 μ s.

It can be assumed that a dominating I part (e.g. I < 15 μ s, P < 0.001) causes a more stable feedback characteristic. The feedback will tend less to produce noise. For some scanners (e.g. 80 μ m tube scanner) this setting is mandatory. For some applications, where highest possible reaction speed is desired (e.g. in STM) a dominating I value is set usually.



4.16 Optimizing the scan speed setting

The scan speed can be set in the "SCAN SPEED" field of the main window. The displayed number represents the number of scan lines per second; see also the default scan speed settings (chapter 4.8.4 on page 4-20).

Sca	n Speed .	/line/s
	1	-
	L'	-

Fig. 4-32 Input field for the scan speed, "SCAN SPEED"

In the example above (see figure 4-32), the "SCAN SPEED" is shown at the typical value of one line per second ("line" means one forward and backward cycle).

The velocity of the tip in microns per second is not only contingent upon the chosen scan speed but also on the scan range. The tip speed is displayed as "SPEED" in microns per second. The "SP" display can be found at the lower right corner of the status bar of the main window:

Scanner#2	LINE: 91	SP: 221.961 µm/s	ASV: ON	FN: t0014	LIN: ON	HV: ON	NONCONTACT	

Fig. 4-33 Status bar of the Main Window, Displaying the Tip Speed in $\mu\text{m/s}$

Generally, users prefer to keep the scan time to a minimum. To that end, scan speed can be increased and the image resolution (determined by the number of lines taken a scan) can be reduced. However, in order to optimize image quality, the opposite (high resolution and low speed) is required.

To determine the **maximum reasonable scan speed**, start by entering a small value. From that point, the speed can be increased step-by-step, as long as the P and I settings in the "Z-FEEDBACK" loop control can still be set optimally. In any case, the scan speed setting should always be below the maximum reasonable speed.

The maximum reasonable scan speed will vary, depending on the kind of investigated sample structures and the scan range sizes. The higher and sharper the edges on the sample, the slower the maximum usable scan speed. Faster scan speeds are possible on flatter samples.

Faster scan speeds are also possible with smaller scan ranges. We recommend that the displayed "Speed" always is less than 40 $\mu m/s.$

Inversely, at overly high scan speeds, the P and I settings in the Z-Feedback control area can be difficult or impossible to optimize. In other words, despite any efforts by the user, the edges will appear either too "soft", or the displayed edges will have sharp, unreal edges.

The maximum set able scan speed is a factory set parameter.

Note: Improper settings increase wear on the tip.



4.17 Monitoring the "RANGE" Display during the Scan

During the scan procedure, the "RANGE" display in the "Z CONTROL" area should be constantly monitored. If necessary, stop the measurement. The following cases are possible:

"Range" Display	Meaning
Range / %	Scanner fully stretched The range meter shows maximum exten- sion of the scanner. This means that the actuator in the Z direction is fully extended. The tip will pull away from the sam- ple surface, If the tip to sample di- stance increases further.
Range / %	Scanner fully compressedThe range meter shows full contraction of the scanner. This means that the actuator for the Z direction is fully contracted.The tip will be indented into the sample surface, If the tip to sample distance reduces further.
Range / %	Scanner half stretched/compressed The range meter shows the correct set- tings for the approach. The display shows the sample is in the middle of the Z-RANGE of the SCANNER. The extension of the bar (1) shows the ver- tical range over a single scan line. The range is well within correct values. From the range, it is possible to determine if the sample structure fits into the availa- ble z-range of the scanner.

Fig. 4-34 Monitoring the "RANGE" Display

Note: If the range bar is too close to the upper or lower end of the Z-Range, stop the measurement immediately and retract the tip.



Stopping the measurement: Click on the "STOP" button in the tool bar at the top of the main window.

The measurement will stop. The tip will then move to the middle of the current scan range.



The range of the actuator for the Z direction can be seen from the extension (1) of the bar within the "RANGE" indicator; see in figure 4-32. If the indicator shows too large of a range, or that the bar doesn't properly fit within the indicator, then the sample has overly large structures within the selected scan area. Other than with special applications, this means that the measurement must be stopped, or that it will automatically be stopped with "AUTORETRACT" on.

If the z-range of the sample was too large, we recommend either reducing the scan area or moving the scan range (by changing the offset) and starting a new scan; see chapter "Choosing a New Scan Range" on page 4-52.

Other than that, we recommend completely retracting the tip and then trying to approach again:

Retracting the Tip: In the tool bar in the main window, click on the "**TIP-APPROACH**" button.

The "TIPAPPROACH" dialog box will appear.

In the "TIPAPPROACH" dialog window, first click on the "RETRACT" button and then, a few seconds later, on the "STOP" button.

When available, you may also *carefully* turn the hand wheel in the direction of the affixed arrows.





As previously noted, the tip may retract automatically when there is an "out of range" feedback indication from the range meter. This feature has several parameters that you can adjust. Please go to the "AFM-PARAMETER" menu and click on "AUTORETRACT" to see these different options (see chapter "AUTORE-TRACT- automatic tip retraction" on page 5-28).

After the retraction, you may wish to look for a new area on your sample. This is e.g. possible with the XY microscope stage, After the new area has been located, you can start the next approach and then start a new measurement (see chapter "Approaching the tip (Approach)" on page 4-37).



4.17.1 Correcting the approach with the "STEP" function

As an alternative to the completely new approach, you may also try correcting the approach by using the "STEP" buttons the "TIP APPROACH" dialog window.

Click on the "TIP-APPROACH" button.



In the "**TIPAPPROACH**" dialog window, you will find the following.

With every click on the approach "STEP" button, the tip will approach the sample by a set distance. Conversely, the system will retract that same set distance for every click on the retract "STEP" button.

<u>Operating Mode</u>: The "**STEP**" buttons function is similarly to the automatic step approach. Every time the motor is moved, the scanner retracts the tip before any motor motion occurs.

After every click on one of the "STEP" buttons, *carefully watch* the "Z-RANGE" indicator bar.

The goal of most approach procedures is to put the bar as close to the 50% mark as possible.

<u>Note</u>: Be extremely careful using the 'STEP" buttons, since crashing the tip is possible.

After reaching the desired range, close the "TIPAPPROACH" dialog window by clicking "OK".

You may now start a new measurement by clicking on (e.g.) the "SINGLE SCAN" button.









4.18 Saving your Measurement Data

After finishing a scan in the single scan mode, or after clicking the "Stop" button, you may manually save the measurement data from your scan. (For further information on saving your data automatically, please see chapter "The Auto Save Function" on page 5-27).

To save the current measurement data, click on the "SAVE" BUTTON.



The "SAVE" dialog box will appear (title depends on operating system language).

ाड्डा Speichern	unter			×
Speichem	鷆 Demo		- ← 🗈	≝ .
Name	Änderungs	Тур	Größe	
Itestfile1				
Datei <u>n</u> ame:	Itestfile1			Speichem
Dateityp:	SIS Files (*.sis)		_	Abbrechen
244	1			/

Fig. 4-35Dialog Box (SAVE)

Save your measurement data in the "SAVE" dialog box by giving the file your desired name. You may also now choose the location for your file. Save the file by clicking on "SAVE". The "ACQUISITION PARAMETER" dialog box will appear:

Acquisition Parameter	
Parameter	
Sample	centering sample
Comment	calibratiin check
Cantilever	Silicon
	OK Cancel

In this dialog box, you may add additional comments that you would like to have saved with the image. Confirm any changes by clicking "OK". The image is now saved for further data or image processing with image processing software.



4.19 Choosing a New Scan Range

After finishing a scan, you may choose to create a new scan range. The easiest way to do this is by left-clicking the mouse in the large image window over the previous scan and then dragging a box over the desired new scan range area.

To create a new frame range for the first time:

- Click in the image display window with the left mouse button.
- Drag a new frame within the image window while depressing the left mouse button. When you release the mouse button, the new frame will be square.

After creating a new frame, you can alter the frame size and shape; see chapter "Opening the selection frame" on page 5-9.

This procedure can be performed with the mouse in either the large or small scan range display window. The active frame is displayed with frame edge markers. An example of this new frame choice is explained further in the Figure below.

To start a new scan in the new scan area, click again on the "START SCAN" or "SIN-GLE SCAN" button.



Fig. 4-36 Choosing the next scan area within the last image or in the "X/Y CONTROL" field.

- 1 New frame in the image display area (not active in this example)
- 2 New frame in the maximum range scan display area
- 3 Markers to show that this frame is active


4.20 Retracting the tip

After clicking the "SINGLE SCAN" button, either wait for the scan to finish, or click on the "STOP" button to end the scan.

The tip will then move to the middle of the chosen scan range.

In the tool bar at the top of the main window, click on the "TIP-APPROACH" button.

The "TIPAPPROACH" dialog box appears.

In the "**TIPAPPROACH**" dialog box, click on the "**RETRACT**" button.

When available, you may also *carefully* turn the hand wheel in the direction of the affixed arrows.







RETRACT

INACTIVE

The tip will retract to a safe distance within a few seconds.

The "RETRACT" status indicator will continue to appear in the "TIPAPPROACH" dialog box until the motor is stopped by clicking on the "STOP" button, or until it reaches its stop limit.

Once the motor stops, the "INACTIVE" status indicator will appear.

To exit the **"TIPAPPROACH"** dialog box, click "OK".

You may now remove your sample and turn off the system.

If the *Nanos* is mounted in a microscope turret, you may also now swivel in an optical objective.

Note: Before swiveling the turret to an optical objective or changing the sample, make certain that the tip is no longer in the approach position. When turning the turret, only use the turret ring. Never use the objectives to turn the turret.



4.21 Turning off the System

To avoid waiting for the warm up period, it is better to turn off the system only when you are not planning to use it for some longer time, or when the system is not being supervised by qualified personnel. For this, the following steps are necessary:

• To end the program, click on the "FILE" menu and select "EXIT".



- A message will always appear and ask if you would like to save the current image. If you wish to save your image, and have not yet done so, do that now.
- When closing the program, the "REMOVE TIP" status message will appear and the tip will retract a factory set time. After that you may shut down the computer.

• The *SCAN*Control *C* electronics may also now be turned off. It is also a good habit to turn off the active isolation at this point. If the sample is still on the stage, take this opportunity to remove it and place it in a dust free case.

The measurement is now complete.



In this chapter the functions in the user interface "ScanPanel" will be specified.

In the following you will find a list of the available functions. If a function was described already, there is a reference to the corresponding chapter. If a function was not yet shown, it will be described in the following paragraphs

Functions, which are not described here (optional modes), come with a separate extension of this user manual.

5.1 Screen sectioning of the user interface



The user interface is the main window of ScanPanel. It is divided into 6 sections.

- Menu bar: Click with the left mouse button on a menu item to list the available submenus. Sel-1 ect a submenu from the list with the left mouse button. The corresponding dialog field will open up.
- 2 **Tool bar**: The tool bar contains buttons. Often used dialog fields can be opened directly by these buttons. The buttons are used alternatively with the menu bar.
- Section for displaying the image recording: This screen section shows the measured 3 image data during scanning. One or four synchronously recorded channels can be displayed simultanously. Each displayed channel contains the channel name, the set scan range and a color bar to show the topographic range (or signal range and unit with other signal types).
- Status line: left side: displays "ready", in case of the system is clear for accepting inputs 4 (otherwise a progressing display can be shown). Right side: space for status indications (e.g.: "Scanner name"/ "Speed" / "Linear" / "HV" / "Mode").
- 5 Section Z-Control: The adjustment of the closed loop Z-feedback controller is done in the lo-



wer part of this section. In the upper part the displayed signal range can be adjusted. This display change works for the selected channel. There is a profile shown of the current scan line for this adjustment.

6 **Section XY Control**: This Section is used for setting the scan range. The set scan range, with respect to the maximum scan range, is displayed graphically as a frame.

In the following paragraphs the single functions will be introduced. A reference to a chapter with a detailed description will be indicated.

5.2 Available submenus

Functions, which are not available in the main window, can be opened up with a submenu from the menu bar.

The menu bar consists of the following menus:

File

- SaveAs: see chapter 4.18 on page 4-36
- Exit: see chapter 4.21 on page 4-39

Scanning

- Mode/Channel,
- Tip Approach,: see chapter 4.9 on page 4-16 and see chapter 4.10 on page 4-18
- Start Scan: see chapter 4.13 on page 4-28
- Single scan: see chapter 4.13 on page 4-28
- Stop scan: see chapter 4.13 on page 4-28
- XY-Curves : optional; see additional manual for this mode

View - You may change the appearance (colors, fonts) of the ScanPanel user interface with the functions in this submenu.

- Palette a color spectrum for displaying the recorded images can be chosen in this submenu:
 - Glow

palette Bruker Nano Glow (standard)

• Grey

- grey scale palette "red"
- Red
 Green note
- Green palette "green"
- Blue palette "blue"
- Rainbow palette "rainbow"
- Channels used for switching between one- and four-channel display
 - 4 Images per page
 - 1 Image per page
- Color to change color of control elements
 - Tab changes color for registers
 - Spin Edit changes color for text fields
- Font adjusts the font of the control elements
 - Axis changes font of the axis
 - Z-Scale changes font of the Z-Scale color bar
 - Tab changes font of the registers
 - Spin edit changes font of the text fields
 - Headings changes font of the headings
 - Frames changes font of the frames



• Oscilloscope changes font of the oscilloscopes

Adjust

- Signal Adjust, this function is important but should not be often used. Thus there is no corresponding button. see chapter 4.6 on page 4-4
- Phase: see chapter 7.3 on page 7-14
- XY Linear: see chapter 7.1.2 on page 7-2
- Z Sensor: see chapter 7.2 on page 7-12
- Z Gain: see chapter 5.5 on page 5-5
- Lock in: see additional PM-Control user manual
- Advanced settings: see chapter 5.9 on page 5-19

AFM Parameter

- Calibration: see chapter 7.4 on page 7-17
 - Calibration Image max range: starts scanning for calibration
 - Calibration data: opens calibration data window
- Align: see chapter 7.4.5 on page 7-29
- Plane Correction:see chapter 5.10 on page 5-20
- External Channel Configuration, see chapter 5.11 on page 5-22
- Acquisition Delay Time, see chapter 5.12 on page 5-25
- Auto Save: see chapter 5.13 on page 5-27
- Auto Retract: see chapter 5.14 on page 5-28

Help

- Info shows the version number of the ScanPanel software.
- Modul Info this function read out the version numbers of the moduls inside the ScanControl.

5.3 Available buttons

The tool bar is for fast access of frequently used functions and setting changes. The tool bar is shown in figure 5-2.



Fig. 5-2 Tool Bar of the main window

For calling a function, just click with the left mouse button on the corresponding button.

The icons have the following meaning:



Opens the MODE/CHANNEL window; see chapter 4.7 on page 4-6



Opens the **TIP APPROACH** window; see chapter 4.9 on page 4-16, and see chapter 4.10 on page 4-18



Start scanning with "auto repeat"; see chapter 4.13 on page 4-28



Start scanning one full image; see chapter 4.13 on page 4-28

Chapter 5





Pause; the line by line motion of the scanning process stops. This means the current line is scanned continously.

opens another profile display, where forward and backward profile can be displayed simoultanously; see chapter 4.18 on page 4-36



ШÚ

Interrupts the scanning process. The tip is moved to the center of the set scan range. see chapter 4.13 on page 4-28



Opens the dialog for saving the recorded image data; see chapter 4.18 on page 4-36



Switches between single-image and four-image display. see chapter 4.8.5 on page 4-15



Displays company details

Input field for the image resolution (number of lines by points); see chapter 4.8.3 on page 4-14

512 x 512	•

All buttons in the tool bar contain a so called "quick-info". If the mouse pointer is moved over the button, a legend is displayed.

5.3.1 Button appearance

Available Functions are indicated with colored buttons in the tool bar and black font in the menu bar. Active functions are indicated by imprinted buttons. During measuring, some functions are disabled; corresponding buttons appear grey.

Function active	Function not active	Function disabled		
	H			
Button imprinted	Button not imprinted	Button grey		

For example the active measuring channel is also indicated by an imprinted label. see chapter 4.8.5 on page 4-15



5.4 The recording image window

In this window are your measurement data are displayed during scanning.

A tracker can be opened and modified here to set a smaller area for the next image (see chapter 5.6.1 on page 5-9).

5.5 The field "Z CONTROL"

During measurement the field "Z-CONTROL" has to be checked precisely. Here the parameters for the z-feedback loop are to be optimized during scanning. To do so, there are two displays and four adjust elements:

The display elements are:

- the diagram for displaying a profile (other term "Line scan" in "Oscilloscope"
- the display "RANGE" or the "Rangemeter"

The adjust elements are:

- The slider for P-part of the feedback control (P = proportional)
- The slider for I-part of the feedback control (I = integral)
- The slider "DISPLAY SENSITIVITY" to change the contrast (i.e. the scaling) of the oscilloscope
- The Input field for the scan speed ("SCAN SPEED")

The display and adjust elements are explained in the following

The profile display "oscilloscope"



Fig. 5-3 The diagram to display a profile; "Oscilloscope window"

The data of the selected measurement channel are displayed as a line profile on this "oscilloscope". The horizontal axis shows the pixel number (if you measure an image with 512 x 512 pixels this axis will also have 512 points). The vertical axis shows the unit of the selected measurement channel (e.g. nm or °; degrees).

The oscilloscope window is used to help adjusting the Z-feedback loop control. In addition it will also give an impression of the dimension of the measured channel (e.g. approximate height, approximate phase deviation) assuming the corresponding calibration is correct.



The "range meter"

The full length of the range meter bar corresponds to the maximum available zrange of the scanner. When the tip is approached, the position of the z-range is displayed through the position of a bar inside this range. The used z-range within the last recorded scanning line is displayed through the dimension of this bar.

The width of the bar shows the percentage of the currently used Z-range with respect to the available Z-range. The position of the bar shows the position of the scanner.

If the bar is in the upper part (close to 100%) the scanner is rather contracted. If the bar is in the lower part (close to 0%) the scanner is rather elongated.



Fig. 5-4 Rangemeter

Further information, see chapter 4.16 on page 4-32

Note: Adjust these sliders only with small steps! Wait after each adjustment for the result, which is displayed after the full scanning line is recorded. Wrong adjustment may increase tip wear! Much too fast settings can cause acoustic feedback (whistling of the scanner). In this case pull up the sliders immediately.

The control speed for the P- and I-part of the feedback is adjusted using these sliders.

If the sliders are moved downwards the control speed will be increased; moving the slider upwards will decrease the control speed.

Further information regarding the use of the P- and I-part control see chapter 4.8.2 on page 4-13 or see chapter 4.14 on page 4-30.



Fig. 5-5 Slider P and I for Z-Feedback adjustment



The Slider "DISPLAY SENSITIVITY"

Contrast	This slider adjusts the display sensitivity of the Oscilloscope Window.
T:	The number below the slider shows the value used for am- plification of the current data point. The amplification is used for better display of the data.
	The settings of the display sensitivity slider will have an ef- fect on the Oscilloscope Window and the display of the mea- surement in the measurement data window. It will not affect the raw data, which you will store after the scan is finished.
19,511	Fig. 5-6Slider "DISPLAY SENSITIVITY"

Input field "Scan Speed"

Scan Spe	ed / line/s
1	-

The value in this field determines how fast the raster scanning will be performed. The unit is lines per second.

Further information can be found in chapter 4.8.4 on page 4-14 or in chapter 4.15 on page 4-31.

Fig. 5-7 Input field "SCAN SPEED" - number of recording lines per second

Input field "Z-Gain"



This is a percentage of maximum available voltage for deflecting the scanner in z-direction. A value smaller 100% decreases the maximum Z-Range. I.e the range of the digital to analog conversion is decreased, which means increasement of the digital resolution. This improves the instrument performance on flat samples.

Fig. 5-8 Input field "Z-GAIN" - percentage of maximum Z-Range



5.6 The field "XY CONTROL"

This section is used to choose and adjust the lateral scan range and position. To do so five input fields and one display window are available.

The input fields are:

- X Range
- Y Range
- X Offset
- Y Offset
- Angle
- square

The scan range is influenced by the input fields "X RANGE" and "Y RANGE". These settings can be used to zoom into or out of a previously acquired image.

The input fields X Offset and Y Offset are used to move the position of a zoomed image.

The input field Angle is used to turn the next measurement by the corresponding value.

The input field square is for more convenient typing of the same X- and Y-Range.

The image shown in the display window is always the last image which was measured with maximum possible scan range without rotation (Angle = 0). It is intended for easy orientation on the sample.

The setting of a scan range can be done also graphically, via opening a frame with the mouse. This was described shortly (see chapter 4.8.1 on page 4-12 and chapter 4.19 on page 4-37). It will be described more detailed in the following paragraphs.



5.6.1 Opening the selection frame

In the maximum scan range window of the field "XY Control" the frame for graphically setting the scan range can be opened up. It can be opened alternatively in the field for the recorded image, but within the previously scanned range.

The first time after program start, the selection frame is opened up in the field for the actual recorded image (large image field) after the following procedure.

- Click with the left mouse button in the large image area.
- Draw with mouse button pressed the selection frame. The selection frame is a square after opening.

In the field for the maximum scan range (small image field), the frame is opened up after the following.

- Click with the left mouse button in the small image area. The frame is active now with its maximum size.
- Move the mouse pointer over the frame until the pointer is converted to "zoom" (see next paragraph).
- While pressing the left mouse button, move up the mouse to downsize the frame.
- After this, the selection frame can be modified further on. The available functions are displayed in the following.



5.6.2. Scaling up or down the selection frame

In the middle of the selection frame has the mouse pointer the shown design (see right).

Γ	Ξ	1	
L			

Press the left mouse button and move the pointer up or down. The frame becomes scaled up or scaled down proportionally with it.



Fig. 5-9 Scaling up/down the selection frame proportionally



There is another possibility to change the size of the selection frame quick and easy:

Move the mouse pointer to the field for the maximum scan range (small image field). Click with the **right mouse button**.



Following small selection menu opens in the frame:



Fig. 5-10 Context Menu for the selection frame

The items in the context menu have the following meaning:

Maximize select maximum scan range.				
Square (X)	The value "Y-RANGE" is set on the same value as "X-RANGE".			
Square (Y)	The value "X-RANGE" is set on the same value as "Y-RANGE".			



5.6.3. Changing the selection frame from one corner

At the corners of the frame the mouse pointer has the following design (see right):

Press the left mouse button while drawing with the mouse. The selection frame becomes scaled up or scaled down corresponding to it.

The actual size of the selection frame is displayed in the input fields for "X-Range" and "Y-Range".



Fig. 5-11 Scaling up/down the selection frame from one corner

Note: In the calibration tool this pointer has a different sense (coupling)



5.6.4. Changing the selection frame from one edge

At he edges of the selection frame the mouse pointer is shown with the following design (see right):
Frame width: smaller/wider....

Press the left mouse button and draw with the mouse. The width or the height can be scaled up or down separately and independently from each other.



Fig. 5-12 Scaling height or width of the selection frame separately



5.6.5. Shifting the position of the selection frame

Outside the middle of the selection frame, the mouse pointer is shown with the proportional zoom in / zoom out symbol (see right).

In the middle of the selection frame is the mouse pointer shown with the following symbol (see right):



머리

Press the left mouse button and move the mouse. Like this it is possible to shift the selection frame. With releasing the mouse button, the selection frame is set at the new position.



Fig. 5-13 Shifting the selection frame



5.6.6. Turning the selection frame

At the corners of the selection frame, the pointer is shown with the following design (see right):

Press the left mouse button and draw with the mouse. Like this, the selection frame is turned around its middle to the left or to the right. With releasing the mouse button, the selection frame is set at the new position.

The effective angle is shown in the input field "ANGLE / DEG".



Fig. 5-14 Turning the selection frame



5.6.7. The meaning of X- and Y-Offset

The coordinate system of the large image field (recording image) and of the small image field (xy-control) are not identical. The large image field is shown with the coordinate system of the set scan range. The small image field is shown with the coordinates of the maximum scan range.

With the next image, you will learn the meaning of the parameters X-Range, Y-Range, X-Offset, Y-Offset (see figure 5-15).



Fig. 5-15 Coordinate system of the set scan range and maximum scan range (vers. 1.1p)

The origin (zero) is in the middle of the respective window for both. The parameters "X-Offset" and "Y-Offset" are related to the distances between the origin of the selection frame and the origin of the maximum scan range. Please pay attention to the sign.

The Parameters "X-Range" and "Y-Range" are related to the set scan range. These are the length of the selection frame edges.

Note:	The orientation of "Y-Offset" has been inverted from ScanPanel 1.1p on. "X-
	Offset" and "Y-Offset" refer to the maximum scan range coordinates. "X-Ran-
	ge" and "Y-Range" refer to the set scan range coordinates.



5.7 The status bar

The left side of the status bar on the bottom of the main window indicates on the current status of the system, like secondary scanner movements:



Fig. 5-16 ScanPanel Status bar (left side) with three different indications

If the system is ready for a new input the left side indicates "ready".

The right side of the status bar shows additional information, like:

Scanner#2 LINE: 91 SP: 221.961 µm/s ASV: ON FN: t0014 LIN: ON HV: ON NONCONTACT

Fig. 5-17 ScanPanel Status bar (right side), one example

The right side of the status bar gives information like:

FCTOPO:	Field contrast ration from field contrast setting
Scanner#:	shown if more than one set of system parameters has been setup in the system
LINE:	currently scanned line
SP:	scan speed in $\mu\text{m/s}.$ This is computed by the adjusted scan speed in lines/s, and the set scan range
ASV:	Autosave setting on/off
FN:	file name and number for the current autosave file
LIN:	Linear setting from mode/channel window on/off
HV:	High voltage on/off setting from mode/channel window
NONContact:	mode setting from mode/channel window



5.8 Slider parameter setting; SLIDER PROPERTIES

The Range and other properties of the most sliders on the user interface can be changed in the submenu "SLIDER PROPERTIES".

Click with the right mouse button on the slider.



 Slider Properties

 Max:
 0.00510

 Max:
 0.00000

 Min:
 0.00000

 TickFrequency:
 10.000

 LargeChange:
 0.005

 SmallChange:
 0.001

 OK
 Cancel

The slider Properties dialog Menu is opened:

Fig. 5-18 The dialog field "Slider Properties"

Following parameters can be changed

1	Min Max.	Min. and Maxvalue of the slider.
2	TickFrequency	Spacing of the scale.
3	LargeChange	step width by using the keys "page up" or "page down" or by clicking with the mouse below or above the slider.
4	SmallChange	step width by using the keys "line up" or "line down" (available in sub dialog windows)



The dialog field "ADVANCED SETTINGS" can be opened during scanning in Non-contact mode. The parameters "SET POINT" and "FREE AMPLITUDE" can be adjusted here. The adjustment through the scanning makes it possible to optimize these parameters during a scan.

Note: The setting is only available in the Non-contact mode with "coarse calibration" switched off.

The additional dialog field may be opened in the menu "PARAMETER -> PLANE CORRECTION".

isisi SC	CANPanel					
File	Scanning	View	Adjust	AFM Parameter	Help	
₽	🗽 🖶		Si	gnal Adjust		1 🔛 🦿
				hase		
			X	/ Linear		
			Z	Gain		●//
			A	dvanced Settings		

The "advanced settings" dialog field opens up:

	Advanc 📧
	Set Point / %
I	65
	Free Ampl. / nm
	150

Fig. 5-19 Step profile using Auto Slope

The parameters "SET POINT" and "FREE AMPLITUDE" can be adjusted here during scanning. These parameters are exactly the same as in the "Tip Approach (Non-contact)" window.



5.10 Plane Correction

Topographic AFM-images show usually a small height relative to the lateral image size. The proportion, lateral to vertical, is usually μ m to nm, i.e. > 1:1000. Thus it appears that tilt angles in this range are shown as a strong inclination in the images. Usually this inclination dominates the topographic images. The features which are to be investigated can be much smaller. Thus the software needs to compensate this inclination of the images. This is called plane correction.

Note:

All image adjustments using the plane correction will affect the displayed image but not the raw data. All adjustments described below may be also done during the scan.

The settings for the plane correction can be modified in the menu "PARAME-TER -> PLANE CORRECTION".



The standard setting is "AUTO SLOPE". With this setting the software calculates a slope and an offset of each scan line automatically. The displayed image is compensated by this slope and offset.

The setting "AUTO MEAN" disables only the slope compensation for each line, but the offset is compensated further on. This may be useful if you have a sample with a step like profile. Keeping the mode "AUTO SLOPE" it would be displayed as below (see figure 5-20).



Fig. 5-20 Step profile using Auto Slope

In Auto Slope mode the software tries to adjust the different levels of the step and creates an artificial slope. In this situation you should use the Auto Mean



mode. The same sample would be displayed as shown below: (See figure 5-21).

	_2 Lontrol _	Topography	Display Sensitivity
6.709 µm	2 µm 4	100 200	1,000

Fig. 5-21 Step profile using Auto Mean

In "AUTO MEAN" mode the step is displayed correctly, i.e without creating an artificial slope.

If you chose "AUTO MEAN" or "AUTO SLOPE" mode, the options submenu is enabled. Go to PARAMETER ->PLANE CORRECTION -> OPTIONS (AUTOMATIC); the PLANE CORRECTION (AUTO) window opens.

Plane Correction (Auto)
Y Plane Average over 20
OK Cancel

Fig. 5-22PLANE CORRECTION (AUTO) dialog window

The plane correction functions computes the offset over a number of raster lines. The number of lines considered, can be entered in the field "LMS AVERAGE NUMBER" (LMS – Least Mean Square). In the figure 5-22 the number of considered lines is 20. If not yet 20 lines are completed, the corresponding number of lines at the end of the last scanning image are add on.

The **check box** in the above image affect the display of the image after the scan is ready. The image becomes recomputed anyway: if unchecked all lines are considered, if checked the number in the field is valid.

The plane correction works with linear regression. The linear regression in x of one raster line gives the parameters a (slope) and b (offset) of a straight line: $g(x) = a^*x + b$. The linear regression in y over all the offset values b(y) give another straight line: $b'(y) = u^*y + v$.

For slope correction the value $g(x,y) = a^*x + b'(y)$ is substracted from each pixel. The parameter a is computed separately for each line. The number of scanning lines for computing the parameter b' can be set in the above shown "PLANE CORRECTION (AUTO)" dialog window.

The last plane correction mode is the "AUTO OFF" mode. Go to **PARAMETER** -> **PLANE CORRECTION** -> **AUTO OFF**; In this mode the submenu "PLANE MANUAL" is enabled. Go to **PARAMETER** -> **PLANE CORRECTION** -> **PLANE (MANUAL)**. The "PLA-



NE CORRECTION (MANUAL)" window will open.

PlaneCorrection (Manual)	×
Parameter: Topo Slope X	ography Slope Y	Offset
	<	
C Auto Para C Auto Slope	,	OAD
	ОК	Cancel

Fig. 5-23PLANE CORRECTION (MANUAL) window.

In this window you may choose the settings for the slope in the fast scanning direction (slope X) and the slow scanning direction (slope Y). Using the arrow buttons the values may be increased or decreased. The more arrows are on the button the bigger the steps will be. You may also input a value in the text fields.

To load the settings which would be used by the automatic software slope and offset correction click the "LOAD" button in the "LOAD AUTO PARAMETER" submenu. Auto Slope will display the slope correction parameters; Auto Mean will display the offset correction parameters. These parameters may be used to get initial values for the manual plane correction.

5.11 Configuration settings for Extern Channels

The controller *SCAN*Control *C* provides one standard read in port to read in and store data, synchronized with the scanning procedure. This port is intended for the optional metrology sensor (also called Z-Sensor). If required by the customer, it is possible to modify this port for reading in an external voltage. Further more the *SCAN*Control *C* provides the option to install another module for three more read in channels.

To display the data scaled and with units in the ScanPanel, the configuration of the extern channels have to be made. The kind of signal connected and its unit,



SCANPanel		
File Scanning View Adjust	AFM Parameter Help	
🛃 🗽 🖶 🔜 🔁 🔤	Calibration	+
	Align	
	Plane Correction	→
	Extern Channel Configuration	
	Acquisition Delay Time	
	Auto Save	
	Auto Retract	

needs to be named and the range of values needs to be specified.

To configure the external channels, go to $\ensuremath{\mathsf{PARAMETER}}$ -> $\ensuremath{\mathsf{EXTERN}}$ Channel Configuration

The settings for the separate channels can be entered in the window EXTERN CHANNEL PROPERTIES.

Extern Channe	el Properties		×
Extern Char Extern Char Data Type Sgl. Source	Topography Topograph	Data Preview Extern 1 Extern 2 Extern 3 Extern 4	
Name Min Max Unit	ZSensor		
	a.u.	OK	Cancel

Fig. 5-24 Settings for the metrology sensor (also called Z-Sensor).

In figure 5-24 the standard configuration for the metrology sensor (also called Z-Sensor) is shown. The signal at the "ZS" connector is hardware connected to the EXTERN_4 channel. With the standard setting "TOPOGRAPHY" the voltages, digitized from the input "ZS", will be recorded in the channel "Z-SENSOR". The data will be scaled by using the calibration data for the Z-Sensor acquired by the semi automatic calibration (see chapter 7.4).



Note: Standard system parameters may not include the setup for enabling configuration change. This is only possible for distinct hardware setup. If there is no effect with configuration changes, check with your service supplier or with the manufacturer.

5.11.1 Read in of an extern voltage

For recording an external voltage signal, your system need to be prepared to do so. If this is the case, connect your external signal to the z-sensor socket. The signal needs to be in a range of between approx. -4V and +4V (due to hardware tolerances, this value is unique for every device). The signal can be recorded synchronized with the scanning in channel "EXTERN4". You need to configure the channel according to the example below.

Extern Channel Properties	×
Extern Channel Measure Mode Extern_4 User Extern Channel Properties Data Type User Sgl. Source User	Data Preview Extern 1 Extern 2 Extern 3 Extern 4
Name Extern4 Min -4	
Unit V	
	OK Cancel

Fig. 5-25 Settings for additional hardware, supplying an external voltage.

Example: Your additional device produces a signal in the range of $\pm 4V$. It is connected to the "ZS" socket. The recording channel should be scaled in volt. Please enter the following parameters (see also figure 5-25):

 EXTERN CHANNEL: MEASURE MODE: DATA TYPE: 	Extern_4 User	input configuration device
DATA TYPE:SGL. SOURCE:	USER USER	data type signal source
NAME:MIN:	External Device -4 (on request -10)	signal name minimum value

UNIT:

- 4 (on request 10) maximum value V unit is volt

5.11.2 configuring additional read in channels



One possible extension of the system is, to purchase a module for reading in three more external channels.

The additional hardware module must be properly plugged in and fixed at the *SCAN*Control *C* main board unit by a skilled technician. If your *SCAN*Control *C* is provided with BNC sockets "EXTERN1", "EXTERN2" and "EXTERN3" at the rear panel, the three inputs at the card need to be connected to them.

The presence of the additional module is automatically detected by the software (see "HELP-> MODUL INFO") The three input channels are named "EXTERN1", "EXTERN2" and "EXTERN3". They need to be configured according to the above example, separately for each extern Channel. In contrast to the Z-Sensor input the standard signal input range is +/- 10 Volt.

The additional module comes with exact calibrated values for Min. and Max. To provide exact voltage measurement, you should enter the calibrated values for Min. and Max. after the above mentioned example.

5.12 Acquisition Delay Time

The ScanPanel offers the option to start the raster scanning procedure after a certain delay period.

This may be required for certain measurements, i.e to reach highest resolution.

Measurements may be already disturbed by the presence of persons in the room. Conversation or persons entering or leaving the room produce noise and thermal drift. This can affect the results of high resolution measurements. Also vibrations of the building (produced on another floor or nearby the building) can disturb the results.

To avoid those disturbances - which are usually much stronger during day time - the measurement may be set up and delayed a certain time to measure at night or during the weekend.



To configure the software to delay the measurement please follow the next steps:

SCANPanel	
File Scanning View Adjust	AFM Parameter Help
	Calibration >
	Align
	Plane Correction
	Extern Channel Configuration
	Acquisition Delay Time
	Auto Save
	Auto Retract

The ACQUISITION DELAY TIME window will open:

Acquisition Delay Time			
Delay Time	20 🔺 sec		
	OK Cancel		

Fig. 5-26 Acquisition Delay Time window

In the input field Delay Time a time span in seconds is entered. The start of the measurement will be delayed by this time. The count down will begin after you start a single scan or a continuous scan. The maximum delay time is currently 30.000 seconds.

After pressing the "Start measurement" button, a window will be displayed showing the count down until the raster scanning will be started. The scan will be started automatically when the count down is finished.

1	Acquisition Delay Time				
	Current Operation				
	Acquisition Delay				
	Time remaining: 10 sec				
l	Cancel				

Fig. 5-27 Acquisition Delay Time countdown

It is recommended to use the Auto Save option (PARAMETER -> AUTOSAVE, see also "The Auto Save Function" in this manual) in combination with the acqui-





5.13 The Auto Save Function

The ScanPanel offers the option to save your measurement results automatically.

If this option is activated, the acquired data will be saved automatically each time after one full image is recorded or the "Stop" button is pressed.

To configure the auto save option go to AFM-PARAMETER-> AUTOSAVE.

SCANPanel		
File Scanning View Adjust	AFM Parameter Help	
🛃 👥 🖶 💾 🖃 🔤	Calibration	+
	Align	[
	Plane Correction	→
	Extern Channel Configuration	
	Acquisition Delay Time	
	Auto Save	
	Auto Retract	

The "AUTO SAVE OPTIONS" dialog window will open.

to Save Opti - Auto Save C		
🔽 Auto Save		
Save only if	no. of lines is greater than:	
• 0%	C 25% C 50% C 75% C 100%	
- File Paramete	31	
Browse		
Location	C:\backup images\	
File Name	scanned file number	
File Counter	0000	
Comments		
	OK Cancel	

Fig. 5-28 "AUTO SAVE OPTIONS" dialog window.



	function. If the box is check	ed to switch on or off the auto ked the auto save function is ac-
Browse	ders to choose a folder to	ed to browse through your fol- store your measurement files. for your files. A consecutive o this name.
Location C:\backu	p images\	The text field "LOCATION" dis- plays the folder name, whe- re the file is stored.
File Name Scanned f	file number	The text field "FILE NAME" dis- plays the name for the mea- surement file. A consecutive number will be attached
File Counter 0000		The text field "FILE COUNTER" displays which number was attached to the last file name.
© 0% C 25% C	050% 075% 0100%	The current image is only sa- ved if the number of scanned lines has reached the set per- centage before the scan was stopped.

After you have entered all information to the window leave it by clicking the "OK" button. If you want to discard your changes use the "CANCEL" button.

5.14 AUTORETRACT- automatic tip retraction

You may configure the ScanPanel for automatic tip retraction in case there is the danger of a tip crash.

To configure the automatic tip retract routine go to PARAMETER > AUTO RE-TRACT.





The window "AUTO RETRACT" will open:

A	Auto Retract				
	Automatic retraction in case of:				
	Stop button pressed				
	C Acquisition finished				
	Danger of tip crash				
	Danger of loosing contact				
	OK Cancel				
	 Danger of tip crash Danger of loosing contact 				

Fig. 5-29 Options dialog for automatic tip retraction

The selectable options for automatic tip retraction are:

 Stop button pressed: 	The tip will be retracted each time, the measurement gets stopped by using the STOP-Button (located in the ScanPanel
 Acquisition finished: 	main screen/tool bar). The tip will be automatically retracted each time the image acquisition is finished; using e.g. 512 x 512 pixels, the acquisition is finished after the 512th line.
• Danger of Tip crash:	The tip will be automatically retracted and the scanning will be stopped, if you run the risk of pushing the tip into the sample surface. This is indicated, if the Z-Range meter is at its highest position (it is highly recommended to use this setting).
 Danger of loosing contaction 	t:The tip will be automatically retracted and the scan stopped if you run the risk of loosing contact with the sample surface. This is indicated, if the Z- Range meter is at its lowest position. This is not indicating danger to the tip or the system. Howe- ver, the acquired pixels without the tip in approach contain no information.

By checking the box 🔽 the automatic tip retract will be activated for the corresponding option, by unchecking the box 🗖 the option will be deactivated.

However, strong handling errors can not be avoided by automatic tip retraction. Please take care, especially on following situations:

- With the *Nanos* in a microscope turret, do not turn the turret before retracting the tip manually, e.g. after a scan.
- With manual stages, do not move the sample laterally during the *Nanos* is approached to the sample.

Chapter 5





In this chapter is explained, how tip changes are performed. For operating with an optical microscope turret, the centering of one optical lens with respect to the *Nanos* tip position is explained additionally.

6.1 Causes for tip wear

The surface structure of the sample surface as well as the tip can suffer from tip wear during scanning. There are several reasons for these unwished modifications, particularly of the tip shape. It can be caused by normal use as well as by careless operating. The normal tip wear comes from:

- friction between the tip and sample surface in the CONTACT MODE.
- friction between the tip and condensation film on the surface.

Careless operating leads to more drastic effects on the tip shape. The following situations should be avoided:

- The topography of the sample surface in the scanned area must not be higher than the Z-Range of the scanner. Check this with the displayed "Z RANGE". Correction: reduce the set scan range "XY-RANGE", or start scanning at another position on the sample.
- Violent touch between tip and sample surface, caused by improper manual approach.
- Incorrect setting for proportional part, P, and integral part, I, of the closed loop Z-FEEDBACK control system.
- Scanning speed too fast.
- Particles on the cantilever from dirty samples or friction at the tip through too big particles on the surface; use samples free from micro particles wherever possible.
- Incorrect setting of the approach parameters, for example "LOAD FORCE" or "SETPOINT".

6.2 Indications for tip changes

The sharper the tip, the more exact is the image of the measured structure usually. But there can be done still measuring, also with a blunt tip. It depends on the matter of investigation and the shape of the blunt tip, if the tip needs to be changed immediately or not. For example very small and rare particles on a otherwise flat sample become imaged more clearly by a tip with a plain end. But it needs to be considered that the reproduced particles show not the true size and shape. The following phenomena indicate that the tip lost its sharpness.

- Edges appear multiple in the recorded image. This means, the fine tip end is already split into several (mostly two) tips.
- Triangle shaped structures of same size in the images are potentially produced by a blunt tip. A sectional view of a standard tip is a triangle.
- If the topographic signal jumps up or down during raster scanning, it comes along with tip wear. Jumping up indicates the tip collects a particle. Jumping down indicates the tip loses a particle (e.g. from wear of friction). Dirt at the



cantilever may be hard to remove. Tips need to be changed usually in this case. Do care for clean samples!

- Small structures show up blurred or more often sharp, but with a bigger size, compared to previous recorded images of the same sample (check first correctly set OPERATING POINT ADJUST).
- Open the dialog field "FREQUENCY ADJUST(NON CONTACT)'" If the amplitude versus frequency diagram looks unusual (e.g. numerous flat peaks), this can also indicate a bad tip. However a not proper affixed tip (e.g. trough dirt on the alignment chip) can cause this too.

6.3 Summary of the procedure

This paragraph is a checklist for tip changes. The points in the checklist will be explained detailed in the following paragraphs.

- Remove *Nanos* from its stand after loosening one screw
- Remove cantilever connector from the *Nanos* after loosening one allen screw. There are two different designs (air and air/liquid version).
- Remove cantilever chip from the cantilever connector after opening the clip.
- Replace the cantilever chip on the cantilever connector.
- Mount cantilever connector on the Nanos.
- Mount *Nanos* on its stand.



Note:

6.4 Remove Nanos from its stand

6.4.1 Quick-snap adaptor design (microscope)

Always touch the ring on the lens turret to rotate this. Never rotate the lens turret by the lens. This causes the loss of centering.

Step 1:

Retract sample stage and *Nanos* to their stops. To retract, press the button

us

in the TIP APPROACH dialog field or use the hand wheel.

Fig. 6-1 Hand wheel for Z-Approach

Note: some microscopes do not have a limit switch before the stop. Press always the stop button, before the block is reached.

Step 2:

loose the locking screw (varying designs) on the quick-snap adapter, keep hold of the *Nanos* while doing so.

Note: the Nanos must be held to stop it from falling down. This is to avoid damage through misaligned snap mechanism. Do not change the factory setting of the other screws at the adaptor!

Step 3:

Hold the *Nanos* with one hand and swivel it to one side at the lens turret.

Step 4:



Only touch the Nanos body, never the white scanner end piece! Hold the body at its edge or at the cable lead through with two fingers of the other hand to prevent the Nanos from falling onto the sample stage. If possible, use the cap on the Scanner.

Unplug *Nanos* from the lens turret downwards.

Fig. 6-2 Plugging out the scanning head (3 photos)















Inside parts of the measuring head **may break**! Particular danger of breakage at the scanner end piece from impact and yaw (lateral) force! **Touching** the cantilever chip tip **renders this useless**!

Step 5

Turn the *Nanos* upside down and carefully place it in the base plate (ring) that comes with the quick-snap adaptor. Tighten the locking screw (plastic).



Fig. 6-3 Example for base plate (Ring)

6.4.2 Changeable microscope turret design

If the microscope has a removable lens turret the additional quick-snap adapter is usually not needed.

In this case the complete lens turret is removed from the microscope and turned upside down to change the tip.

6.4.3 Z-Adapter design (PICOStation)

Procedure:

- Retract *Nanos* with the motor or with the hand wheel (1.) to its upper stop or to its limit switch.
- Remove the Allen screw (2). Keep hold of the Nanos while doing so.
- Remove the *Nanos* together with its Z-Adaptor from the guide pin into the direction of the arrow. (Danger of breakage; see above).



Fig. 6-4 Photo from the PICOStation


6.5 Remove cantilever connector from the *Nanos*

6.5.1 Standard design for measurements in air

Note: The Nanos should be placed in the holder (base ring), coming with the quicksnap adaptor. Tighten the locking screw (plastic) for this work.





Inside parts of the measuring head **may break**! Particular danger of breakage at the scanner end piece from impact and yaw (lateral) force!

Step 1:

Carefully loose the fastening screw of the cantilever connector with the Allen key.

Compensate lateral forces, if necessary, by a slight counterpressure, e.g. with the finger nail.



Step 2:

Slide on the cover bracket (do not tighten the Allen screw yet). Remove the cantilever connector from the *Nanos* carefully with the cover bracket.

Touch always gently. Do not work with large forces, in particular if the cover bracket gets jammed.

Step 3:

place the cantilever connector in its transportation box.

For storage in the transport box affix the cover bracket to the cantilever connector by turning the Allen screw out. The thin layer of soft material in the upper shell affixes the plug, when the box is closed.





_Fig. 6-5 Cantilever plug (4 photos)



6.5.2 Design for measurements in fluids

Note:

The Nanos should be placed in the holder (base ring), coming with the quicksnap adaptor.Tighten the locking screw (plastic) for this work.



Inside parts of the measuring head **may break**! Particular danger of breakage at the scanner end piece from impact and yaw (lateral) force!

Step 1:

Unplug the electrical connector from the socket at the *Nanos*.

The contact fits in both directions. The design makes it impossible to invert the poles.

Step 2:

loose the Allen screw at the cantilever connector carefully.

Touch it always gently. Do not work with large forces, in particular if the cover bracket gets jammed.

Step 3:

Slide on the cover bracket (do not tighten the Allen screw yet). Remove the cantilever connector from the *Nanos* carefully with the cover bracket. Do not pull at the connecting cable.

Step 4:

place the cantilever connector in its transportation box.

For storage in the transport box affix the cover bracket to the cantilever connector by turning the Allen screw out. The thin layer of soft material in the upper shell affixes the plug, when the box is closed.









Fig. 6-6 Liquid Plug change (4 photos)



6.6 Replacing the tip on the cantilever connector

Note: The cantilever connector must be removed from the scanner end for tip changes, otherwise the tip may get into contact with the optical fiber end.

The tip is replaced without adjustments. The work should be carried out on a firm table while seated. It may help to replace it under a stereo microscope.





Touching the tip part at the cantilever chip renders this useless!

Tools needed:

- 1 Cantilever connector
- 2 Cantilever chip in adhesive package
- 3 Fine tweezer
- 4 Screwdriver

The objects shown are included in delivery.



Procedure:

- Remove the spring clip, if attached.
- Loose the screw (3) until the spring clip (2) is open.
- remove the used tip (1).
- Insert the new tip carefully into the alignment chip under the spring clip (see next page).





3

Fig. 6-8 Cantilever connector

Fig. 6-7 Tools to change tips

The cantilever chips used have a negative structure on their back side. Adjustment is done by inserting the tip into the corresponding positive structure on the cantilever connector (see chapter 2.5.3, page 2-9).



-Fig. 6-9 Adjustment structure (alignment chip) (1), Tip (2), Tip inserted correctly (3)



This is how the procedure can look like:

- Pick the cantilever chip with the tweezer as shown (see figure 6-10). Loose it trough turning from the adhesive pad.
- Now pick up the cantilever chip more at its front to put it easy under the spring clip.
- Now put the cantilever chip from the front or from the side under the spring clip (see figure 6-11 left or right)

For safe handling it is recommended to support the tweezer by one finger of the other hand.

- If the cantilever chip is not yet positioned exactly on the positive bars, slide it carefully sidewards by the tweezer into its position (see figure 6-12 left).
- Before closing the spring clip check the right position of the cantilever chip optically. Look at the reflected light (e.g. daylight) by using the chip as a mirror. Touch the cantilever chip centric and from top, softly with the tweezer.

If the tip moves or bounces, it is not yet in the right position.



Fig. 6-10Cantilever Chip taking out from storage box



Fig. 6-11Cantilever-Chip inserting, frontwards (left) or sidewards (right).



Fig. 6-12Aligning the cantilever chip (right); position check by touching from top (left).

<u>Note</u>: safe tip change needs some practise. Practise the tip change with a used cantilever chip! Do not touch the alignment chip with the tweezer or sharp tools. This may easy damage the alignment chip, in particular at the positive bars



- Close the spring clip with the screwdriver.
- Slide on the cover bracket. If the cantilever connector needs to be transported, affix the cover bracket by turning the Allen screw outwards.



film



Fig. 6-13Closing the spring clip for the cantilever chip

6.7 Mount cantilever connector on the Nanos

6.7.1 Standard design (for operation in air)

Note:

The Nanos should be placed in the holder (base ring), coming with the quicksnap adaptor. Tighten the locking screw (plastic) for this work



- loose the Allen screw from the pin in the storage box (if existing) and from the cover bracket as well.
- Take care, that the screw is not screwed in too far, otherwise the connector can not be mounted.
- Carefully pick up the cantilever connector with the cover bracket.



Fig. 6-14Connector storage box

Insert the part into its socket on the measuring head. Keep its attitude so, that the cantilever connector can not fall off the cover bracket.

Avoid touching the optical fiber end with the bottom side of the cantilever connector.

- Remove cover bracket sidewards.
- Bring the cantilever connector to its correct position by slightly pushing it downwards. Push coeval on both sides of the connectors chassis, e.g. from top with both nails of your Fig. 6-15Connector insertion to scantwo thumbs.

The cantilever connector is placed on the ceramic ferrule of the optical fiber. It is inserted correctly, if still approximately one sheet of paper fits between the bottom side of the connector and the scanner.

- Tighten the Allen screw of the cantilever connector with the originally supplied Allen key. You can care for compensating lateral forces, by a slight counterpressure, e.g. with the finger nail.
- Check the correct position with the interferometric signal: open the Dialog field "SIGNAL Fig. 6-16Screwing cantilever connector ADJUST" with system switched on and Scan-

Panel open (). If the parameter "gain" is

adjustable and if its value than is common for this special cantilever connector, tip and cantilever connector are both placed correctly.

6.7.2 shielded design, (for operation in fluid)

Note: The Nanos should be placed in the holder (base ring), coming with the quicksnap adaptor. Tighten the locking screw (plastic) for this work







ning head







Procedure:

- loose the Allen screw from the pin in the storage box (if existing) and from the cover bracket as well.
- Extract the electrical connector from its sokket in the storage box.
- Carefully pick up the cantilever connector together with the cover bracket. Support also the electrical connector. Do not pull at Fig. 6-17Liquid plug storage the cabel.
- Insert the part into its socket on the measuring head.

Avoid touching the ferrule and optical fiber end with the bottom side of the cantilever connector

- Remove cover bracket sidewards.
- Bring the cantilever connector to its correct position by slightly pushing it downwards. Push coeval on both sides of the connectors chassis, e.g. from top with both nails of your two thumbs.

The cantilever connector is placed on the ceramic ferrule of the optical fiber. It is inserted correctly, if still approximately one sheet of paper fits between the bottom side of the connector and the scanner.

Insert the electrical connector into its socket at the Nanos body.

The contact fits in both directions. The design makes it impossible to invert the poles.

- Tighten the Allen screw of the cantilever connector with the originally supplied Allen key. You can care for compensating lateral forces, by a slight counterpressure, e.g. with the finger nail.
- Check the correct position with the interferometric signal: open the dialog field "SIGNAL ADJUST" with system switched on and Scan-Panel open (). If the parameter "gain" is adjustable and if its value than is common for this special cantilever connector, tip and can-

tilever connector are both placed correctly. Fig. 6-20Screwing liquid connector

6.8 Mounting the Nanos on its stand





Fig. 6-18Connector plug insertion



Fig. 6-19Liquid plug electrical connector





6.8.1 Inserting into the microscope quick-snap adaptor





Inside parts of the measuring head may break! Particular danger of breakage at the scanner end piece from impact and yaw (lateral) force! Touching the cantilever chip tip renders this useless!

Step 1:

• Insert the *Nanos* as shown into its quick snap adaptor in the microscope lens turret. The Nanos locks with a snap.

Only touch the Nanos body, never the white scanner end piece! Hold the body at its edge or at the cable lead through with two fingers of the other hand to prevent the Nanos from falling onto the sample stage. If possible, keep the cap on the Scanner attached.



Fig. 6-21Head insertion to quick snap

Step 2:

- Keep hold the *Nanos* safe during you turn the logo frontwards and the cabels to the rear, so that other lens are not touched.
- Lock the *Nanos* with the single screw.

Do not change the factory setting of the other screws at the adaptor!



Fig. 6-22safety screw at quick snap



6.9 Centering one optical lens with respect to the tip position

The centering procedure is used to bring the focus of the optical microscope to the position of the *Nanos*. With the Bruker Nano centering adaptor it can be done for a single lens. With a polarizing turret it can be done for each lens, although it makes only sense for the lens with high magnification.

Step 1:

Position the Bruker Nano **centering sample** on the sample stage of the microscope.

On the centering sample is a structure, consisting of 256 x 256 squared fields. The squares are numbered hexadecimal. Each square shows its row and column number one upon the other. The period of the squared structure is 10 µm. The style of letters (from 2006) is similar to OCR-A. Other specifications see Appendix.



Fig. 6-23Centering and calibration sample

Step 2

Record one image with the *ULTRA*-Objective from this sample to define the tip position. (see chapter 4 on page 4-1). Do not move the sample from this point.

The parameters X-Offset and Y-Offset in the ScanPanel main window need to be set to zero for the centering procedure. (see on page 4-12). The suggestive set scan range (X-Range, Y-Range) is 20 µm - 40 µm (also with scanning stage systems).



Fig. 6-24AFM image of the centering sample

Step 3

Swivel in the center able lens, usually the one with highest magnification, by only handling the turret.

Always touch the ring on the lens turret to rotate this. Never rotate the lens turret by the lens. This causes the loss of centering

Fig. 6-25Optical lens with centering adaptor





Step 4: Compare the optical image with the recorded raster scanning image (see figure 6-26 A and B).





Fig. 6-26Situation before centering.

A: Image recorded with the *Nanos* at position 8F,77B: seen through the optical lens before centering

Step 5:

Use the enclosed Allen keys to move the cross hairs in the optical image to the position of the raster image (see right).

In the example, you need to move the cross hairs to position 8F,77 for centering.

Fig. 6-27Centering the optical lens





A: Image recorded with the Nanos at position 8F,77
 B: seen through the optical lens with correct centering

Step6: Check the centering: bring again the *Nanos* in position and record another image; compare it to figure 6-26 A. If the position is different, you need to perform the centering one more time.

BRUKER 7 ADJUSTMENT AND CALIBRATION

The device is calibrated from factory side. The sensors for position determination are adjusted according to the scan range of the *Nanos*. We recommend to double check the adjustment and calibration at regular intervals. Especially changes in the ambient conditions (i.e. temperature) may require a new calibration. In case your *Nanos* has not been used recently or if it has been used sporadic the calibration should be checked previous to further measurements.

An adjustment of the linearization requires always a new calibration. Therefore the adjustment of the linearization is described first.

Note: We recommend to save the system parameters previous to any changes (see chapter 3.5.1 on page 3-8, step 1).

7.1 Adjustment of X/Y LINEARIZATION

The software adjustments for "X/Y-FEEDBACK" loop (the linearization) are described in this chapter. Two facts have to be considered:

- The range of possible X- and Y-Positions is measured and stored by using the function "LINEARIZATION TABLE".
- The X/Y-Feedback loop is adjusted by the proportional P and the integral I part for both scanning directions.

The piezoelectric materials used to produce the scanning head show non-linearities between the applied voltage and the deflection. That is the correlation between applied voltage and mechanical deflection of the scanning head is not linear. Using a scanning probe microscope without linearization will therefore result in distorted images. This distortion can be avoided with your *Nanos* by the linearization. The linearization secures that the deflection of the scanning head at each pixel is controlled by the position sensors (see chapter 2.5.9 on page 2-16).

The standard version of the *Nanos* comes with sensors (strain gauges) which measure the real X-Y position of the tip in the scan range.

In "LINEAR ON" mode the positioning of the scanning head is done by the control circuit. This control circuit is called **X/Y-Feedback**; it controls the X-Y position of the tip according to the position information from the sensors. This mode is also called "Closed Loop mode".



7.1.1 Preparations

Previous to the adjustment of the linearization the following steps are required:

- 1. Switch the computer system on and wait until the operating system has started (see also chapter 4.5 on page 4-3).
- 2. Switch on mains switch for the measuring electronics *SCAN*Control *C* on the front of the device.
- 3. Start the *ScanPanel* program, e.g. by double clicking the DESKTOP SYMBOL:



- 4. Wait until the system has warmed up (at least 30 min.)
- 5. Go to "MODE/CHANNEL" and switch off the option "LINEAR", please make sure "HIGH VOLTAGE" is switched on.
- 6. Do some scans with maximum scan range; these scans may be preformed without approach on the sample, or, to do a double functionality test, on a sample with well known features (e.g. Bruker Nano centering sample).
- 7. If you did the warm-up scans on a sample retract the scanning head now by clicking the button "RETRACT" in the window "TIP APPROACH". After several turns of the step motor click "STOP".
- 8. Go to "MODE/CHANNEL" and switch on the options "LINEAR"; "HIGH VOLTAGE" should still be active.

7.1.2 Open the menu X/Y-Linearization

Note: Before opening this menu make sure the tip is retracted from the sample surface. To be able to open the menu [®]X/Y LINEAR...[®] the options "HIGH VOLTA-GE" and "LINEAR" have to be activated in "MODE/CHANNEL" WINDOW.

Note: The error message "Calculate new LINEARIZATION TABLE" may indicate also, that the scanner is not properly connected or that it is damaged.

Select "ADJUST" from the menu bar and click "XY LINEAR...".





The menu "LINEARIZATION" appears on your screen.



Fig. 7-1 Menu "LINEARIZATION"

IN THIS DIALOG FIELD YOU CAN START A PERIODIC SCANNER MOVEMENT. THIS IS IN-TENDED TO DO RANGE DEFINITION AND FEEDBACK TRIM FOR LATERAL LINEAR CON-TROLLED SCANNER MOVEMENT (closed loop mode or "LINEAR ON"). THE TABLE GIVES A SHORT VIEW ON AVAILABLE FUNCTIONS. THE FOLLOWING PARAGRAPHS SHOW HOW TO PERFORM THE ALIGNMENT.

Tabelle 7-1: Labels and terms in the menu "LINEARIZATION".

1	SENSOR SIGNAL	This diagram (the "oscilloscope") shows the mea- sured deflection of a piezo actuator as "SENSOR SIGNAL". The signal is shown over two periods of piezo tube movement with maximum deflection. In addition the curve of target values for the linear movement is shown in the diagram. The range of target values is determined by the function "LINEARIZATION TABLE".
2	SCAN SPEED	Available scan speeds for this menu.
3	POSITION	Position of the scanning head for the unmoved direction.
4	LINEARIZATION TABLE	Button for automatic measurement of the maxi- mum scan range (details see below).



Tabelle 7-1: Labels and terms in the menu "LINEARIZATION".

5	FEEDBACK ADJUST	These sliders are used to adjust the speed of the loop "XY-FEEDBACK" by increasing or decreasing the proportional or integral part. The adjustments have to be done for the chosen scan speed and separately for both orientations.
6	READ DATA - START	Starts a periodic scanner movement with chosen orientation and speed. The sensor signal of the corresponding actuator is shown in the diagram for two periods of the movement.
7	READ DATA - STOP	Stops scanner movement.
8	LINEAR ON/OFF	No meaning from vers. 1.1.n on; switches bet- ween: controlled scanner movement (ON) and scanner movement without position control by sensors (OFF).
9	ERROR SIGNAL	Shows the deviation between sensor signal and <i>ULTRA</i> value. In closed loop mode the deviation signal should be as small as possible without causing resonance of the scanning head.
10	ERROR SIGNAL SCALE	Amplification factor for the error signal display.
11	ORIENTATION	Determines the scanning direction for the adjust- ment of the X/Y Feedback loop.

More detailed explanations for these functions will be given in the text below.

7.1.3 Linearization range (LINEARIZATION TABLE)

Note:	<i>Note: The options</i> "HIGH VOLTAGE" <i>and</i> "LINEAR" <i>have to be activated in the m</i> "MODE/CHANNEL".			
	Checking range definition of the linearization	on sensor signals		
	Adjust "Scan Speed" : The selected scan speed is only effective within this window (effects also the function "LINEARIZATION TABLE").	Scan Speed		
	Adjust "ORIENTATION ": Chose which scanning direction should be used.	Orientation		



CLICK "READ DATA - START".

The scanning head begins moving periodically with the selected orientation and the selected speed. This is displayed in the diagram window "SENSOR SIGNAL". Please check, as also described below under "Procedure", if curve 2 in figure 7-2 (target curve) is located between minimum and maximum of slightly bent curve 1 ("SENSOR SIGNAL").

AFTER DOING SO CLICK **"READ DATA - STOP"**. The scanner movement is stopped.



Operating mode description: Upon pushing the button "START" the scanning head starts moving periodically with the selected orientation between its minimum and maximum deflection. A triangle voltage is applied to the scanning head for this movement.

The position of the *Nanos* is detected by its position sensors (strain gages). It is displayed in the sensor signal diagram as curve 1 (see figure 7-2). This diagram (oscilloscope) shows two periods of the movement. Curve 2 shows the target values of the deflection for a linearly controlled movement.

The scanning head moves only with selected orientation and selected speed. The other orientation is kept constant at the positions "XPOS" or respectively "YPOS" (in units of pixels with reference to the pixel number selected in the main window).



Fig. 7-2 Example for diagram before and after correctly adjusted "LINEARIZATION TABLE"

Procedure: Please check according to figure 7-2, if it is required to readjust the linearization by using the function "LINEARIZATION TABLE"; the minimum and maximum value of curve 2 should be within the vertical range of curve 1. All target values can be reached in this case.

Afterwards check this for the second "ORIENTATION". If this condition is fulfilled for both orientations, you do not have to recalculate the "LINEARIZATION TABLE", In this case skip the next step and proceed with chapter 7.1.4 on page 7-7.



New range definition of the linearization sensors:

Note: If the function "LINEARIZATION TABLE" is used it is required to re-calibrate the "X-RANGE" and "Y-RANGE" (see chapter 7.4 on page 17).

Click the button "LINEARIZATION TABLE". The maximum linear scan range in Xand Y-direction will be defined.

This procedure is performed with the speed selected at "SCAN SPEED".

The necessary time for the procedure is displayed. After it is finished check the maximum scan range as described under "Check measured maximum scan range" (see on page 7-4).



Calculating Linearization Table! Time: 13 sec

Operating mode description: by clicking "Linearization Table" the maximum possible deflection in X- and Y-direction are re-measured. To do so, the scanning head is first moved periodically in X- and then in Y-direction. The direction not moved stays in the middle of its scan range (not at "XPOS", "YPOS"). The movement is performed with the scan speed selected in the "SCAN SPEED" menu. The scanning head is moved five times between minimum and maximum deflection. During the last three cycles the maximum and minimum sensor values ("DMS-values") are recorded and averaged.

This defined DMS-Range presents a table of the maximum available scanner deflection. DMS-values will be computed, where the scanner is controlled to at each piloted pixel.

The maximum scan range is calculated with a 2% tolerance to the real maxima.

If curve 1 touches or excesses the upper or lower border of the Sensor Signal Diagram the electronics cannot process the data. In this case a new hardware adjustment by Bruker Nano GmbH or your local representative is required.

If the button "LINEARIZATION TABLE" is pressed without properly connected scanner, the images in mode "LINEAR" can show large distortions.



7.1.4 P/I value adjustment of the X/Y-FEEDBACK

Step 1 - Select SCAN SPEED

Select the scan speed for the scanning head in this window. It is recommended to use a setting similar to the scan speed for the image acquisition.



Note:	The scan speed may be also changed after starting the data acquisitio				
	Step 2 - Select X- or Y-direction				
Select the scanning direction you want to adjust first.		t first.			
ORIENTATION X:					
	Setting for movement perpendicular to the cantilever logitudinal axis.	Orientation C X Direction			
	ORIENTATION Y:	CYDirection			
	Setting for movement in cantilever axis				
Note:	The orientation must be adjusted previous to				

te: The orientation must be adjusted previous to the scanner movement. To change it after starting the scanner movement, please press the "READ DATA - STOP" button first.

Step 3 - Start scanner movement

Click the button "**START**". Now the scanning head moves periodically with the selected speed and orientation.



Note:

The scan speed may be altered after starting the data acquisition; XPOS, YPOS, ZPOS *and* ORIENTATION *cannot be changed after its start.*





Fig. 7-3 Scanner movement with "X/Y-FEEDBACK" loop switched off.

The diagram Sensor Signal ("Oscilloscope") displays

- (1) the measured X- or Y- position and
- (2) the linear target value curve for X- or Y- position.

The oscilloscope shows two periods of the movement. The difference between the two curves reflects the non-linear portion of the movement. This deviation is displayed in the oscilloscope Error Signal (3). The screen shot was made in ("LINEAR OFF"), (4).

Step 4 - Switch on linearization

Note: The "LINEAR ON" switch has no meaning from vers. 1.1.n on. It can be only selected AFTER the start of the scanner movement.

Activate "LINEAR ON".

The "X/Y-FEEDBACK" is now switched on.

Γ	Linear on/off		
	✓ Linear. on/off		

The two displayed curves (see figure 7-2) should be adjusted in the following to match each other.

If the "ERROR SIGNAL" shows only small steps the adjustment is correct (mind the amplification factor). For optimal match, the sliders for P-proportional and I-integral part of the X/Y-Feedback loop have to be adjusted.



The following table gives examples for too fast, too slow and correct adjustment of the P and I values. The result of your adjustments should be similar to "PI OK".



Tabelle 7-2: Adjustment for P and I slider of the "X/Y-FEEDBACK" LOOP

Chapter 7



The values for P and I can be only changed by the sliders; typed in values in the corresponding fields will not be accepted (see chapter 5.8 on page 5-18)

Click the **"STOP" BUTTON**. The scanner movement will be ended. The display in the diagram will not change anymore.



Deactivate "LINEAR". This will switch off the X/Y-Feedback loop control.

If "LINEAR" *is not switched off the scanner movement cannot be re-started.*



Step 6 - Adjustment for second orientation

The adjustments have to be repeated for the second orientation. Switch the orientation as shown:

ORIENTATION X:

For loop adjustment of slider in X-direction

ORIENTATION Y:

For loop adjustment of slider in Y-direction

Click the button "START".

The scanner moves now again periodically with the adjusted speed in the selected orientation.

Activate "LINEAR ON".

The "X/Y-FEEDBACK" loop control is now activated. Proceed with Step 5 - Adjust P/I values (see on page 7-9) and adjust the second orientation.





Linear on/off		
Linear. on/off		



Step 7 - Close dialog window

Click the "STOP" BUTTON BEFORE CLOSING THE LINEARIZATION DIALOG WINDOW.



Confirm the settings for the LINEARIZATION MENU BY HITTING THE OK button. If you select "CANCEL" the settings will not be saved.

Note:	After adjustment of the linearization the calibration of the maximum scan ran-
	ge has to be performed.



7.2 Offset trim of the Metrology Sensor signal (Z-SENSOR)

Note: The "Z-SENSOR" is an optional function for the Nanos.

This chapter will explain how the adjustment for the amplifier of the Metrology Sensor is accomplished. This procedure is a hardware adjustment. The Offset of an amplifier is trimmed by a potentiometer. This might be required after changes of the ambient conditions (temperature, humidity). Usually the amplification factor "GAIN" does not have to be adjusted; this could be only set by opening the device.

Note: It is mandatory to retract the tip from the sample previous to selecting the function "ADJUST -> Z-SENSOR".

Select the optional function "Z SENSOR" from the "ADJUST" section of the menu bar.



The dialog window Z-SENSOR opens.





Adjustment and CalibrationVersion 1.2 (May. 2009) - MH



The scanning head is now periodically moving through the maximal possible Z-RANGE. Two curves are displayed in the diagram ("oscilloscope") of the dialog field "Z-SENSOR". These two curves are acquired and displayed during the periodical Z-movement of the scanning head.

Curve (1) shows the desired position in the Z-range as a function of time. Curve (2) displays the measured Z-SENSOR values.

The vertical axis represents the maximum range of the Z-SENSOR value. The measured Z-SENSOR values must be within this range.

The potentiometer at the "Linear 2000 box" has to be trimmed in order to adjust the range of the measured Z-SENSOR values (see photo).

Note: Please use only the small, slanted, labeled screwdriver which came with the system! Do not confound it with the screwdriver for tip changes. Using any other screwdriver may cause damage to the electronics of the linear 2000 box.



Fig. 7-5 Potentiometer for amplifier offset of the Z SENSOR.

The adjustments have to be made according to figure 7-4, right hand side. The curve is supposed to fit into the window with sufficient space at the top and at the bottom.

After the adjustment leave the dialogue window by hitting the OK button.

OK	

Note: Adjusting the Z-SENSOR OFFSET requires to check the Z-SENSOR calibration (see chapter 7.4 on page 17).



7.3 Adjustment of the PHASE Channel

The channel "**PHASE**" is used for recording the phase difference between the excitation signal (*Phase of the CPV signal*) and the true oscillation of the cantilever (*Phase of the interferometer signal*).

If the excitation of the cantilever is at its actual resonance frequency, the phase amounts 90° theoretically. This 90° is adjusted hereby. The signal delay in the electronic circuits and in the optical fiber can be compensated through this adjustment.

The Parameter "PHASE DIFFERENCE" will be adjusted in the following for recording the PHASE signal. The adjustment may be performed with approached tip.

Note: The phase channel is part of the optional NON-CONTACT module. If PHASE was selected in the MODE/CHANNEL window (see chapter 4.7.1 on page 4-6), the function for adjustment can be chosen.

Select the function "PHASE" FROM THE "ADJUST" SECTION OF THE MENU BAR.



The dialog window PHASEDIFFERENCE appears:



Fig. 7-6 Dialog window PHASEDIFFERENCE

Adjustment of the parameter "PHASEDIFFERENCE":

Automatic Adjustment; without user intervention, the adjustment is done auto-



matically. The slider is moved through its whole range and afterwords it is moved back so that the phase signal reaches its middle. After this, you may leave this dialog field with "OK" and the phase adjustment is done.

<u>Manual adjustment</u>; the slider may be also used to manually set the phase. To do so click on the slider with the left mouse button, hold it down, and move the slider to the designated value.

<u>Details:</u>

To make full use of the available range of 0°-180°, an adjustment to 90° is reasonable.

The Phase slider effects on shifting the phase of the excitation. The amount of this shifting can be in the range of 0°... 360°. The Phase of the true cantilever oscillation is measured with respect to this shifted excitation signal.

The Phase amounts to a value between -180° and 180°. However, only its norm is measured. This shows also figure 7-6: After 180° is reached, the phase signal becomes smaller again. The range between 180° and 360° is mapped onto a phase signal between 180° and 0°. I.e. an increasing phase shows up as a decreasing signal in this range. This may be used for inversion of the phase contrast in the recording image.

The scaling of the phase signal is calibrated from the automatic adjustment. The Minimum of the phase signal corresponds to 0° and the maximum corresponds to 180° .

Inversion of the contrast in the phase image can be produced as follows:

- With retracted scanner by setting the "Operating Point Adjust" to the inverted edge, see chapter 4.10.1 on page 4-19. This turns the phase by 180 degrees. and inverts the direction.
- By edge inversion of the slider "PHASEDIFFERENCE". Note how the movement of the slider effect on the phase signal in the diagram. It can be both up/down or one up and one down. Moving the slider to inverted action causes contrast inversion of the phase signal
- Apart from this you may find by trying different settings for "PHASEDIFFE-RENCE" other favorable contrast settings. For example, if the norm of the phase signal should be recorded, it can be done by setting the signal to "0°".

The scaling of the phase images is in degree. It is saved including the images. The scaling is calibrated from the min. and max values, read out in this dialog. Therefore this dialog field needs to be opened one time after each system start before recording phase images.

The channel "PHASE" may visualize structures not visible in the "TOPOGRAPHY". THE NEXT IMAGE SHOWS AN EXAMPLE (PHASE AND TOPOGRAPHY ON BRUKER NANO



CENTERING AND CALIBRATION SAMPLE).



Fig. 7-7 PHASE image example (from the centering sample).



Note: The factory-made calibration values should be checked in regular intervals.

The system may be calibrated by using a suitable, regular, and well-known structure. In the following the "Bruker Nano centering and calibration sample" is used. The calibration of the below parameters should be checked regularly.

- Scaling of the horizontal axis of the scan range (X-Range)
- Scaling of the vertical axis of the scan range (Y-Range)
- Scaling of the topographic axis of the scan range (Z-Range)
- Scaling of the metrological axis of the scan range (Z-Sensor Range; optional)

The calibration is performed separately for the selected modes and channels of operation.

- LINEAR on and HIGH VOLTAGE on ("LINEAR ON", "HV ON")
- LINEAR off and HIGH VOLTAGE on ("LINEAR OFF", "HV ON")
- LINEAR off and HIGH VOLTAGE off ("LINEAR OFF", "HV OFF")

7.4.1 The menu CALIBRATION DATA

Not: The displayed scales are respectively valid for the selected combinations of "LINEAR ON/OFF", "HV ON/OFF". To change the mode of operation go to "MODE/ CHANNEL".

Select "CALIBRATION, CALIBRATION DATA" FROM THE AFM PARAMETER SECTION OF THE MENU BAR.

SCANPanel			
File Scanning View Adjust	AFM Parameter Help		
🗗 💢 🖶 🖳 🔁 🔤	Calibration	×	Calibration Image
	Align		Calibration Data
	Plane Correction		
	Extern Channel Configuration		
	Acquisition Delay Time		
	Auto Save		
	Auto Retract		

Depending on the selections in the "MODE/CHANNEL" window ("LINEAR" on/off "HIGH VOLTAGE" on/off the corresponding calibration will be displayed.



The display window CALIBRATION opens:

Calibration			
× Calibration × Range	200.70	μm	XY Coupling
Y Calibration			
Y Range	200.70	μm	YX Coupling
Z Calibration —			
Z Range	5.28	μm	DISPLAY
Z Sensor Range	6.58	μm	
- Margin Options-			Zoom
Margin	5.0	%	 Margin Pixel = const.
Margin Width	10997	nm	C Margin Width = const.
Spring Constant			
Spring Constant	0.2	N / m	Margin Pixel
			Cancel

Fig. 7-8 Display window for Calibration values

Tabelle 7-3: "CALIBRATION"	parameters
----------------------------	------------

X CALIBRATION	X RANGE: XY COUPLING:	max. scan range in X-direction. Portion of the X-position, which is added to the Y-position, for compen- sation
Y CALIBRATION	Y RANGE: YX COUPLING:	max. scan range in Y-direction. Portion of the Y-position, which is added to the X-position.
Z CALIBRATION	Z RANGE: Z SENSOR R:	max. Z-RANGE. (option): Range of the metrology tool Z SENSOR (usually larger than Z-RANGE).



Tabelle 7-3: "CALIBRATION	" parameters
---------------------------	--------------

MARGIN OPTIONS	MARGIN: Margin width in percentage of the maxi- mum scan range which is scanned but where no data are acquired. The values may be displayed here but not changed. MARGIN PIXEL =CONST: the margin range is a fixed number of pixels, regardlessly of the scan range. MARGIN WITH = CONST: the margin range is a fixed range, regardlessly of the set scan range. Setting MARGIN PIXEL =CONST is highly recommen- ded. MARGIN WIDTH = CONST may result in a very long recording time for images with small scan ran- ges (long waiting time).
SPRING CONSTANT	Spring constant for the used cantilever type in CON- TACT mode.

The calibration should be checked in regular intervals, but especially after:

- Modifications of the system
- Moving the system to a different location with different ambient conditions (temperature, humidity etc.).
- Adjusting the X/Y-linearization
- Starting the system after a longer period (weeks of months) without operation.

7.4.2 Semiautomatic Calibration

Note: We recommend to save the system parameters previous to any changes (see chapter 3.5.1 on page 3-8, step 1).

The ScanPanel starting with version 1.07 allows semi-automatic calibration of the system.

To perform this type of calibration first a sample with known parameters (calibration sample) is scanned. After that the user enters the real dimensions of the sample.

We use the Bruker Nano-centering sample for it. This has appropriate structures for the standard maximum scan ranges. Also the mode HV-off can be calibrated with the small structures in its corners (see chapter 8.1 on page 8-1).

Please follow these instructions for the semi-automatic calibration:

- Approach the tip to the sample (see chapter 4.9 on page 16 or chapter 4.10 on page 18). Calibration may be done in "CONTACT MODE" or "NON-CONTACT MODE".
- Start the measurement by selecting "PARAMETER -> CALIBRATION ->CALIBRATION IMAGE -> MAXIMUM RANGE". The measurement will be done by using maximum physical scan range and any rotation or flip (selected in the "ALIGN..." section) will be automatically switched off.



SCANPanel				
File Scanning View Adjust	AFM Parameter Help			
	Calibration	•	Calibration Image	Maximum Bange
	Align		Calibration Data	
	Plane Correction	•		
	Extern Channel Configuration			
	Acquisition Delay Time			
	Auto Save			
	Auto Retract			

The scanning starts as described at once:



Fig. 7-9 Dialog window "CALIBRATION"; register "XY-CALIBRATION".

When the measurement is finished the window "CALIBRATION" will open automatically.

- It is recommended to save the calibration image first ("FILE"-> "SAVE")
- To calibrate the lateral scan range choose register "XY-CALIBRATION".
- Execute plane correction; you have several options:



Automatic plane correction:

Calculates an averaged plane from the height of all pixels of the image (linear regression) and subtracts the plane from the image.



Three point plane correction:

Calculates a plane from the height and position of three points in the image and subtracts plane from the image. The three points are selected by mouse click. Each point considers a median of 5 pixel in radius.

Edge detection:

Displays the edges of the image.

• It is recommended to use the three point plane correction. The points should be all placed on the structure or all on the substrate (valleys). Try which plane correction is tilting the image least.

File

e Processing

Image Pr

• For "XY-CALIBRATION" draw a frame around the structure. To do so use the button "INSERT TRACKER". Using the mouse the frame can be adjusted to the structure (figure 7-10).



tion.





Fig. 7-10 Calibration image with inserted frame ("TRACKER") for XY CALIBRATION.

The frame may be moved and modified like described in chapter 4.8.1 on page 12. Only the edge cursors have a different meaning. The lower right curser is used to correct the "coupling" respectively the "non-orthogonality". The other edge cursors are not active.

Note:	The accuracy of the calibration strongly depends on the accuracy of the fra- me around the calibration structure.		
	 Open the window "PITCH" by clicking the "XY CALIBRATION" button. The window "PITCH" opens. 		



Pitch	×
Pitch X 30.000 μm Y 30.000 μm	OK Cancel

Fig. 7-11 Dialog field "PITCH".

- Enter the real edge length into the dialog field "PITCH" for the X- and Y-direction.
- Leave the window "PITCH" by hitting the "OK" buttons. The new calibration values for "X-RANGE" and "Y-RANGE" will be calculated. The image will be displayed with the new scaling.

Z-CALIBRATION

The next section will explain how the "Z-CALIBRATION" is performed.

• For "Z-CALIBRATION" choose the corresponding register.



Fig. 7-12 Dialog field "CALIBRATION", register "Z-CALIBRATION"

• Execute plane correction. You may use automatic plane correction or 3-point-



plane correction but not edge detection (see on page 7-20 for further explanations)

 Insert a line for a cross section by holding down the left mouse button and dragging a line (if the system does not start to draw a line push the >Insert< key on your keyboard). Choose the position in a way that a step with a known height is well visible inside the profile window.



Fig. 7-13 Dialog field "Calibration", register "Z-Calibration" with cross sec-



• Hit the button "PROFILE".

The window "E" opens up:



Fig. 7-14 Cross section for calibration of the Z-RANGE with markers.

• Arrange marker 1 and 2 on the same level; arrange marker 3 and 4 on the other level. The corresponding markers will be connected by a line (see figu-



re 7-14).

- Enter the height difference between the two levels in the field "PITCH".
- Close the window by hitting the OK button. The new "Z-RANGE" will be calculated. The image will be displayed using the new scale.

Z-SENSOR Calibration

For "Z-SENSOR" calibration choose the corresponding register and proceed like described for the "Z-CALIBRATION".

Please note: The "Z-SENSOR" is optional and must be chosen in the MODE / CHANNEL window to calibrate it.

SAVE AND CLOSE

• Close the "CALIBRATION" window by hitting the "OK" or "SAVE + CLOSE" button. Now the new calibration values will be applied. If you choose "CANCEL" the values will not be stored.

The calibration must be performed separately for all combinations of "HV on/off" and "LINEAR on/off". To do so one image per choice must be acquired by scanning via "PARAMETER -> CALIBRATION ->CALIBRATION IMAGE -> MAXIMUM RANGE". To switch between "HV on/off" and "LINEAR on/off" open the "MODE / CHANNEL" window.

The calibration values will be stored by your PC and will be applied to all future scans. If you want to store your registry for any re-installation of the system or if you want to use your AFM with an other computer, please proceed as follows: Close the ScanPanel and export the calibration parameters by saving the registry: Open the Windows Registry editor (regedit), mark the path HKEY_CURRENT_USER/Software/SISRegistry and export it (see also chapter 3.5 on page 3-8).

Starting with ScanPanel version 1.07 it is no longer possible to enter directly the parameters for the X-, Y- and Z-RANGE into the "AFM-PARAMETER" -> "CALIBRATI-ON" - "CALIBRATION DATA" window.

7.4.3 Additional functions in the dialog Calibration



Manual input of the lateral calibration values

Alternatively to the graphical determination of the lateral calibration using the tracker values may be typed in manually. Please follow the procedure described below:

- Print calibration image in large format (e.g. by evaluating the saved image with image processing software or print screen).
- Click the button "EDIT SIZE AND ANGLE".



An input window opens.

Dialog		X
b b H X Range	Length XRange 1.5 4 a 1.5 4 b 1.5 4	Angle α β Ο Cancel

Fig. 7-15 Dialog menu for input of calibration values

Measure the length of the edges of the structure on the print out by means of a ruler and enter the values in the corresponding fields (see figure 7-15).

X Range	SIZE OF THE COMPLETE, QUADRATIC SCANNED IMAGE (E.G. IN CM.)
a	LENGTH OF THE KNOWN HORIZONTAL EDGE OF THE CALI- BRATION SAMPLE IN THE PRINT OUT (E.G. CM.)
b	LENGTH OF THE KNOWN VERTICAL EDGE OF THE CALI- BRATION SAMPLE IN THE PRINT OUT (E.G. CM.)
α	ANGLE BETWEEN THE HORIZONTAL EDGE OF THE CALI- BRATION SAMPLE AND THE HORIZONTAL EDGE OF THE IMAGE (E.G. +3°)
β	ANGLE BETWEEN THE VERTICAL EDGE OF THE CALIBRA- TION SAMPLE AND THE VERTICAL EDGE OF THE IMAGE (E.G. +3°)


- Leave the window by clicking the "OK" button.
- Click "XY CALIBRATION".



The window "PITCH" opens:

Pitch	×
Pitch	
× 30.000 🔺 μm	
Υ 30.000 μ m	ОК
	Cancel

Fig. 7-16 Dialog field "PITCH".

- Put the known real edge length sizes into the dialog field "PITCH". They have to correspond to the entries for a and b in figure 7-15.
- Click "OK" to leave the window "PITCH". The new calibration values "X-RANGE" and "Y-RANGE" will be calculated from the entered values. The image will be displayed with the new scale.

Adjusting the CONTRAST

You may adjust the contrast for better visualization. Similar to the "DISPLAY SEN-SITIVITY" the contrast adjustment in the "CALIBRATION" window is done automatically between the highest and the lowest pixel. But it can be also increased by a percentage of the automatically adjusted range.

• To do so click the button "CONTRAST".

The window "CONTRAST" opens up:



Contrast	X
Cut Off 10.0 🚔 %	Cancel



Fig. 7-17 Dialog field "CONTRAST"

Enter a value between 0% and 50% into the field "CUT OFF". Standard value is 10%. The image will appear brighter now. This function is especially useful for dirty calibration samples.

"Undo"

The function "UNDO" refers to the three functions for the plane correction. It will only undo the last step.

Click the button "UNDO". The last plane correction will be undone.



"DELETE TRACKER".

 Click the button "DELETE TRACKER". The tracker will be deleted. It can be inserted again by clicking "INSERT TRACKER".





7.4.4 Adjusting the spring constant

The **SPRING CONSTANT** has to be adjusted to scale the load force in Contact mode. To do so select "AFM **PARAMETER**" -> "CALIBRATION" -> "CALIBRATION DATA".

SCANPanel			
File Scanning View Adjust	AFM Parameter Help		
	Calibration	•	Calibration Image
	Align		Calibration Data
	Plane Correction	- + ⁻	
	Extern Channel Configuration		
	Acquisition Delay Time		
	Auto Save		
	Auto Retract		

The dialog window "CALIBRATION" OPENS. ENTER THE SPRING CONSTANT INTO THE FIELD "SPRING CONSTANT":

C Spring Constant				
Spring Constant	0.2	▲ N/m	Margin Pixel	28

Fig. 7-18 Dialog field "CALIBRATION - SPRING CONSTANT"

• The spring constant is noted on the cantilever box.

7.4.5 The menu point ALIGN

"ALIGN" is used to mirror and/or rotate the acquired image to match the physical sample orientation or the sample's image in the optical microscope and the AFM scan. The standard settings are: Flip horizontal on, 0°, offset orientation: all activated (see also figure 7-19).

SCANPanel	
File Scanning View Adjust	AFM Parameter Help
🛃 👥 🖶 🔜 🖃 🔤	Calibration •
	Align
	Plane Correction
	Extern Channel Configuration
	Acquisition Delay Time
	Auto Save
	Auto Retract

Select "ALIGN" FROM THE MENU SECTION "AFM PARAMETER".



The menu dialog "ALIGN" opens.

AI	lign	×	
	Scanner Orientation		
	Rotate 0°	C Rotate 90°	
	C Rotate 180°	C Rotate 270*	
	Offset Orientation		
	🔽 🗙 Inversion		
	🔽 Y Inversion		
	Angle Inversion		
	ОК	Cancel	

Fig. 7-19 Dialog window "ALIGN"

✓ ● = Option activated

Tabelle 7-4: Options in "ALIGN" dialog

SCANNER ORIENTATION	FLIP HORIZONTAL: THE IMAGE IS MIRRORED HORI- ZONTAL. THIS IS DONE BY DISPLAYING EACH SCAN- NING ROW BACKWARDS. ROTATE: Rotates the scanned image. This is for alignment with other images, i.e. the optional opti- cal microscope. For vertical flip use both settings.
OFFSET ORIENTATION	X INVERSION: For alignment of the sign of the para- meter X-Offset in the ScanPanel. Due to flip and rotate settings this must be adjusted too. Y INVERSION: For alignment of the Y-Offset in the ScanPanel. ANGLE INVERSION: Direction of turning the scan range.

X marks the position of the horizontal axis in a scanned image (will be displayed correctly if "HV ON" and "FLIP HORIZONTAL" is selected).

 ${\rm Y}$ is the position on the vertical axis (will be displayed correctly if "HV ${\rm ON}$ " is selected).





Note:

Please review the manual of the microscope the Nanos is attached to for cleaning instructions and maintenance.

7.5.1 Cleaning the sample stage

For cleaning the sample stage should be as far away as possible from the *Nanos*. If the *Nanos* is mounted to a microscope turret the turret should be rotated in a way that the *Nanos* is pointing away from the sample stage. Otherwise the risk of touching and damaging the tip is too high.





7.5.2 Cleaning the ferrule

It may be required to clean the ferrule at the end piece of the scanning head. Dirt on the ferrule will partly or completely block the light. This will result in unusual high settings for the "GAIN" in the dialog field "SIGNAL ADJUST".

- Remove the cantilever connector from the scanner.
- Clean the ferrule end (the end of the white pin) very carefully under a stereo microscope or magnifying glass. Use lint free tissue, a cotton swab, isopropanol or compressed air from a can (must be oil and solvent free).
- Some debris or residues, from samples or broken cantilevers, may be persistent. Note: the fiber end inside the ferrule may be <u>never touched directly</u> with sharp objects or even get scratched!



Fig. 7-20 Cleaning the ferrule under magnifier or microscope (1) potential debris, needs to be removed (2) fiber end: do never touch it, particularly not with sharp instruments!





7.5.3 Cleaning the SCANControl ${\cal C}$

- The housing of the *SCAN*Control *C* is best cleaned with a damp cloth.
- Do not use any solvents!
- No moisture is supposed to get into the housing.

Note:	For cleaning instructions of the PC system refer to the manufacturer's ma-
	nual.

Chapter 7







8.1 Centering- and calibration-sample data sheet

Fig. 8-1 Bruker Nano centering and calibration sample (from 2006 on)

Substrate	Material:	Synthetic quartz glass
•	Thickness	1,5 mm ±0,1 mm
•	Sample dimension	5 mm x 5 mm

- Anti Reflective Chrome Structured layer Material: Thickness: nominal 82 nm (margin 80 ±10 nm) Fabric method Electron Beam Lithography
 - Large fields Type Consecutively numbered squares Periodicity 10 µm x 10 µm

Hexadecimal; 00...FF

- Numbering
- Total lateral size 2560 μm x 2560 μm Similar to OCR-A (see figure 8-1)
- Letter Style
- Small fields Position In the four corners of the large field 1µm (former design 1.5 µm) Periodicity
- Type: Symmetric grid (equal size of hills and groves)



8.2 Technical specifications:

Nanos	measuring	head
1103	measuring	neau

Standard maximum ranges Z-only Positioning sensors lateral: Metrology sensor (optional) Deflection detection method	20 µm x 20 µm x 3 µm 40 µm x 40 µm x 4 µm 80 µm x 80 µm x 6 µm 8 µm; for scanning stage (other types on request) strain gages, four per direction strain gages in full bridge circuit fiber optical interferometry
SCANControl C	
Dimensions h, w, d: Weight: Power supply voltage: Protection category Electromagn. compatibility: Type of fuses: Interface to computer Type of computer Digital resolution X, Y, Z Output voltages scanner Output for step motor Output for detector: Laser type built in:	267 mm, 450 mm, 451 mm (excluding feet, including standard handles) ca. 18 kg 110 V - 120 V /60Hz or alternatively 220 V - 240 V /50 Hz SK I, Class A, after test report 21102033_001; TÜV Rhineland 2 x dull 1 A (220 V) or 2 x dull 2 A (110 V) USB Windows operating system; from Win98 SE on 16 bit within set scan range plus 2 x16 bit for setting the size and the position of the scan range $U_x, -U_x, U_y, -U_y$; typical ±165 V U_z : type165 +85 V, CPV: typ. +60 V +4.5 V 5 phase cum micro step mode (optional 2 phase) Optical fiber output; E2000 connector semi conductor; cooled; $\lambda = 785$ nm; P ≤ 1 mW Output laser radiation power: P = 30 µW 16 bit x 3 channels (upgrade able to 6 channels)
laser radiation classifies The controller is, on elec	tegrated a Laser of class 3a. The power of the output the controller to a Laser Class 1 product. tromagnetic compatibility, a Class A product. In a do- product may cause radio interference in which case

Standard stands:

Neosgranite stand; Nanos can be aligned with
incident light, high-grade optical microscope
granite stand for highest resolution

the user may be required to take adequate measures.



8.3 Mains power supply / fuses

Note Before you connect the SCANControl C to mains voltage, make sure that the set supply voltage is equal to the mains voltage, delivered by your local electricity supplier. Switching the system on with a wrong set voltage can seriously damage the device.





- 1 GND Pin plug socket for connecting any device components to earth.
- 2 Power power supply input, carries mains voltage ratchet and fuses



8.3.1 Setting power supply voltage



- Unplug the *SCAN*Control*C* mains connector.
- Open the cover at the mains connector and adjust the ratchet inside after your locally supplied mains voltage.
- Close the cover again.

Note: The adjusted mains voltage remains displayed at the mains connector.

8.3.2 Fuse changes



- Unplug the *SCAN*Control*C* mains connector.
- Open the cover at the mains connector and take out the two fuse holders
- replace the blown fuses in its holder.
- Put the fuse holders back and close the cover again.



8.4 Pin assignments of the SCANControl C connectors

In this chapter the connectors pin layout is shown. All connectors are located at the rear side panel of the *SCAN*Control*C*.



Fig. 8-3 SCANControl C - rear panel (scheme)

Note:



8.4.1 Signal input connectors



Fig. 8-4 Lemo Input connectors SCANControl C

- 3 **XS** X-Sensor-Signal: This is the input connector for the linearization sensor in X direction. The applied voltage from the linearization signal must be in the range of ±4 volt.
- 4 **YS** Y-Sensor-Signal: This is the input connector for the linearization sensor in Y direction. The applied voltage from the linearization signal must be in the range of ± 4 volt.
- 5 ZS Z-Sensor-Signal: This is the input connector for the optional metrology sensor. Instead of for it, it may be used for input signals from other devices (e.g. to record signals from user specific devices).

In this case, the applied voltage can be recorded as channel "extern 4" synchronous with the raster scanning process (if configured in the ScanPanel; see chapter 5.1.6, page 5-7). The applied voltage must be in the range of ± 4 Volt.

Connector design information: Lemo instrument socket, series 00, male pin: order nr.: ERN.00.250.CTA".

GNDS - Ground Sensor: Separate ground for the signals XS, YS, ZS.

6 IN-PS - Input Piezo resistive Signal: linked internal optionally; detector input connector for systems with piezo resistive detector. The applied voltage must be in the range of ±10 Volt Connector design information: Lemo instrument socket, series 0B with two female pins: order Nr.: EGG.0B.302.CLL)



Signal input connectors (continued)

The following input connectors are with optional read in modules internally connected, if available.



Fig. 8-5 Connectors for optional read in channels

1,2,3: IN-1... IN-3 - Input 1... Input 3: low voltage BNC input.

The connector is used optionally as an external input, e.g. for optional devices. The applied voltage can be recorded e.g. as channel "Extern 1... Extern 3". The recording works synchronous with scanning other image data during the raster scanning process.

How to configure the read in channels in the software is described in chapter 5.1.6, page 5-7. The configuration for special external devices (e.g. PM control) is usually specified (see special device manual).

The input voltage is limited to ± 10 V.



8.4.2 Signal output connectors

Note: Please use only the originally supplied cabels



Fig. 8-6 Signal output connectors SCANControl C

- 1 CEV Cantilever Excitation Voltage: Low voltage BNC output. This is linked internal to the optional Non-contact module. The amplitude of the output signal maintains 1 V_{pp}. The cantilever excitation frequency, produced in the Non-contact module is output with this signal. It may be used for external devices (e.g. triggering a lock-in amplifier).
- 2 LV-X Low Voltage X-Channel: low voltage BNC output: The output low voltage corresponds linear with the scanner X-actuation voltage (voltage range see table 8-1 on page 8-9). The output is used e.g. to drive the X component of a scanning stage.
- 3 LV-Y Low Voltage Y-Channel: low voltage BNC output: The output low voltage corresponds linear with the scanner Y-actuation voltage (voltage range see table 8-1 on page 8-9). The output is used e.g. to drive the Y component of a scanning stage.
- 4 **LV-Z** Low Voltage Z-Channel: low voltage BNC output: The output low voltage is linear with the scanner actuation voltage for Z (voltage range see table 8-1 on page 8-9). The output is used to drive the amplifier for the Z-only scanner, in combination with a scanning stage.
- 5 **Interfero-Out** Interferometer output: low voltage BNC output. The output voltage is in the range of ±10 Volt. It is linear with the interferometric signal (linear with the light intensity at the interferometer end). It may be used for external devices (e.g. specific detection units).



Tabelle 8-1: Vo	oltage range of	LV BNC-outputs
-----------------	-----------------	----------------

Connector	Voltage range
LV-X	-1V - 11V
LV-Y	-1V - 11V
LV-Z	-1V - 11V

The output voltage can be customized on request (e.g. ±10V).



Fig. 8-7 Output connectors SCANControl C (continued)

6 **V-OUT** - Voltage Output: This output can be driven via ScanPanel software (Slider "SERVO VOLTAGE"). The output voltage is in the range of -10 Volt to +10 Volt. The output was intended for impressing a voltage at the sample. With some versions of the *SCAN*Control *C*, customized for external devices, this output may not be internally connected. The slider "SERVO VOLTAGE" is not displayed in this case.

Connector design information: Lemo instrument socket, series 00, female pin: order Nr.: ERN.00.250.CTL".

7 CPV - Cantilever Piezo Voltage: This is the output for driving the cantilever Piezo. The output voltage is in the range of -10 Volt to +10 Volt, connected to pin 1 of this socket. Pin 2 is the separate ground of this signal. Connector design information: Lemo instrument socket, Serie0S:, order Nr.: ERA.0S.302.CLL".

Note:

Note:



8.4.3 Nanos/scanner connector

Please use only the originally supplied cabels



Note: Risk of blinding from lasers! Always keep the shutter of the optical fiber connector closed. Do not look into the laser beam, not even with optical instruments!



Tabelle 8-2:	Pin assignment	scanner	connector

Pin	Signal	Description	max. Voltage	Input/Output
1	X-Piezo+	scanner output voltage for electrode "+X"	+200V / -200V	Output
2	AGND X	signal common for X-Piezo+, and X-Piezo-		Output
3	X-Piezo-	scanner output voltage for electrode "-X"	+200V / -200V	Output
4				
5	Y-Piezo+	scanner output voltage for electrode "+Y"	+200V / -200V	Output
6	AGND Y	signal common for Y-Piezo+, and Y-Piezo-		Output
7	Y-Piezo-	scanner output voltage for electrode "-Y"	+200V / -200V	Output
8				
9				
10	AGND Z	signal common for Z-Piezo		Output
11	Z-Piezo	scanner output voltage for electrode "Z"	+200V	Output
12				
13	AGND 15V	signal common 15V		Output
14				
15	AGND 15V	signal common 15V (secondary assigned)		Output
16				
17				
18				
19				
20	Ground	Ground		
21	Ground	Ground		
22	Ground	Ground		
23	Ground	Ground		
24				
25				
26				
27				
28				
29				
30				
31	-15V	-15V power supply voltage	-15V	Output
32	+15V	+15V power supply voltage	+15V	Output
33	Schleife 1	loop for unlocking high voltage	+5V	Output
34	Schleife 2	loop for unlocking high voltage		Input
35				
36				
37				



8.4.4 Motor connector

Note: Please use only the originally supplied cabels.



Fig. 8-9 Connector for coarse approach step motor

The step motor for coarse approach of the tip to the sample surface is connected by the Motor connector (socket type SUB-D 25 pin; assignment see table 8-3 on page 8-13)



Tabelle 8-3: Pin assignment step motor connector

Pin	Signal	Description
1	W5_1	begin of coil nr. 5
2	W4_1	begin of coil nr. 4
3	W2_1	begin of coil nr. 2
4	W2_2	end of coil nr. 2
5	W3_2	end of coil nr. 3
6	W4_2	end of coil nr. 4
7	W1_2	end of coil nr. 1
8	W3_1	begin of coil nr. 3
9	W5_2	begin of coil nr. 5
10	W1_1	begin of coil nr. 1
11		
12		
13		
14		
15		
16		
17	fast	control port for motor speed mode
18	ENC1	encoder 1
19	ENC2	encoder 2
20	Aux1	for optional use
21	Aux2	for optional use
22	+5V	+5 Volt
23	End1	stop switch nr. 1
24	End2	stop switch nr. 2
25	End GND	signal common for stop switches



8.4.5 USB-connector





Fig. 8-10 USB-connector

The USB port is the interface with the computer.



8.4.6 Extension port



Fig. 8-11 connector for optional devices

The extension port is intended for the connection of optional devices.

Chapter 8







A

acquisition mode, 4-11 Acquisition Parameter (save), 4-51 Adjustment phase, 7-14 advanced settings, 5-19 Align, 7-29 Alignment Chip, 2-9, 6-7 amplitude calibration, 4-31, 4-32 Amplitude Channel, 4-13 Angle, 2-15 Angle Inversion, 7-30 approach, 2-18, 4-37, 4-38 manual, 4-49, 4-53 step buttons, 4-50 Argos (PICOStation), 2-18 Atomic Force Microscope, 2-2 automatic approach, 2-18 automatic operating point, 4-27, 4-37 automatic tip retraction, 5-29 Autosave percentage, 5-28 averaging of channels, 4-12

В

Back Channel, 4-13 base ring, 6-4, 6-5, 6-6, 6-9, 6-10 button 1 or 4 images, 4-21 Mode/channel, 5-3 Single Scan, 4-40 Start Scan, 4-40 stop (in main window), 5-4 STOP (main window), 5-4 STOP (Tip Approach), 4-53 Tip Approach, 5-3

С

Calibration, 7-1, 7-13 Align, 7-29 dialog field, 7-18 calibration amplitude, 4-32 insert line, 7-24 calibration sample, 6-13 cantilever, 2-1, 2-2 cantilever chip, 2-2 Cantilever Connector Cover Bracket, 6-5 function, 2-9 replacing the tip, 6-7 standard type, 6-9 standard type removement, 6-5 type for fluids, 6-6, 6-10 Cantilever Piezo, 2-8 Cantilever Plug, 2-10 Cantilever-Piezo, 2-9 centering sample specifications, 8-1 centering sample (SIS), 6-13 Channel (measurement), 4-12 Channel Selection, 4-12 cheat sheet, 4-1 Checklist, 4-1 Cleaning, 7-31 , 7-32 ferrule, 7-32 sample stage, 7-31 Closed Loop, 2-16 Closed Loop mode, 7-1 Closed Loop Scanning Mode, 4-14 coarse calibration, 4-32 connectors CPV, 8-9 Extension, 8-15 GNDS, 8-7 handling, 3-3 IN-1, 8-6 IN-2, 8-6 IN-3, 8-6 IN-PS, 8-7 Interfero-Out, 8-8 LEV, 8-8 LV-X, 8-8



LV-Y, 8-8 LV-Z, 8-8 Motor, 8-12 optical fiber, 8-10 Power Supply, 8-3 Scanner, 8-10 USB, 8-14 V-OUT, 8-9 XS, 8-7 YS, 8-7 ZS, 8-7 Constant Force Mode, 2-11 Constant Height Mode, 2-11 contact measurements, 4-12 Contrast, 7-27 contrast, 5-5 controller, 2-18 Coupling, 7-18, 7-22 coupling, 2-18 Cover Bracket, 6-5, 6-6, 6-11 cover bracket, 6-5 cross hairs, 6-14 Cursor versions meaning, 4-17

D

Dampening, 4-7 Danger dangerous development of heat, 1-2, 1-4 electrical hazard, 1-2 detected wave, 2-6 detector alignment, 6-7 **Dialog** field Signal Adjust, 4-8 dialog field Acquisition Parameter, 4-51 TipApproach (NonContact), 4-26 TipApproach(Contact), 4-22 Display Sensitivity, 4-42 DMS range, 2-17 DMS signal, 2-17 DMS value, 2-17

drift, 4-4 DSP, 2-19 dynamic deflection, 2-12

Ε

edge cursor, 7-22 Edge detection filter, 7-21 edge markers, 4-52 edge markers (selection frame), 4-52 Error Signal, 2-13 Error Signal Channel, 4-13 Excitation, 4-31 Excitation (amplitude calibration), 4-33 Extern Channel, 4-13

F

feedback, 2-12 Feedback Control (Z), 4-44 feedback resonance effects, 4-45 Feedback-setting optimized, 4-44 Ferrule, 6-11 ferrule, 2-10, 6-10, 7-32 fibre-optic interferometer, 2-5 Field Contrast Channel, 4-13 finish measurement, 4-53 first steps, 4-1 Flip Horizontal, 7-30 FM-Control, 2-12 Forward Channel, 4-13 Free Amplitude, 4-35 advanced settings, 5-19 free approach, 4-39 fuses, 8-3

G

Gain Signal Adjust, 4-8





Η

height data, 2-13 High Voltage, 4-15 holder, 6-5, 6-9, 6-10 holder (mount support), 6-6 Hook's law, 2-1

I

1, 4-44 image Phase, 7-16 image acquisition, 4-40 image contrast, 4-42 image recording, 4-40 image resolution, 2-15 installation adaptor rings, 3-7 driver, 3-10 qualified place, 3-2 software, 3-8 software update, 3-8 installing the software, 3-8 integral part I, 2-13 Interferometer Signal, 2-6 intermittent contact, 4-39 isolation system, 4-7

L

Laser, 8-2 laser, 1-4 lateral offset, 4-45 lift height, 4-48 lift range, 5-6 light source, 4-6 line, 2-16 line scan, 5-5 Linear off, 2-16 Linear On, 7-8 Linear on, 2-16

Linear scanning motion, 4-14 Linear2000 box, 3-4 Linearization activating, 4-14 Linear ON, 7-8 setting P/I factors, 7-10 setting P/I-factors, 7-7, 7-10 Start, 7-10 start, 7-7 linearization, 2-16 linearization box, 2-17, 3-4 Linearization Table, 7-4 linearized scan range, 2-17 Liquid-Plugs, 2-10 Liquid-Scanner, 2-10 load force, 2-1, 4-22 long waiting time, 7-19

Μ

magnification, 2-20 mains voltage setting, 8-4 manual approach, 4-49 Margin, 2-18, 7-19 Margin Pixel, 2-16 Margin Width, 2-16 maximum pixel number (resolution), 4-19 maximum scan range, 2-15 Measurement Channel Amplitude, 4-13 Error Signal, 4-13 Error Signal back, 4-13 Extern, 4-13 Field Contrast, 4-13 Phase, 4-13 Topography, 4-13 Z-Sensor, 4-13 measurement data save, 4-51 Measurement Mode, 4-11 measurements in liquids, 1-4 Median filter, 7-21 meter



"Range", 4-38 Range, 4-48 Z Range function, 4-40 metrology, 2-18 metrology sensor, 7-12 mismatch, 4-45 mounting ULTRAObjective at the PICOStation, 6-4 with Z-Adaptor, 6-4

Ν

Nanos (ULTRAObjective), 2-4 Neos (NANOStationII), 2-18 New features, 0-v new scan range, 4-52 noisy images, 4-18 Non Contact measurements, 4-12 non linearized scan range, 2-17

0

Offset, 5-16 Offset Orientation, 7-30 Offset trim Z-Sensor, 7-12 Operating Point Adjust, 4-27 Operating Point Adjust slider, 4-27 Operating Point Warning, 4-27 Operating voltage, 1-3 optical retardation, 2-6 Orientation, 7-4 orthogonality correction, 7-22 oscilloscope, 4-43, 4-45, 5-5 overshooting, 4-45

Ρ

P, 4-44 P/I-factors Linearization, 7-9 P/I-slider

monitoring, 4-44 percentage, 5-7 autosave, 5-28 Phase Adjustment, 7-14 Image example, 7-15 Phase Channel, 4-13 Phase difference, 7-14 PICOStation (photo), 6-4 piezo actuators, 2-3 PI-loop control, 4-44 Pin assignment Motor connector, 8-12 Scanner connector, 8-11 Pitch, 7-23 pivot in ULTRAObjective, 4-6 pixel definition, 2-15 rectangular, 4-19 resolution, 2-15 plane correction, 7-21 three point, 7-21 Potentiometer, 7-13 Preparation, 2-21 presetting the Scan Speed, 4-20 profile, 4-43 profile display (line scan), 5-7 proportional gain P, 2-13

Q

quick-snap adaptor, 6-4

R

Rados, 0-iv Range function, 4-40 monitoring, 4-48 red indicator, 4-49 range meter, 4-49, 5-5 raster scanning, 2-3





Read Data - Start/Stop, 7-5 rectangular pixels, 4-19 reference wave, 2-6 registry, 3-10, 4-4 remove Cantilever Connector (standard type), 6-5 Requirements on the place of installation, 3-2 resolution, 2-18, 2-20 retaining spring, 2-10 Retract, 4-49, 4-53 retracting the tip, 4-49, 4-53 Risk of blinding, 1-1, 1-4, 3-3 Risk of crushing, 1-4 Rotate, 7-30

S

safety margin, 4-6 Safety Regulations, 1-1 Safety regulations Europe, 1-3 hazard warnings, 1-2 operating voltages, 1-3 other countries, 1-3 USA, 1-3 warnings, 1-4 warnings on the rear side of the device, 1-1 safety regulations, 1-1 sampling rate, 4-12 Save, 4-51 save measurement data, 4-51 save image, 4-51 scaling scan range, 7-17 scaling amplitude channel, 4-32 Scan Control dimensions, 8-2 fuse changes, 8-4 mains voltage setting, 8-4 scan pattern, 2-14

scan range, 2-15 Scan Range setting, 4-16 Scan Speed, 2-16, 4-47, 5-7 scan speed maximum, 4-47 maximum reasonable, 4-47 optimizing, 4-47 ScanControl Power supply, 8-3 Scanner, 2-4 Scanner Connector pin assignment, 8-11 Scanner Key / Setup, 4-4 Scanner Orientation, 7-30 scanning, 2-3 Scanning Force Microscope, 2-1 scanning spots, 2-15 Scanning Stage, 4-15 Scanning stage, 4-14 scanning stage, 2-14 Scanning Tunneling Microscopy, 2-2 select channel, 4-12 Contact Mode, 4-11 Non Contact Mode, 4-11 selection frame, 4-52 selection frame (see tracker), 5-12 sensitivity Display Sensitivity, 4-43 sensitivity of detection, 2-8 Set Point, 2-12 advanced settings, 5-19 setting Display Sensitivity, 4-42 High Voltage ON, 4-15 Image Resolution, 4-19 Linear ON, 4-14 load force, 4-22 operating point adjust, 4-27 P/I-sliders optimized, 4-44 resolution (pixel number), 4-19 resonance frequency, 4-29, 4-30



Scan Range, 4-16 scan speed, 4-20 Z-Feedback pre selection, 4-18 Signal Adjust, 4-8 Signal Adjust curve, 4-9 signal processing, 2-18 singing, 4-45 singing of the scanner, 4-18 Single Scan, 4-40 single scan, 4-40 SIS centering sample, 6-13 slow to start, 2-16 software update, 3-8 speed of scanning, 4-20 speed of the tip, 2-16 Spring Constant, 7-19, 7-29 spring Constant setting, 7-29 spring constant, 7-29 square, 4-16, 5-8 stage scanner, 4-14 stand, 2-18 Start program, 4-4 Start scanning auto repeat, 5-3 single scan, 5-3 start scanning, 4-40 static deflection, 2-12 STM, 2-2 Stop Button in tip approach, 4-38, 4-53 Button in tool bar, 4-41, 4-53, 5-4 Stop Scan, 4-41 stop scanning, 4-41, 4-53 System components, 3-1 system parameter, 3-10 system parameters save registry, 3-8

Т

tapping, 4-39 Tiatanos, 0-v time for recording, 4-47 tip, 2-1, 2-2 tip approach, 4-38 Tip changes, 6-1 check list, 6-2 indications for change, 6-1 tip wear, 6-1 tip radius, 2-3 tip wear, 4-45 TipApproach Contact, 4-22 NonContact, 4-26 topographic data, 2-13 Topography, 4-42 topography image, 7-16 Topography Channel, 4-13 tracker, 2-15 delete button, 7-28 opening, 5-9 placing, 5-14 proportional zooming, 5-10 scaling up, 5-12 scaling up/down proportionally, 5-10 turning, 5-15 width/height, 5-13 tube scanner, 2-14 turning off system, 4-54

U

ULTRAObjective centering with optical lens, 6-13 Scanner connector, 8-10 ULTRAObjective mount at the PICOStation, 6-4 changeable lens turret design, 6-4 microscope, 6-12 quick snap adaptor, 6-3



Undo, 7-28 update, 3-8 user account, 4-4

V

vertical range, 4-48 vibration isolation, 4-6 voltage range, 2-17

W

warm-up time, 4-4, 4-54 Warnings, 1-1 wear, 4-47 wear of the tip, 4-45 Weight, 8-2 whistling of the Scanner, 4-18 whistling of the scanner, 4-45 Wiring diagram old tube scanner type, 3-5 scanning stage systems, 3-6 tube scanner systems, 3-4

Χ

X Calibration, 7-18, 7-26 X Inversion, 7-30 X/Y-Feedback, 7-1 X-Offset, 2-15, 5-16 X-Range, 2-15 XY Linearization, 7-2 XY-Control square, 4-16, 5-8 XY-Coupling, 7-18 X-Y-Feedback, 2-16

Y

Y Calibration, 7-18, 7-26 Y Inversion, 7-30 Y-Offset, 2-15, 5-16 Y-Range, 2-15

Ζ

Z Calibration, 7-18, 7-26 Z Range meter, 4-38 Z-Feedback optimizing, 4-44 Z-feedback, 2-12 Z-Gain, 5-7 zoom, 4-52 Z-Range, 2-4, 5-7 function of meter, 4-40 meter function, 4-40 Z-Scanner, 2-14 Z-Sensor, 7-12 Z-sensor, 2-18 Z-Sensor Channel, 4-13 Index

